

Chapter 6

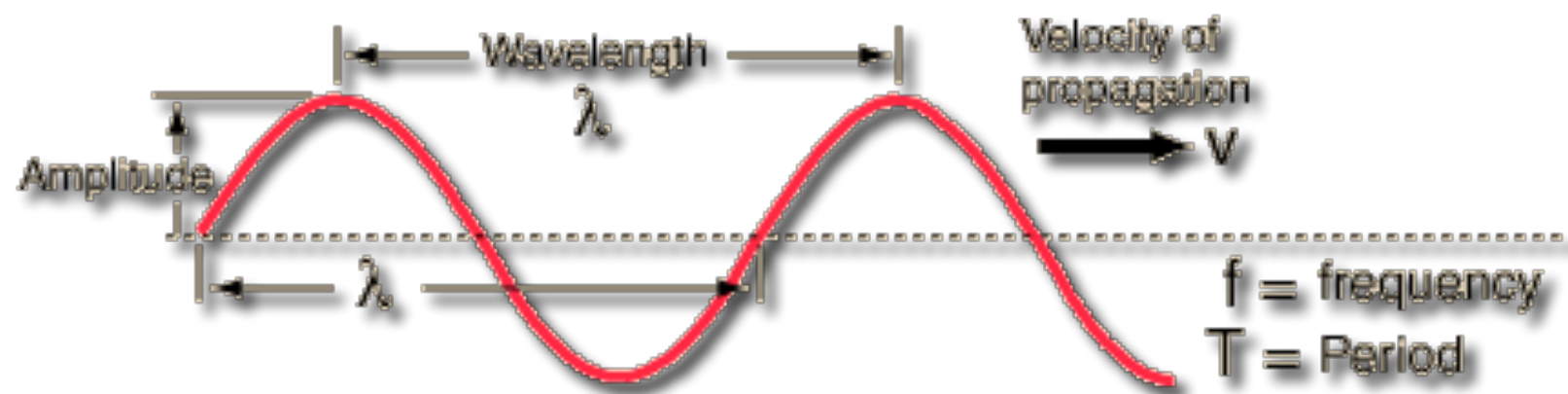
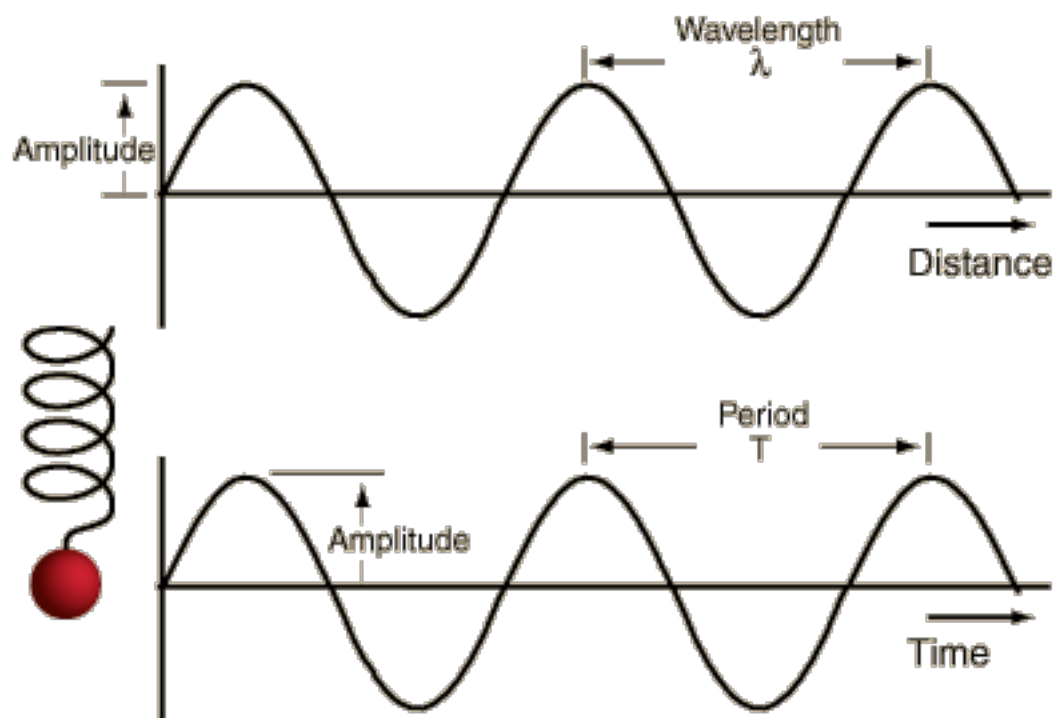
Fourier Optics and High Resolution TEM

(Chapter 28)

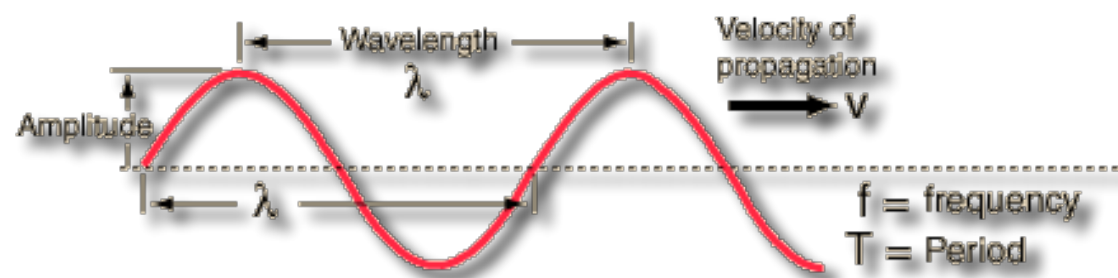


6.1 Periodicity and Frequency

Long λ , Larger period, Low frequency
slow fluctuation in signal



Short λ , smaller period, High frequency
rapid fluctuation in signal

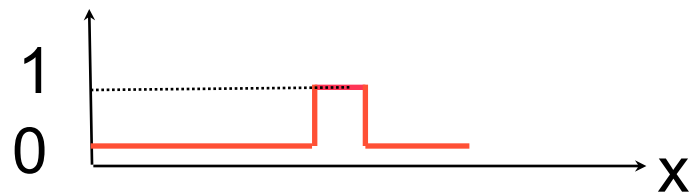


$$\lambda = v \times T$$
$$= v / f$$

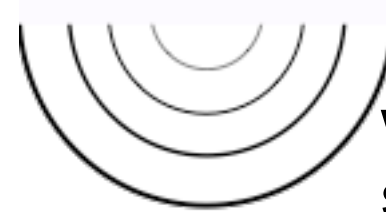
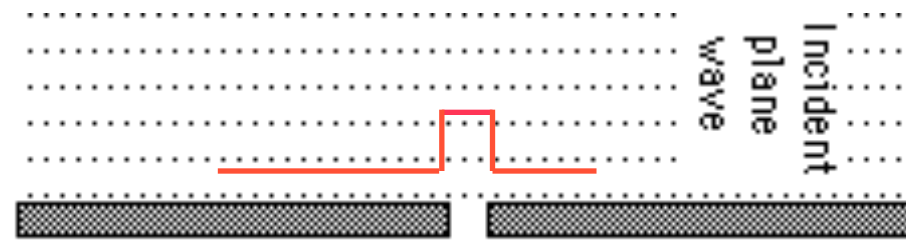
$$T = 1 / f$$



6.2.1 Fresnel and Fraunhofer Diffraction of Single Slit



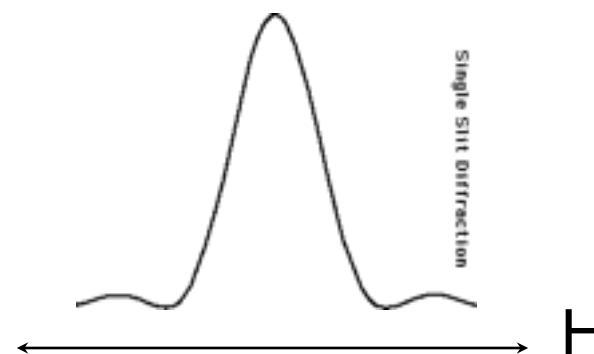
Fresnel Diffraction
(near field)

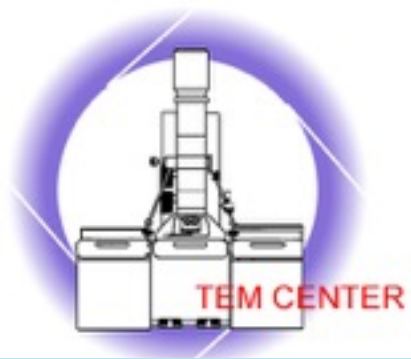


wave front of
spherical wave

Fraunhofer Diffraction
(far field)

Fourier Transform of 1
flat hat functions

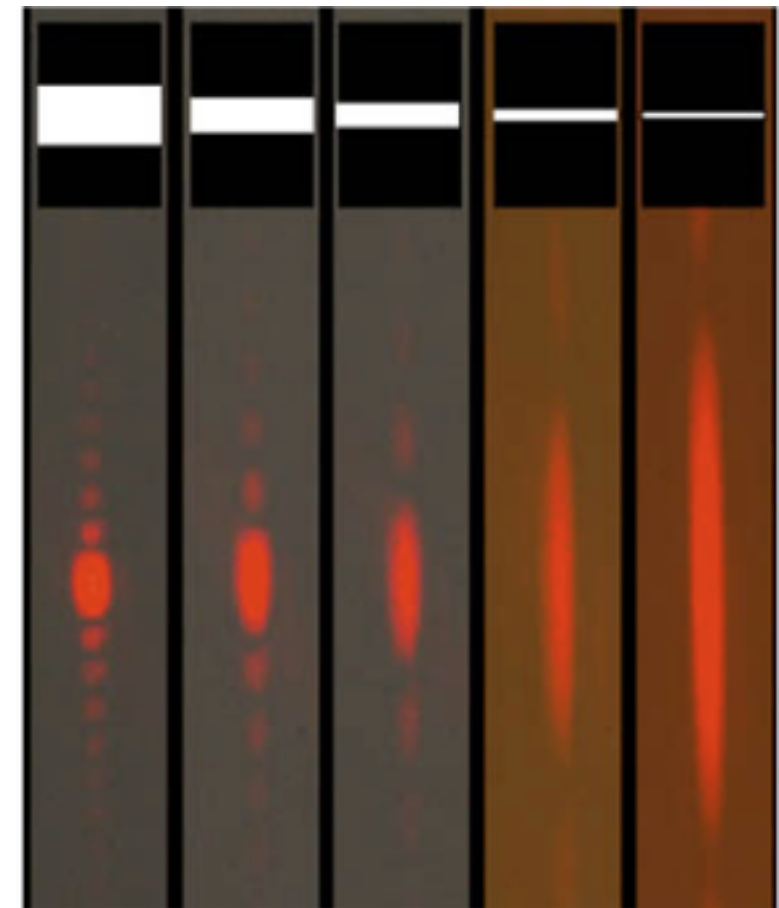
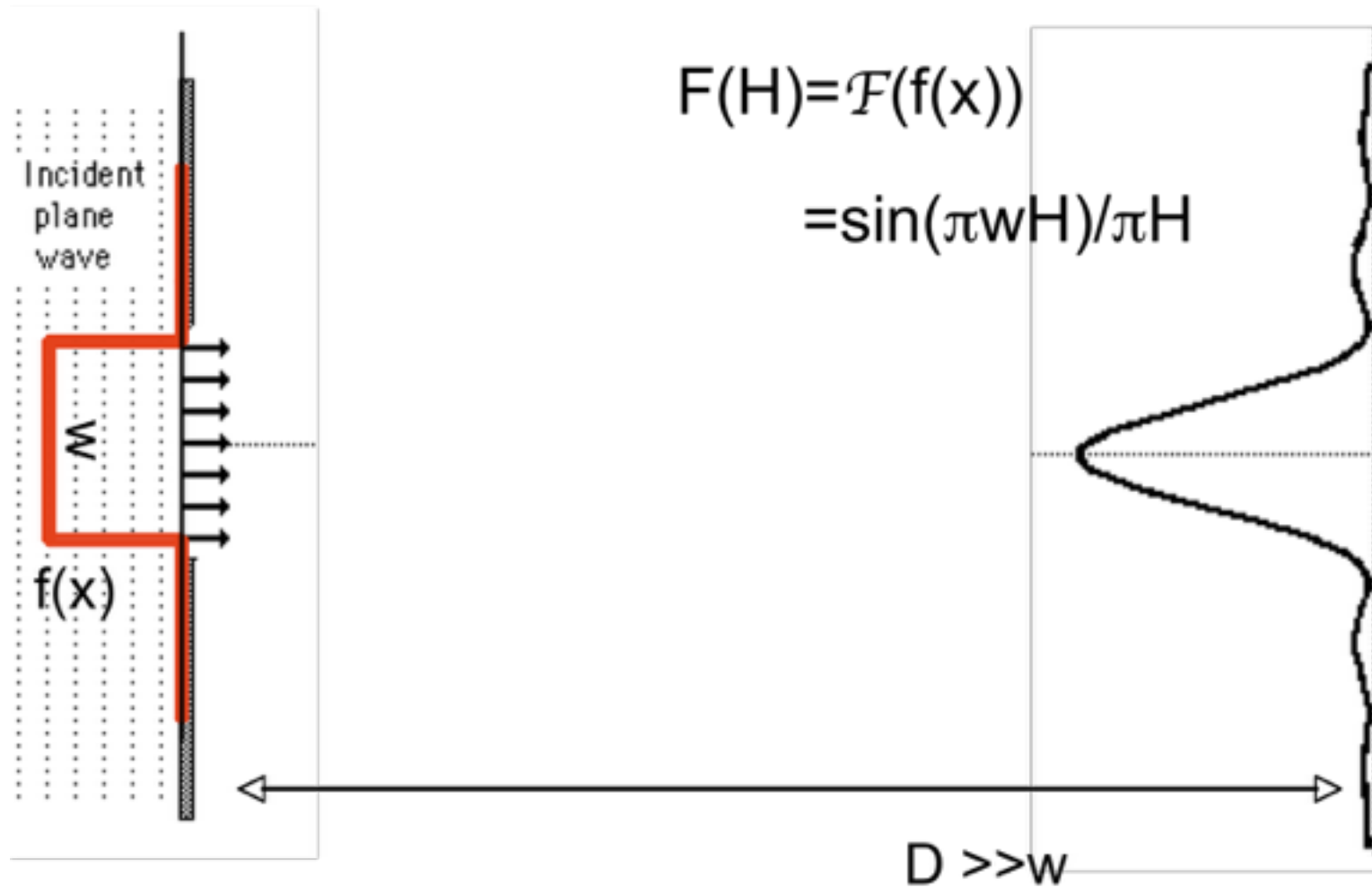


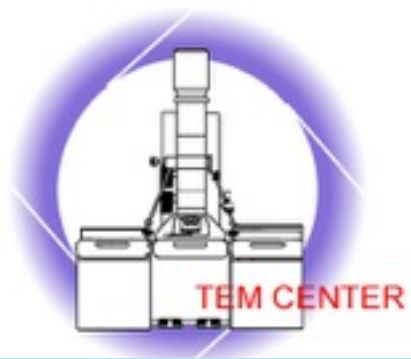


Fourier Transform of Top-Hat Function

Fraunhofer Diffraction

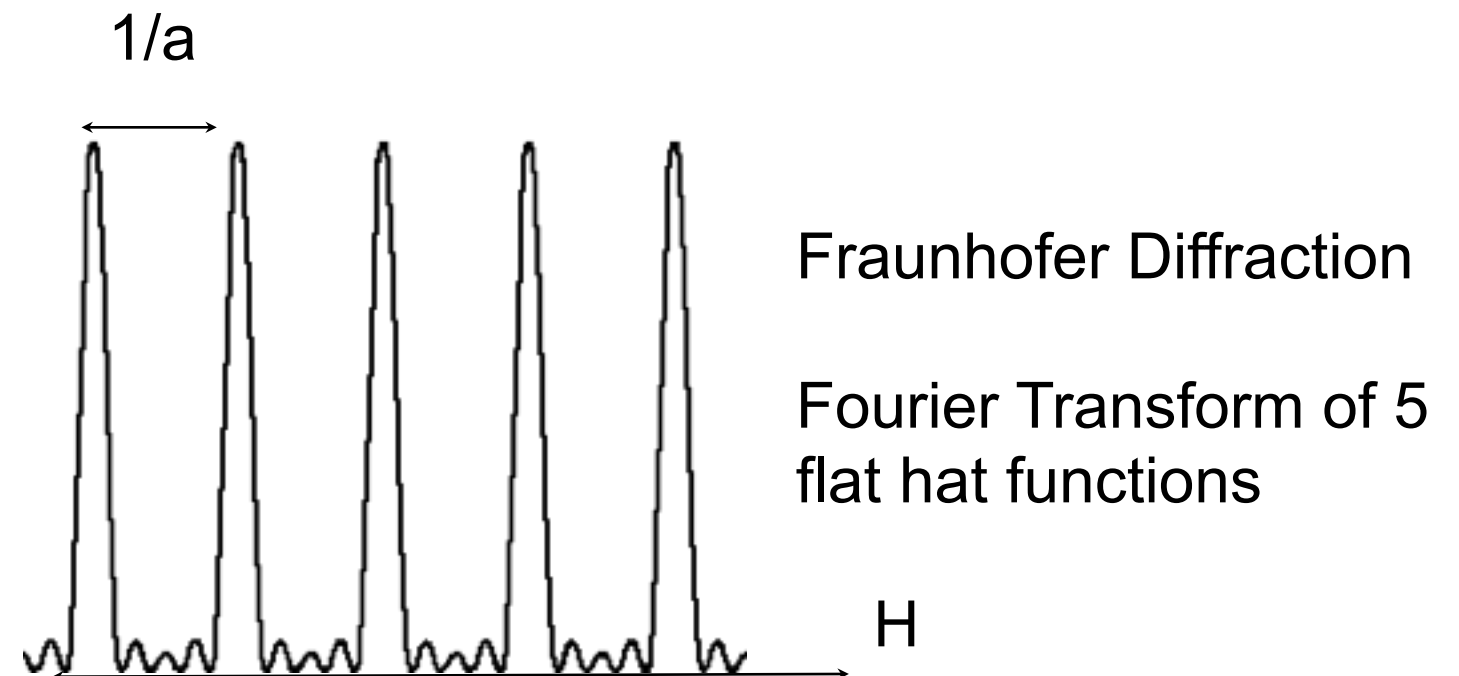
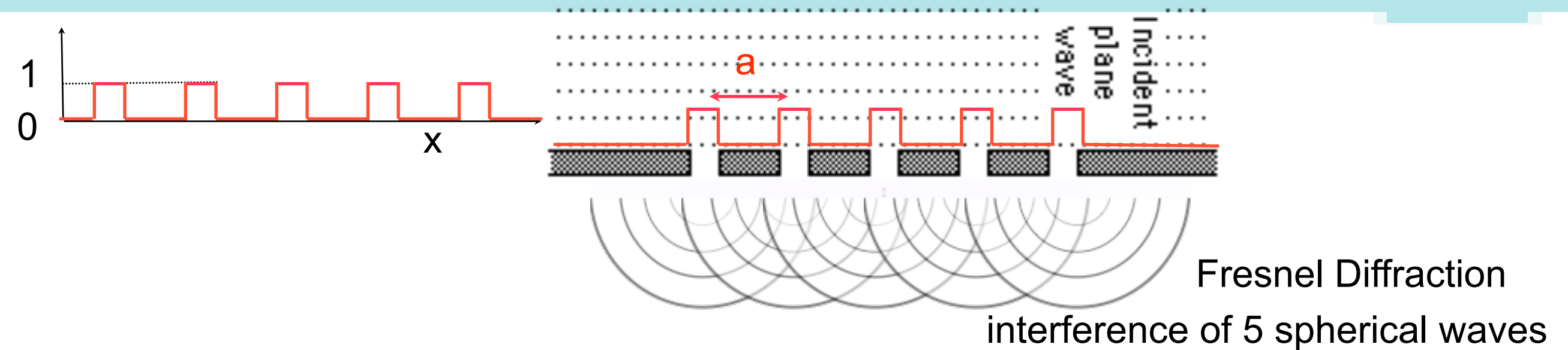
NTHU





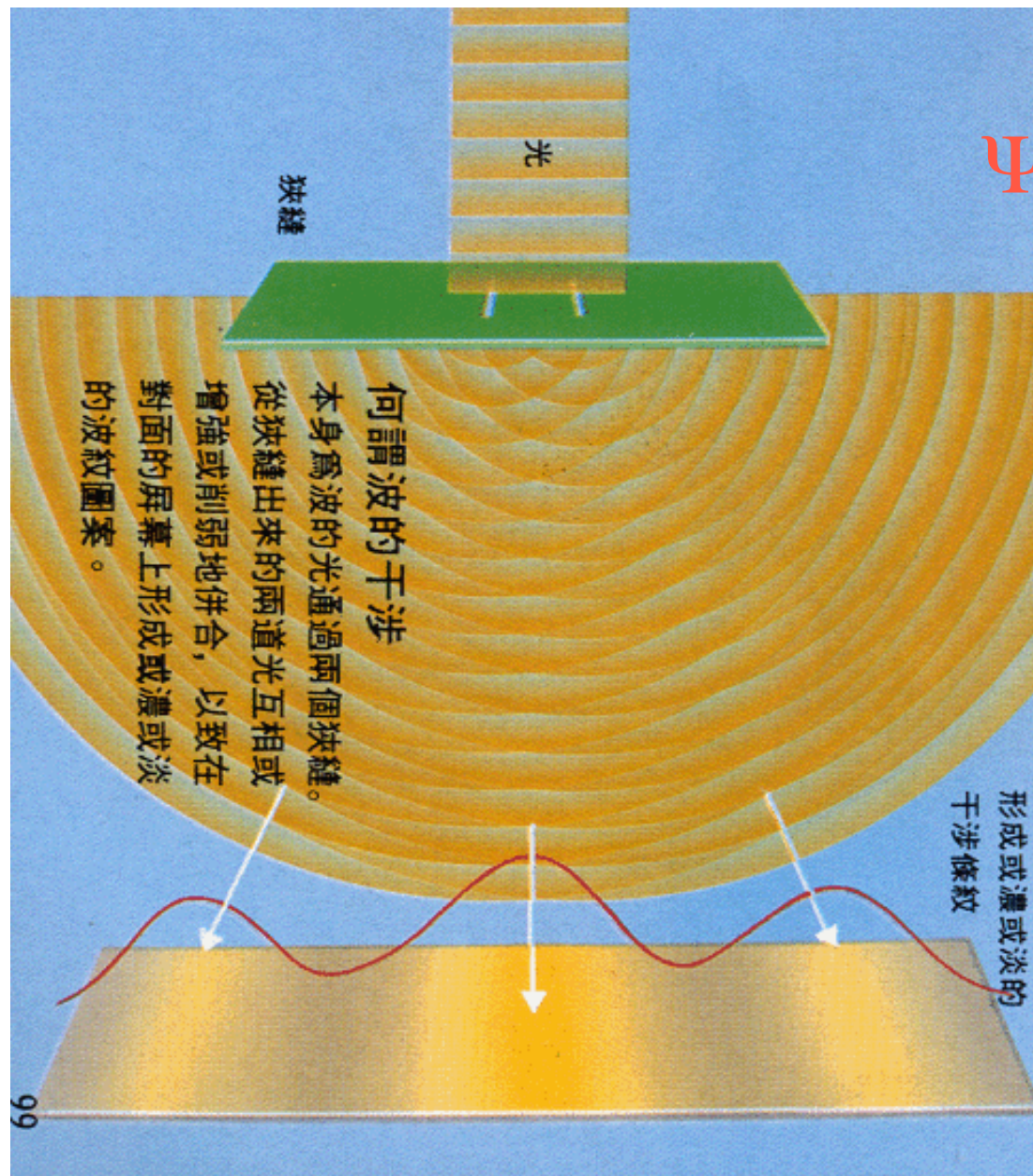
6.2.2 Fresnel and Fraunhofer Diffraction of Multi-grating

NTHU

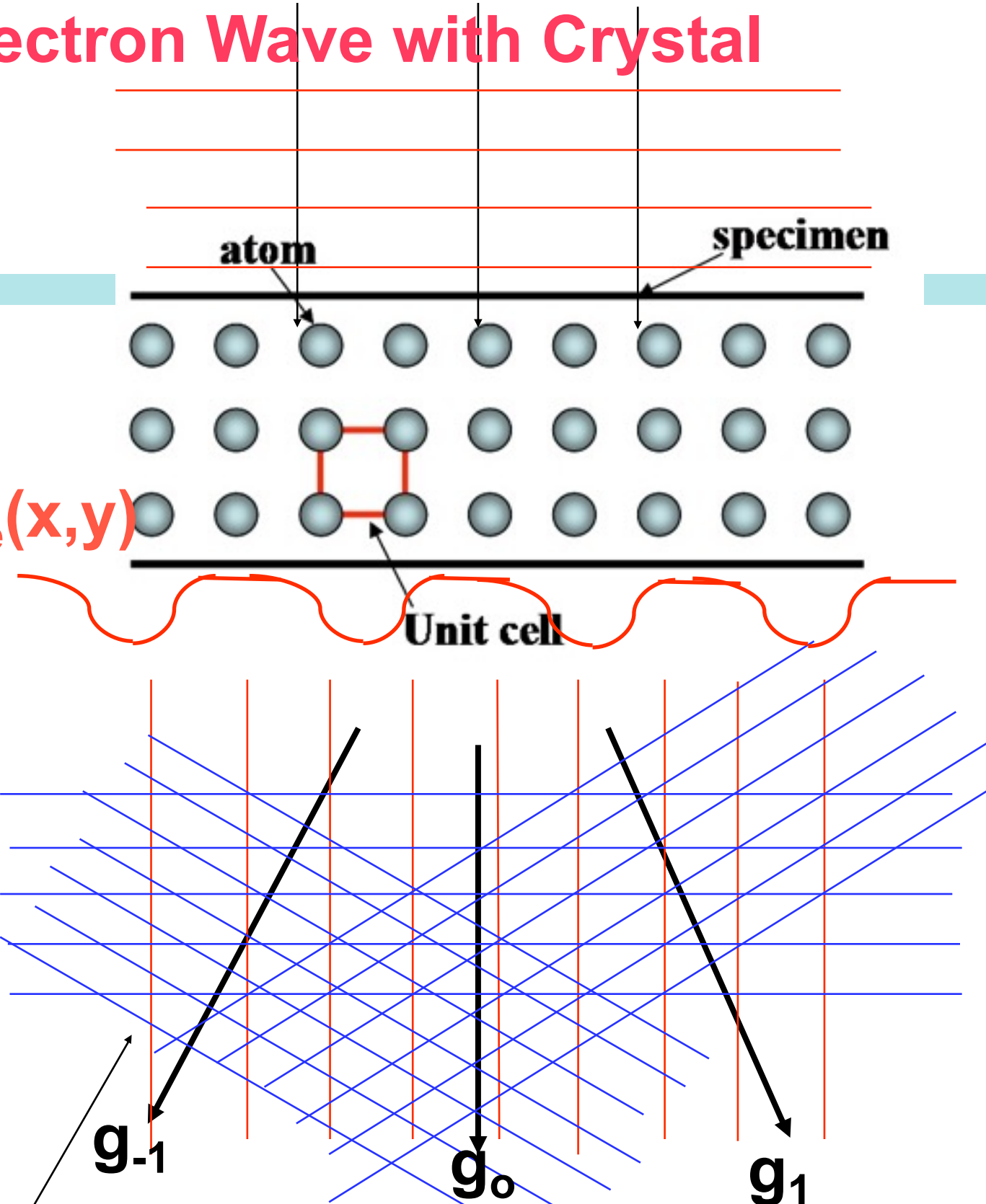




6.3 Interaction of Electron Wave with Crystal



$\Psi_e(x,y)$



Ψ_e is composed of many Fourier components

$$\Psi_e(x,y) = \sum_{H=-g}^g F(H) \exp(-2\pi H \cdot r)$$

亮線位置不一定與原子柱位置重疊



Fourier Synthesis

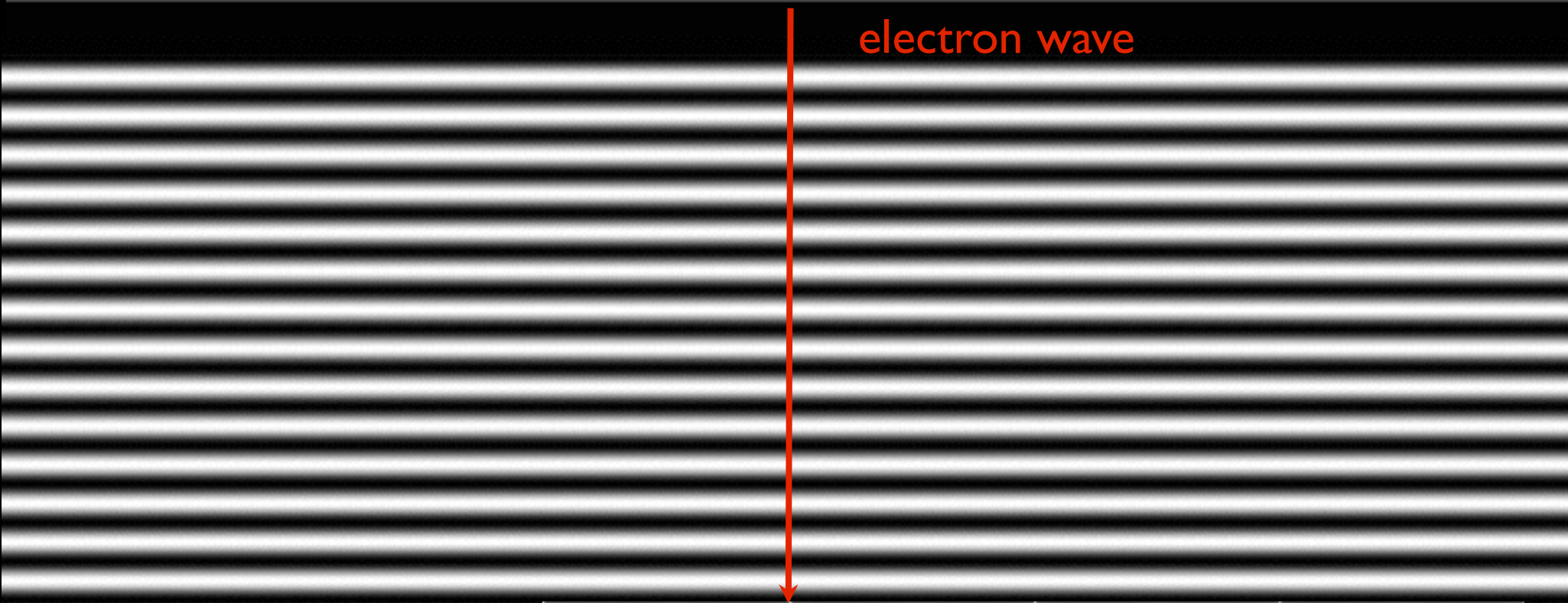
$$f(x) = F(0) + \sum_n F(H_n) \exp(-2\pi n x / a)$$

$$H_n = 2\pi n / a$$

$$f(x) = F(0) + \sum_n \underbrace{F(H_n)}_{\text{Amplitude}} \exp(\underbrace{-H_n x}_{\text{Phase}})$$

So, the $f(x)$ can be regarded as a summation of a series of “WAVE”

electron wave

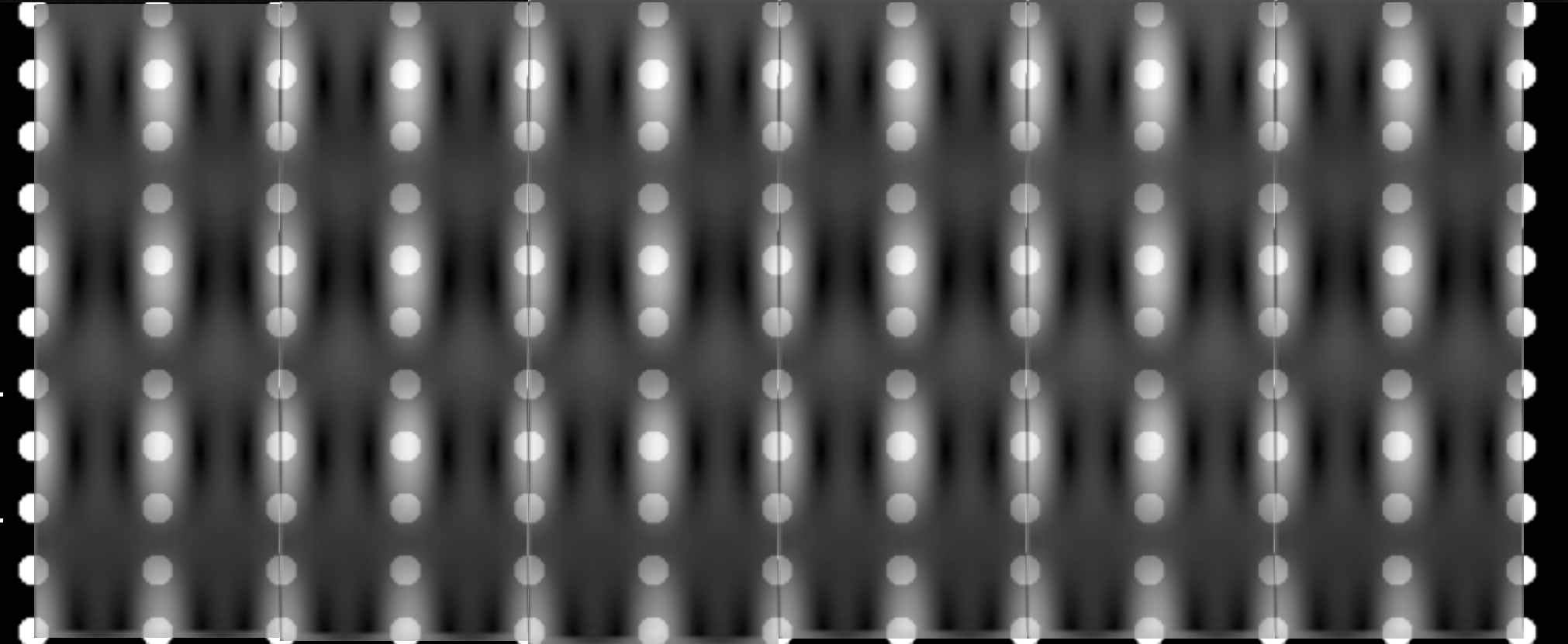


Electron Channeling

wave propagates inside crystal

~ electrons are trapped along the atomic columns

depends on z



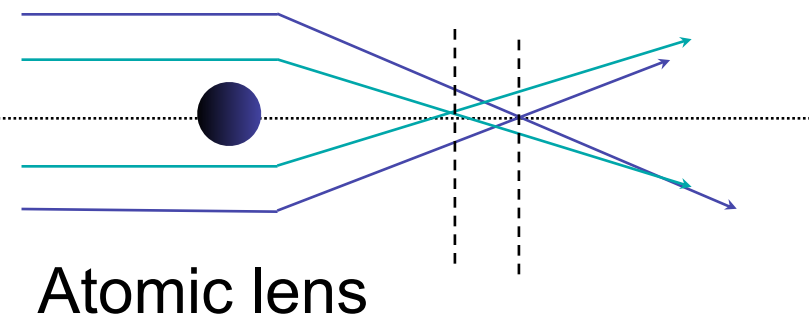
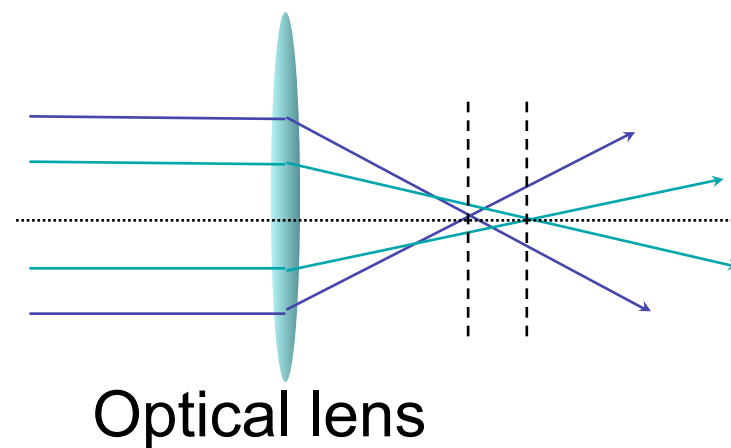
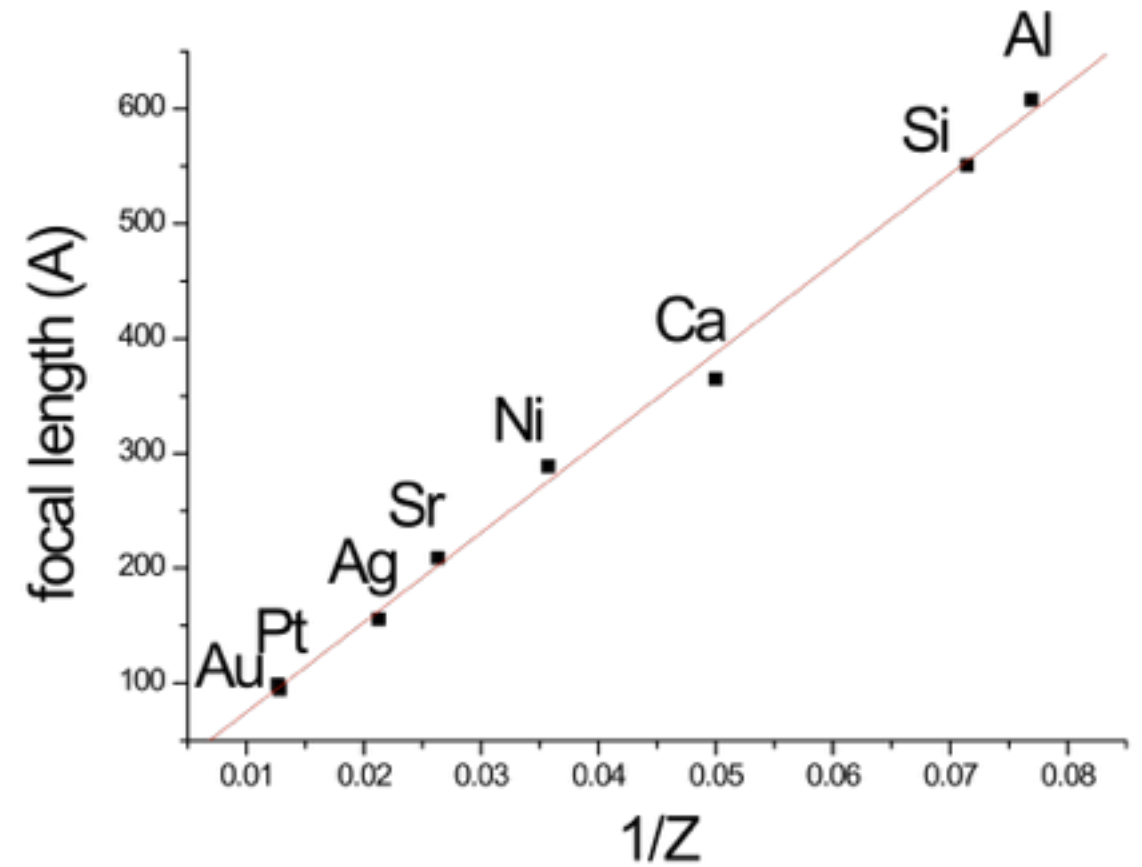
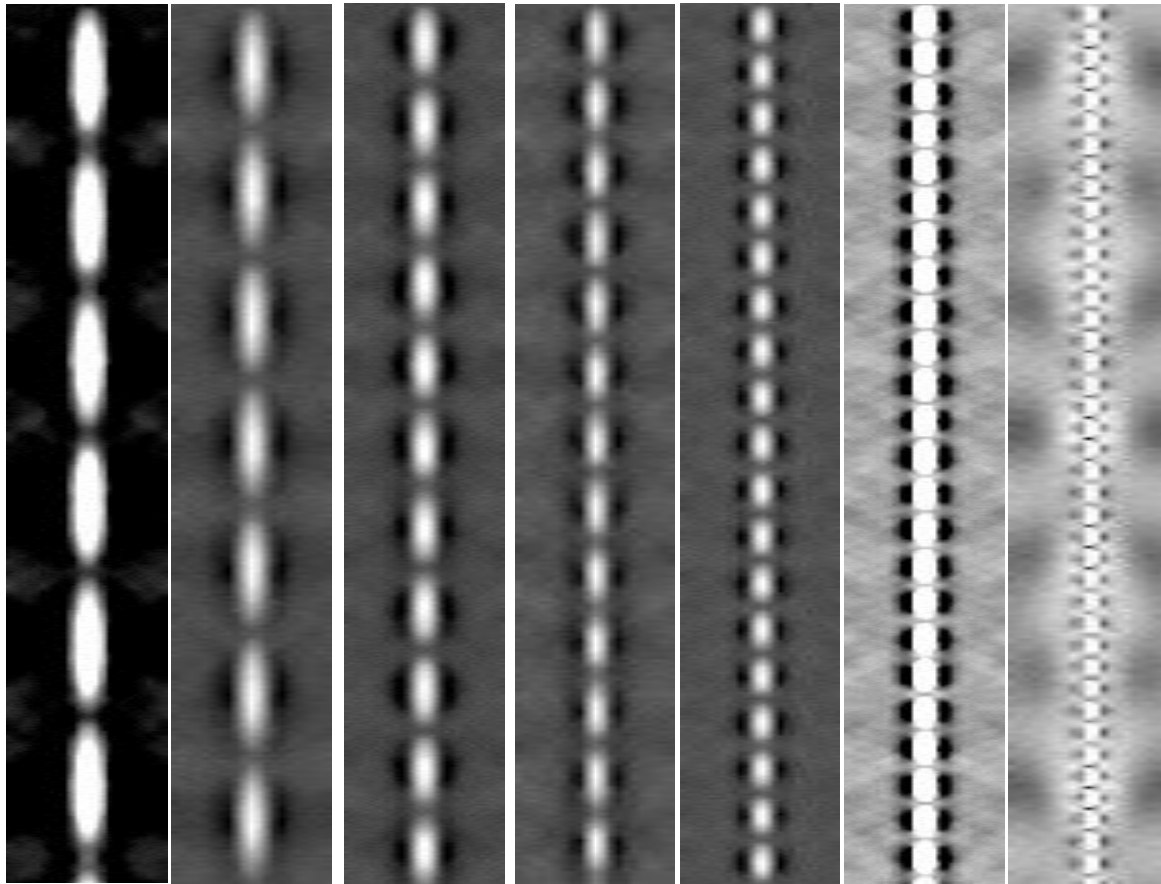
Exit Wave

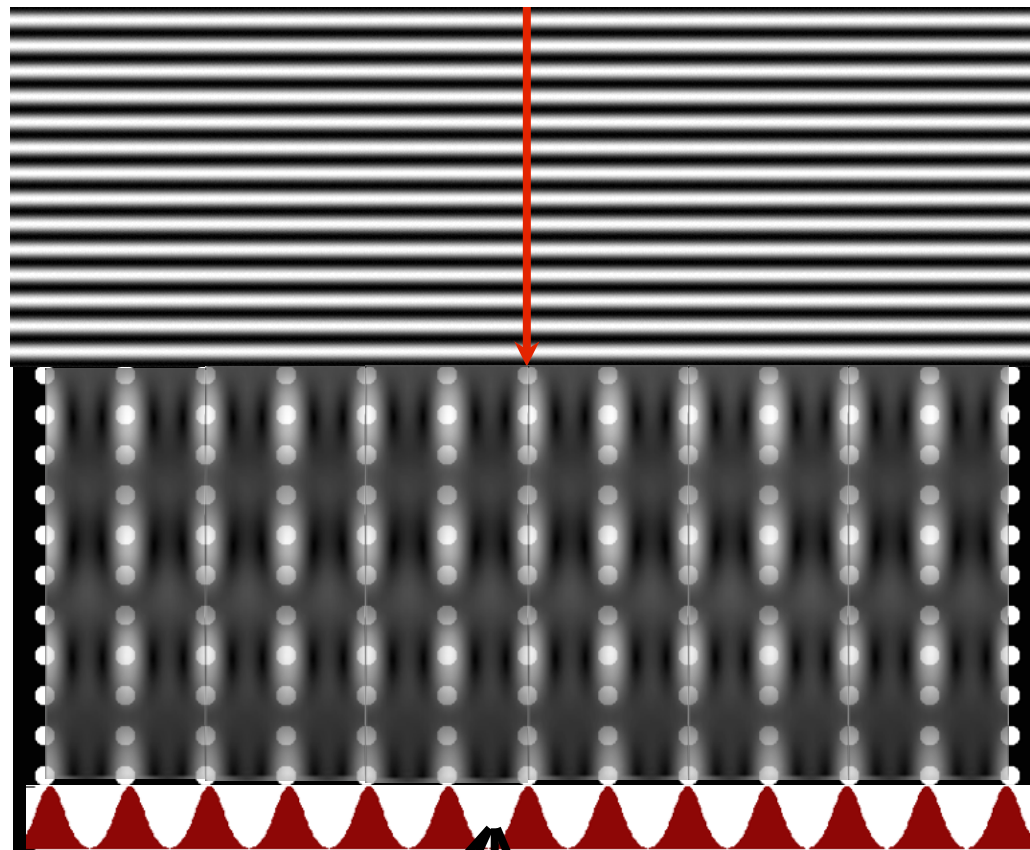
6.3 Wave Propagates inside Crystal

Channeling Theory

Al

Au





electron wave

exit wave

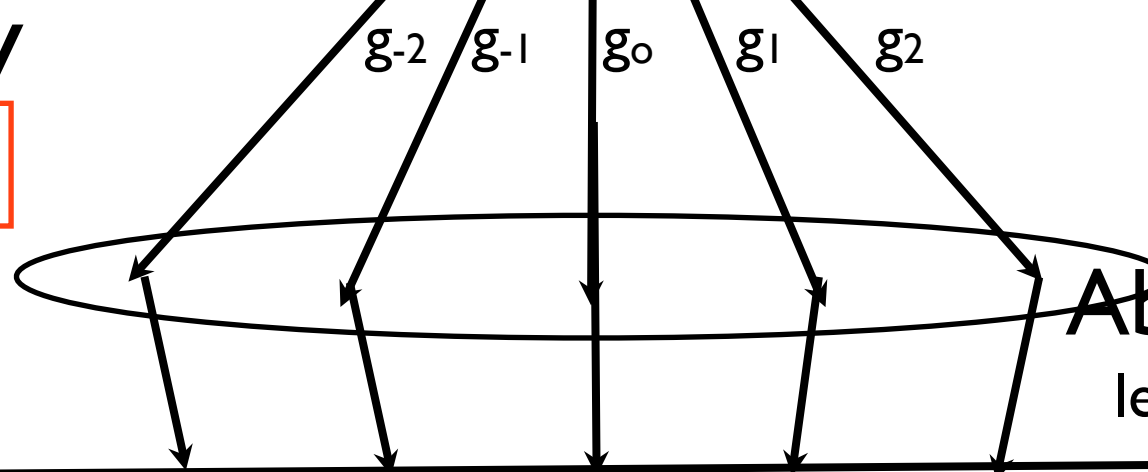
$$\psi_e(r) = A(r) \exp(i\varphi(r))$$

Fourier Theory

$$\psi_e(x,y) = \sum F(g) \exp(2\pi g r)$$

Physics

each Fourier component is called diffracted wave



Abbe Microscopy Theory

lens does two Fourier transforms

Focal plane

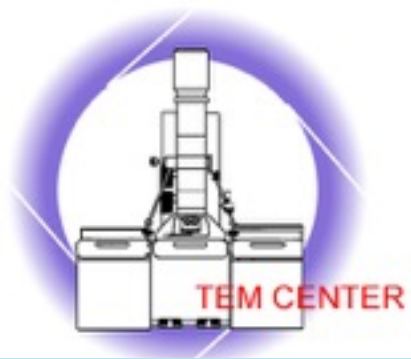
$$|F(g_{-2})|^2 \quad |F(g_{-1})|^2 \quad |F(g_0)|^2 \quad |F(g_1)|^2 \quad |F(g_2)|^2$$

lens aberrations modify the Fourier Components



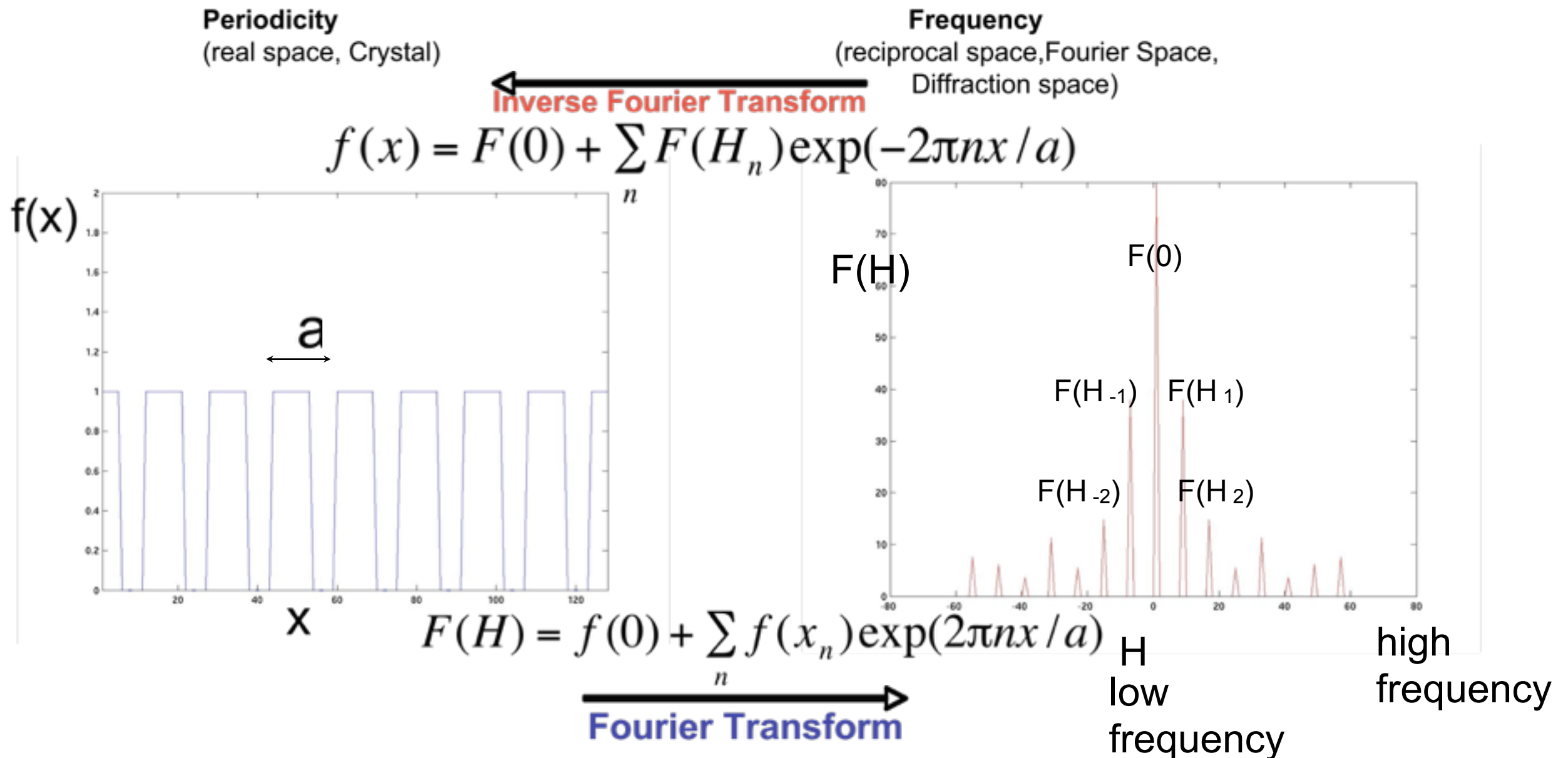
image plane

$$I = |A(r)|^2, \text{ Phase lost}$$



6.4 Fourier Synthesis

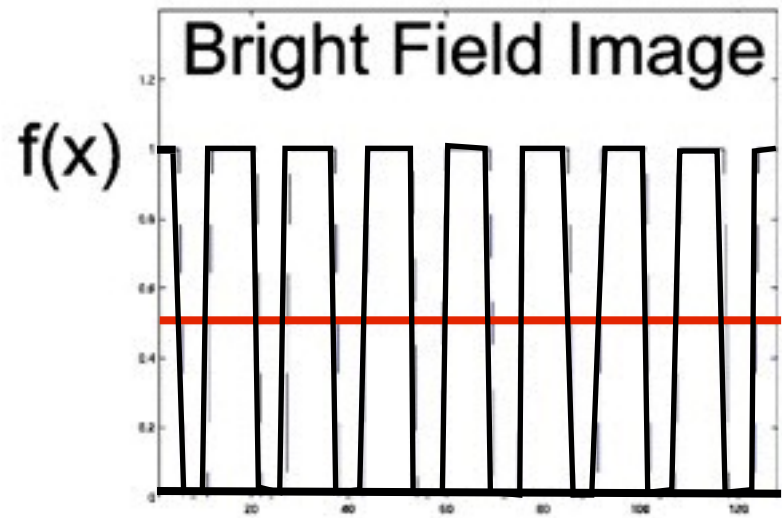
An function $f(x)$ can be expressed in terms of sum of a series of Fourier coefficients $F(H)$ multiply by the sine (or cosine, or exponential) functions



Periodicity
(real space, Crystal)

Frequency
(reciprocal space, Fourier Space,
Diffraction space)

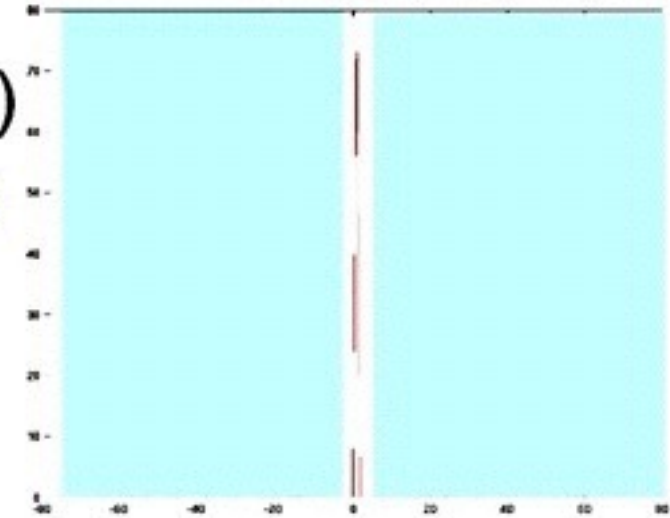
Fourier Synthesis



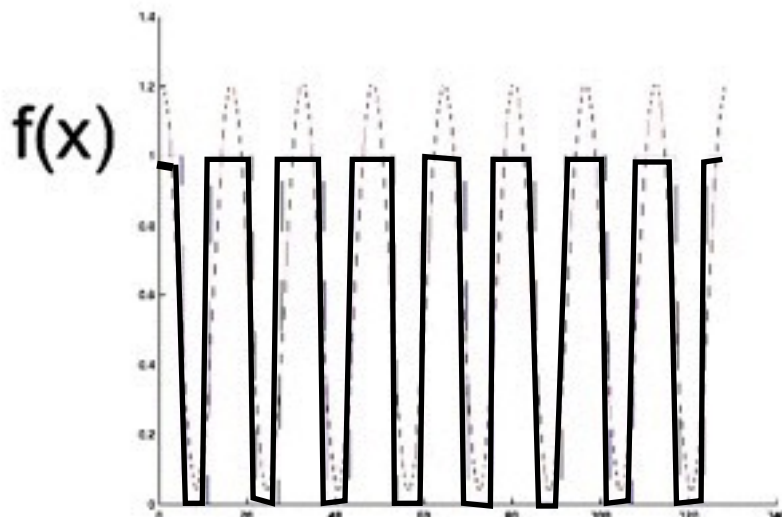
Inverse Fourier Transform



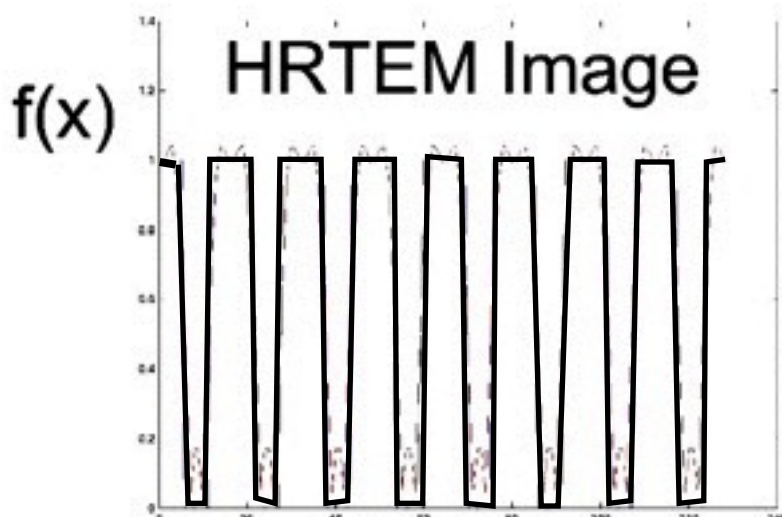
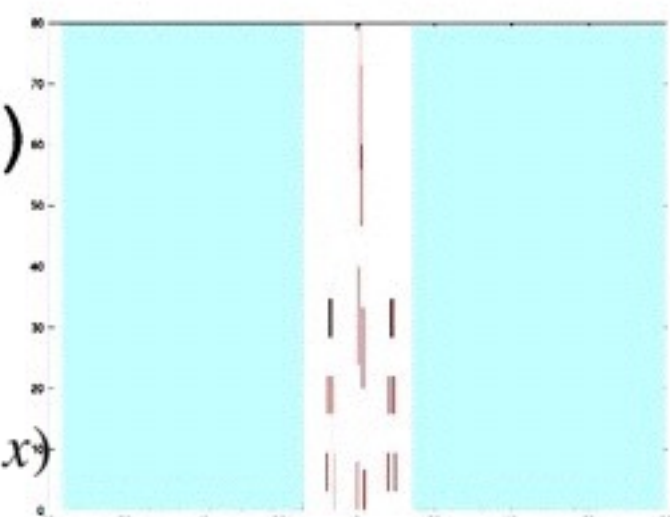
$$f(x) = F(0)\exp(-0 \cdot x)$$



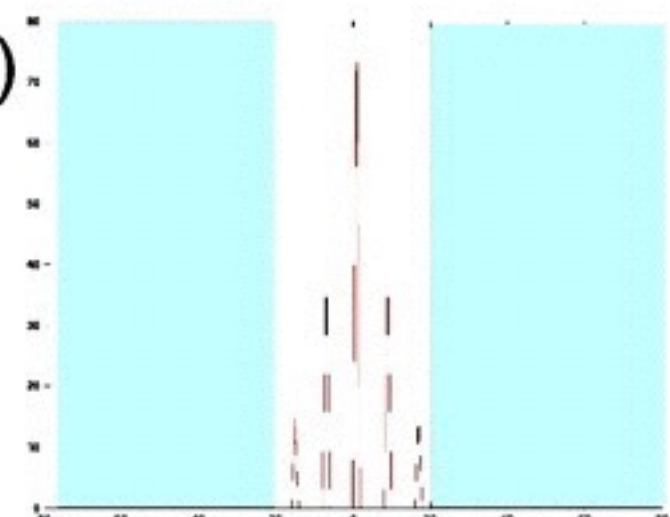
Low
Frequ



$$f(x) = F(0) + F(H_1)\exp(-H_1x) + F(H_{-1})\exp(-H_{-1}x)$$

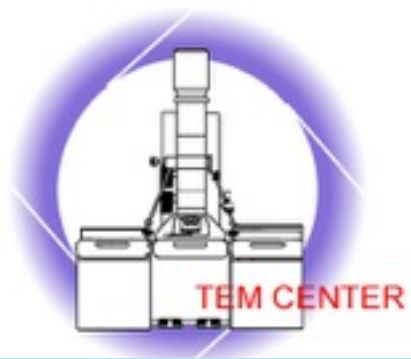


$$f(x) = F(0) + F(H_1)\exp(-H_1x) + F(H_{-1})\exp(-H_{-1}x) + F(H_2)\exp(-H_2x) + F(H_{-2})\exp(-H_{-2}x)$$



High
Frequ



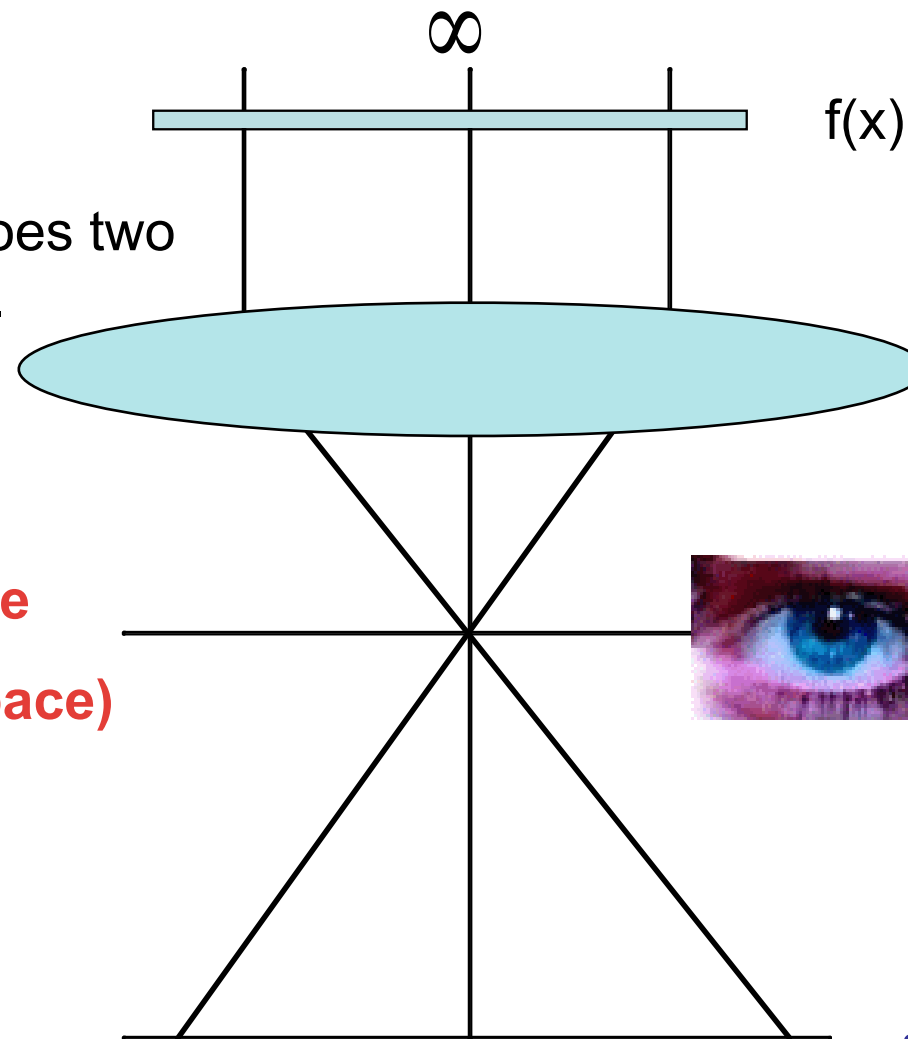


6.5 Abbe Theory of Microscopy

A perfect microscope does two Fourier transformations.

One at **back focal plane**
(Fourier, reciprocal space)

One at **image plane**



For an observer at the focal plane, the beam comes from infinite. So he observes a

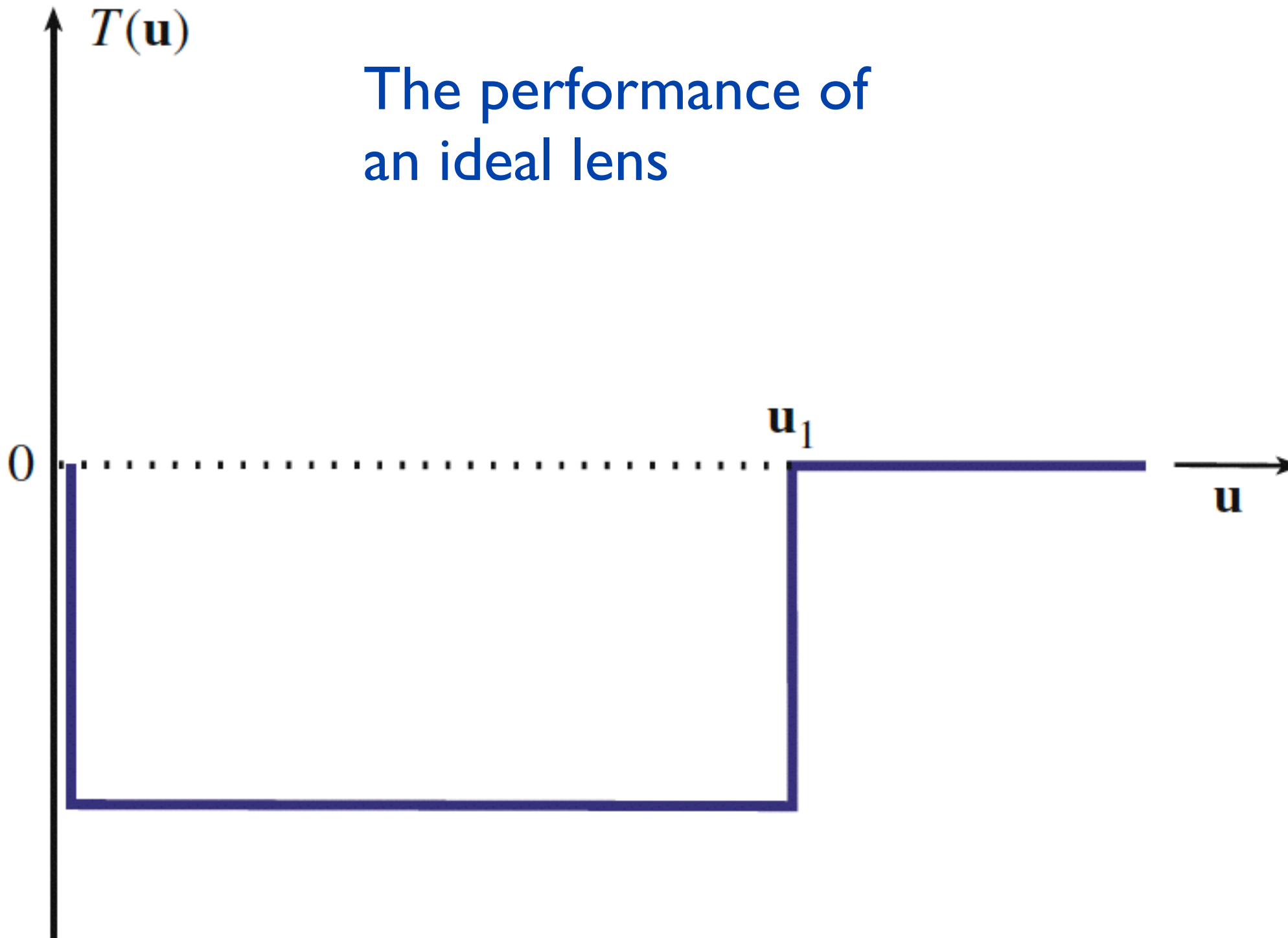
Fraunhofer Diffraction pattern $F(H)=\mathcal{F}(f(x))$

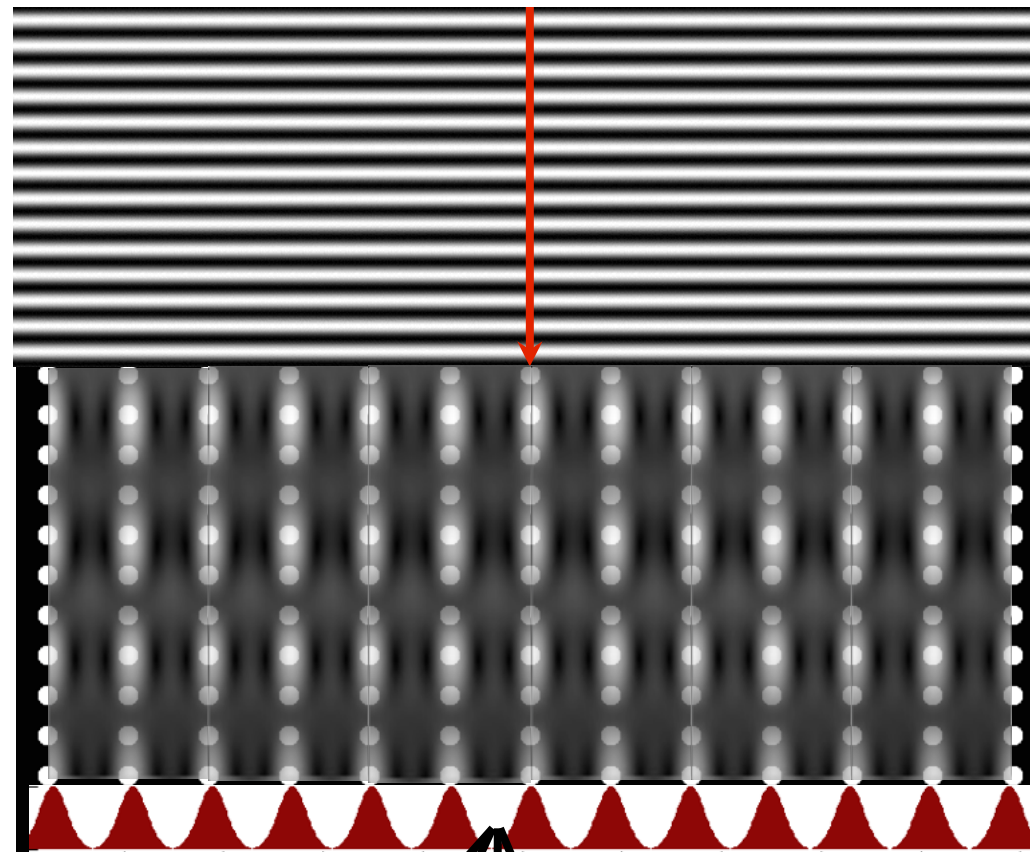
$$f(-x/M)=\mathcal{F}^{-1}(\mathcal{F}(f(x)))$$

Inverted and Real Image



Ideal Transfer function

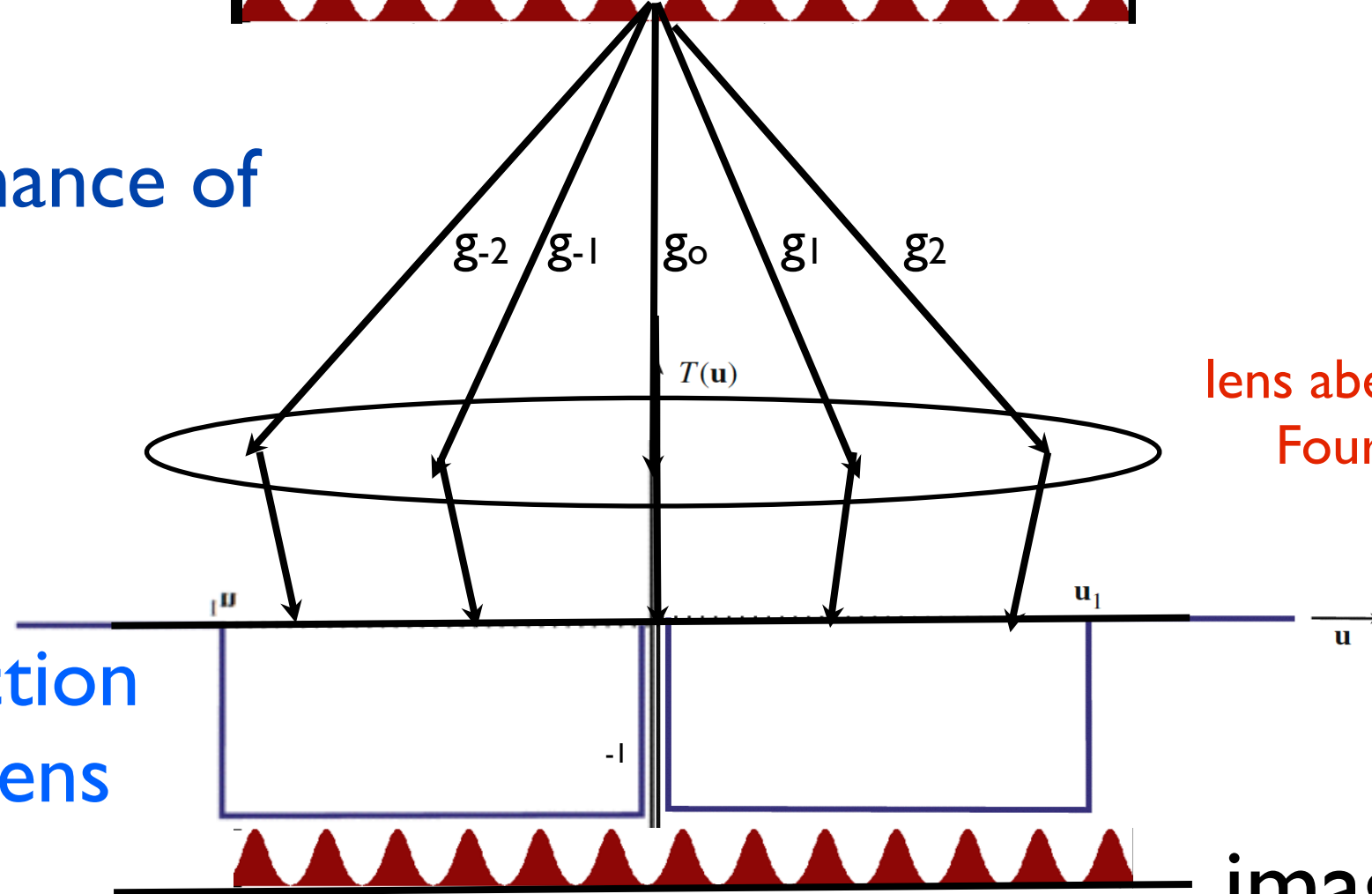




electron wave

The performance of an ideal lens

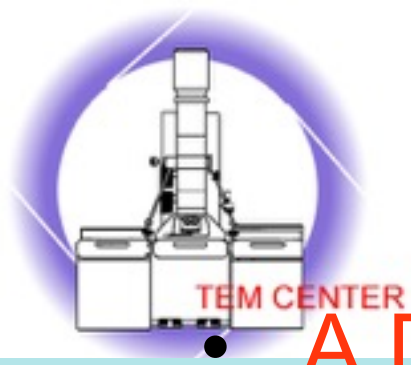
transfer function for an ideal lens



lens aberrations modify the Fourier Components

image plane

$$I = |A(r)|^2, \text{ Phase lost}$$



6.6 Lens Aberrations

NTHU

- **A. Defocus (correctable)**

- The wave propagates a finite distance from the position of exact focus (Change phase of Fourier waves)

- **B. Spherical aberration (correctable)**

- lens has different focus power to beam from different angles ◦ (Change phase of Fourier waves)

- **C. Chromatical aberration (correctable)**

- lens has different focus power to beam with different wavelength (energy) (Change modulus of Fourier waves)

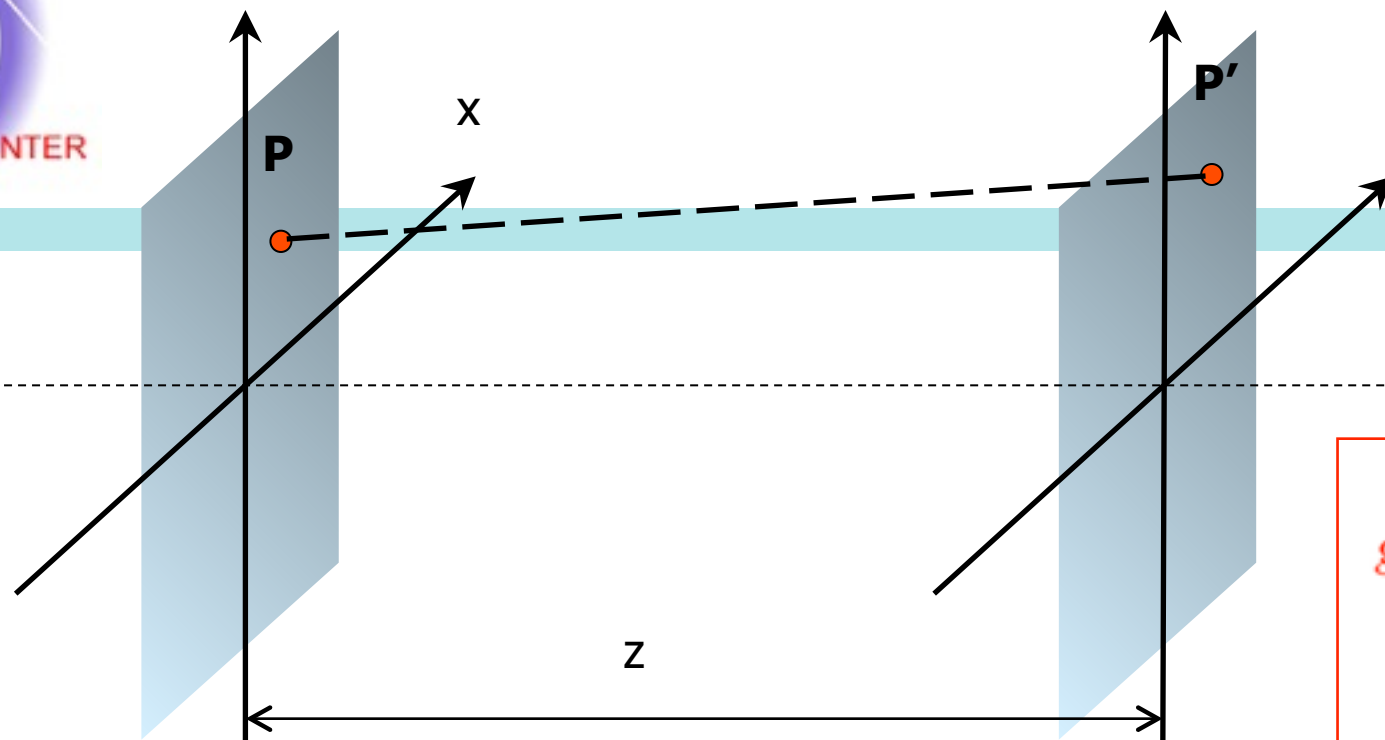
- **D. Spatial Coherency (partially correctable)**

- lens has different focus power to beam with different wavelength (energy) (Change modulus



Defocus and Fresnel Diffraction

NTHU



$$g(x, y) = \int_{-\infty}^{\infty} f(x', y') \phi(x - x', y - y') dx' dy'$$

$$= f(x, y) * \phi(x, y)$$

$$\psi_1(x, y)$$

$$\psi_2(x, y)$$

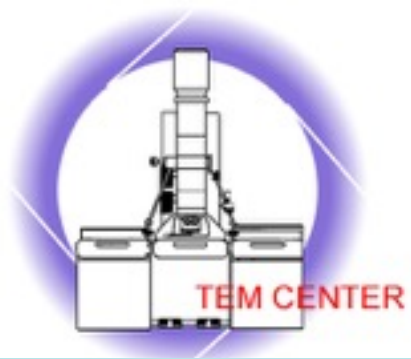
$$\psi_2(x, y) \approx \frac{i \exp(-2\pi iz / \lambda)}{\lambda z} \iint \psi_1(x, y) \exp\left\{-\frac{i\pi}{\lambda z} [(x - X)^2 + (y - Y)^2]\right\} dXdY$$

$$= A \psi_1(x, y) \otimes \exp\left\{-\frac{i\pi}{\lambda z} [x^2 + y^2]\right\}$$

$$\psi_2(x, y) = \psi_1(x, y) \otimes P_z(x, y)$$

Convolution relates information between Real Space--> Real Space.

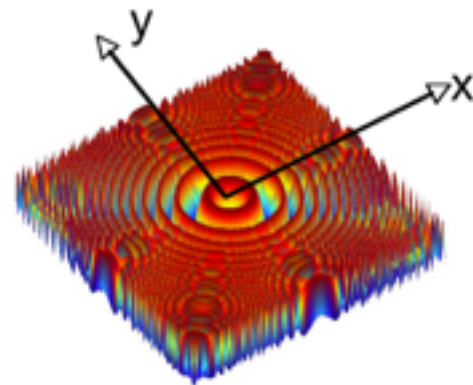
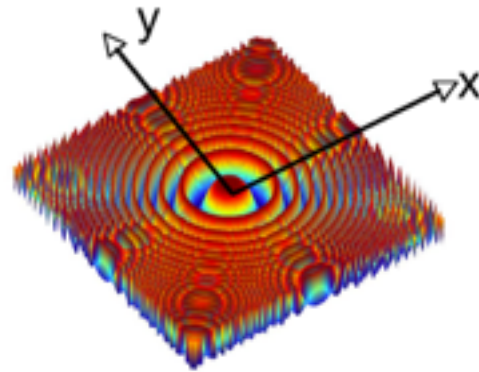
When a signal propagates to a finite distance z , the information will be modified by convolution with a propagator $P_z(x, y)$



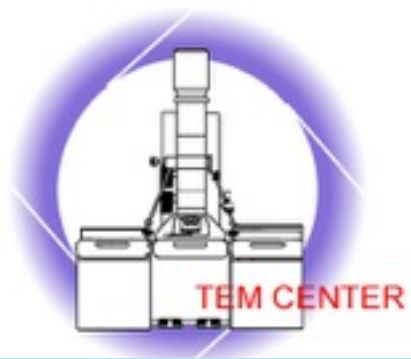
Example of Fresnel Diffraction



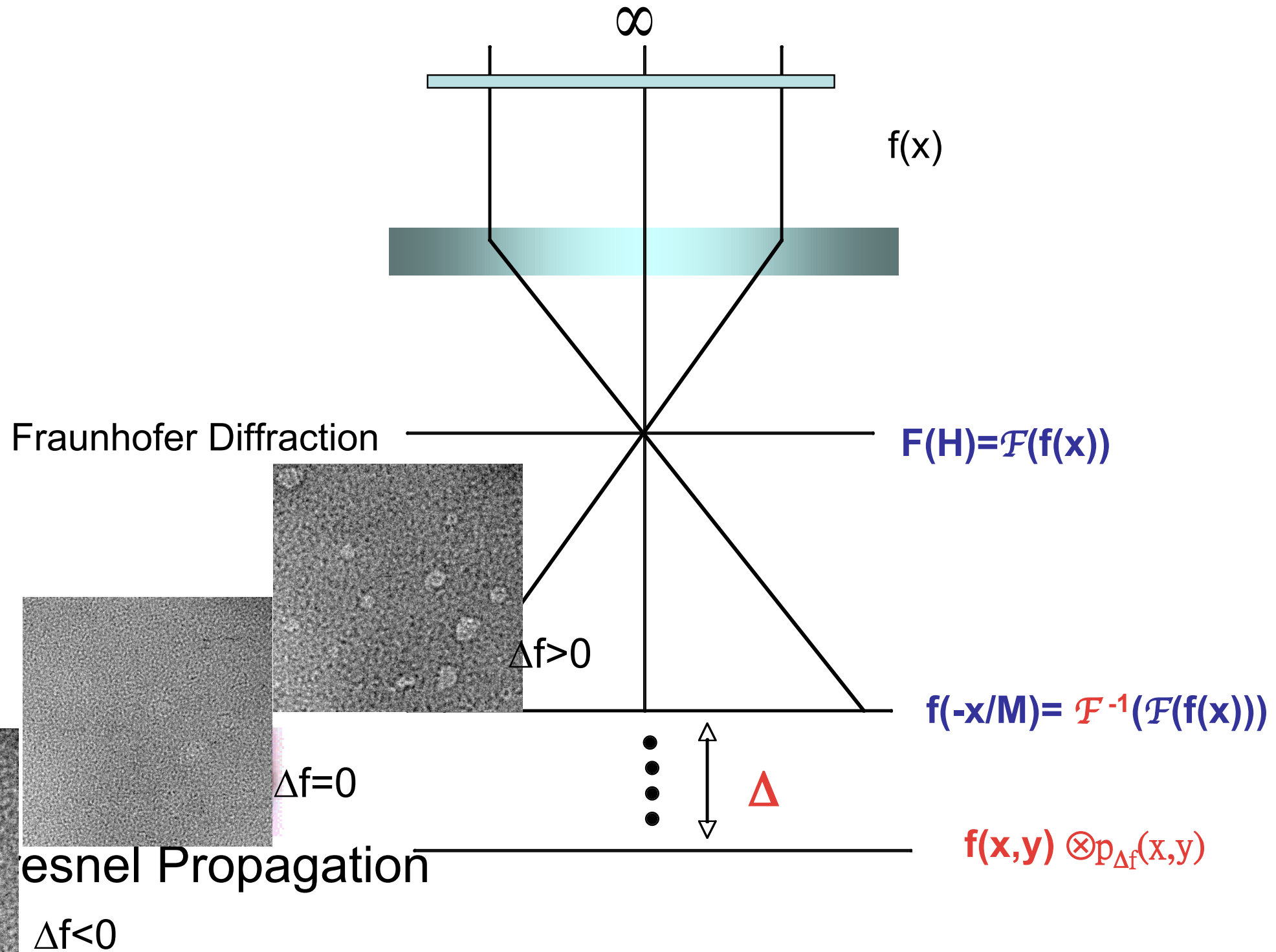
⊗



$$p_z(x,y) = \exp(-2\pi i \lambda (x^2 + y^2) / 2z)$$



6.6.1 Fresnel Propagation in de-focus plane





Aberration From Focus (造成相位差: 越高頻修正越大)

NTHU

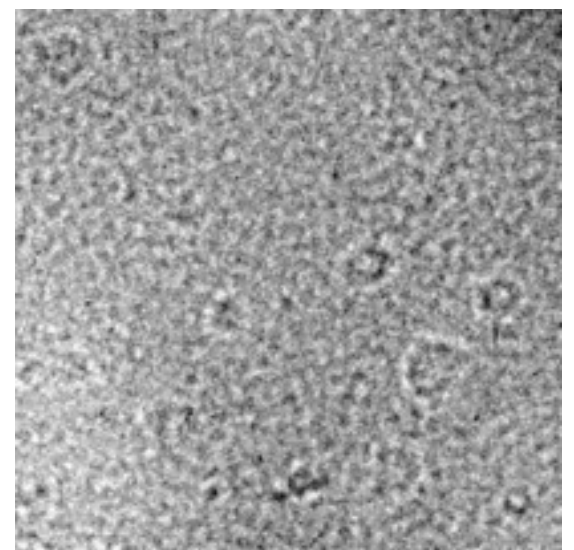
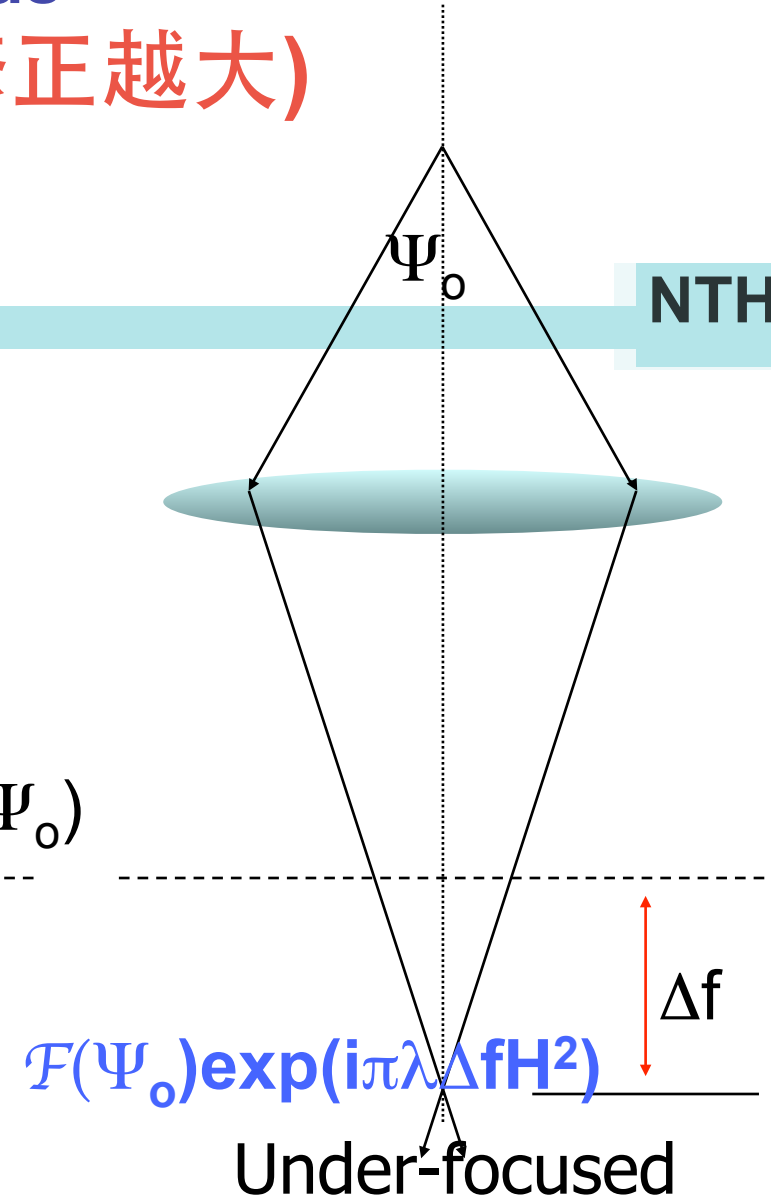
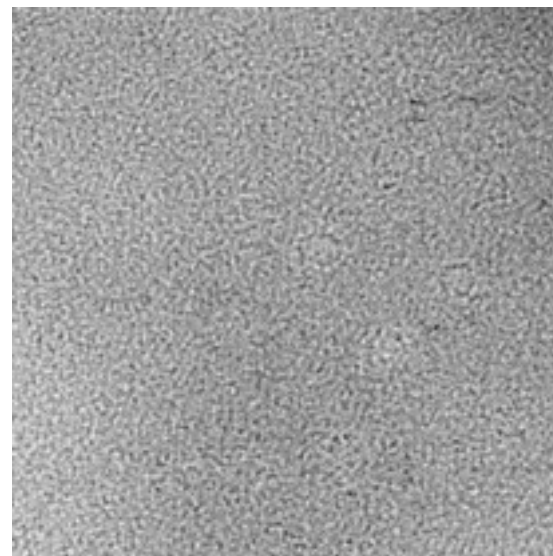
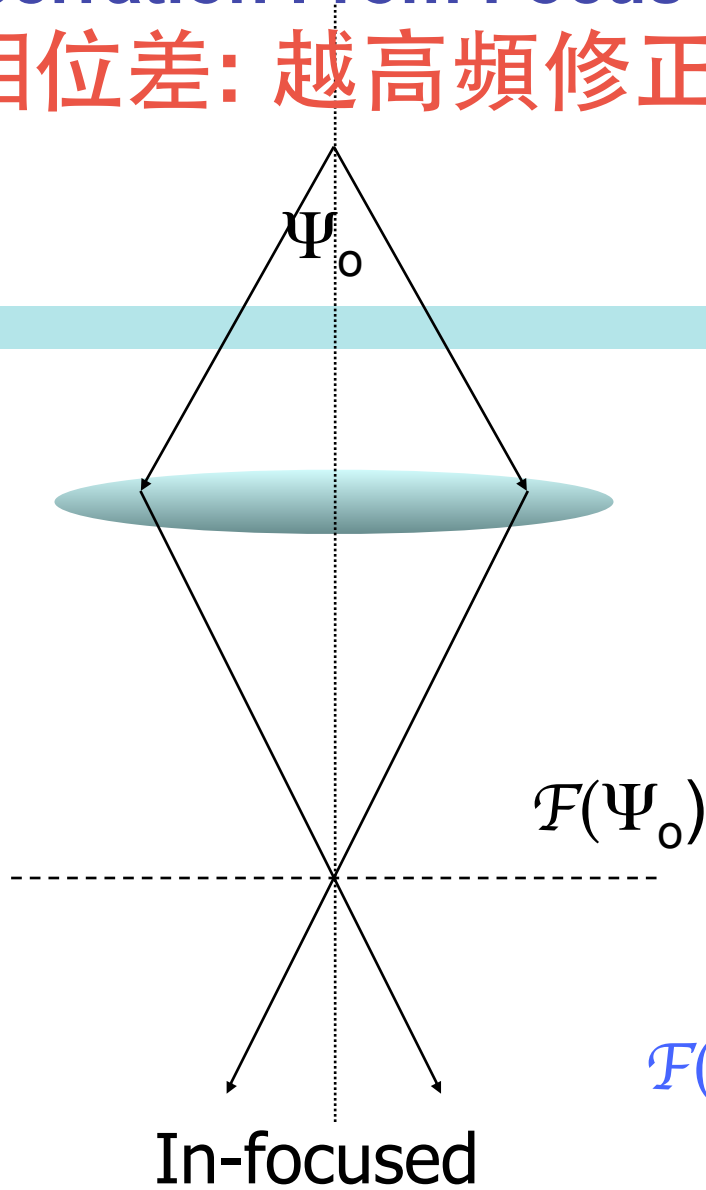
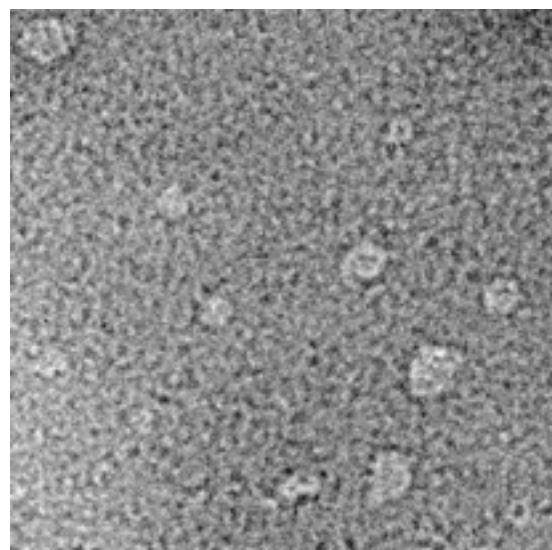
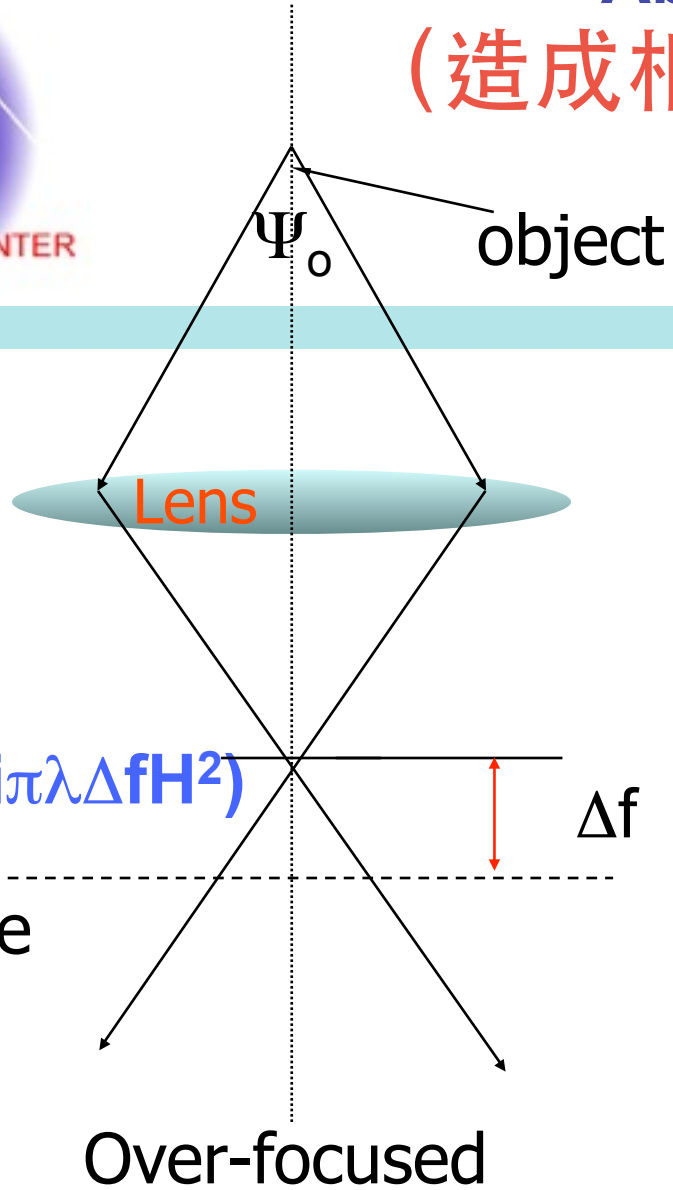


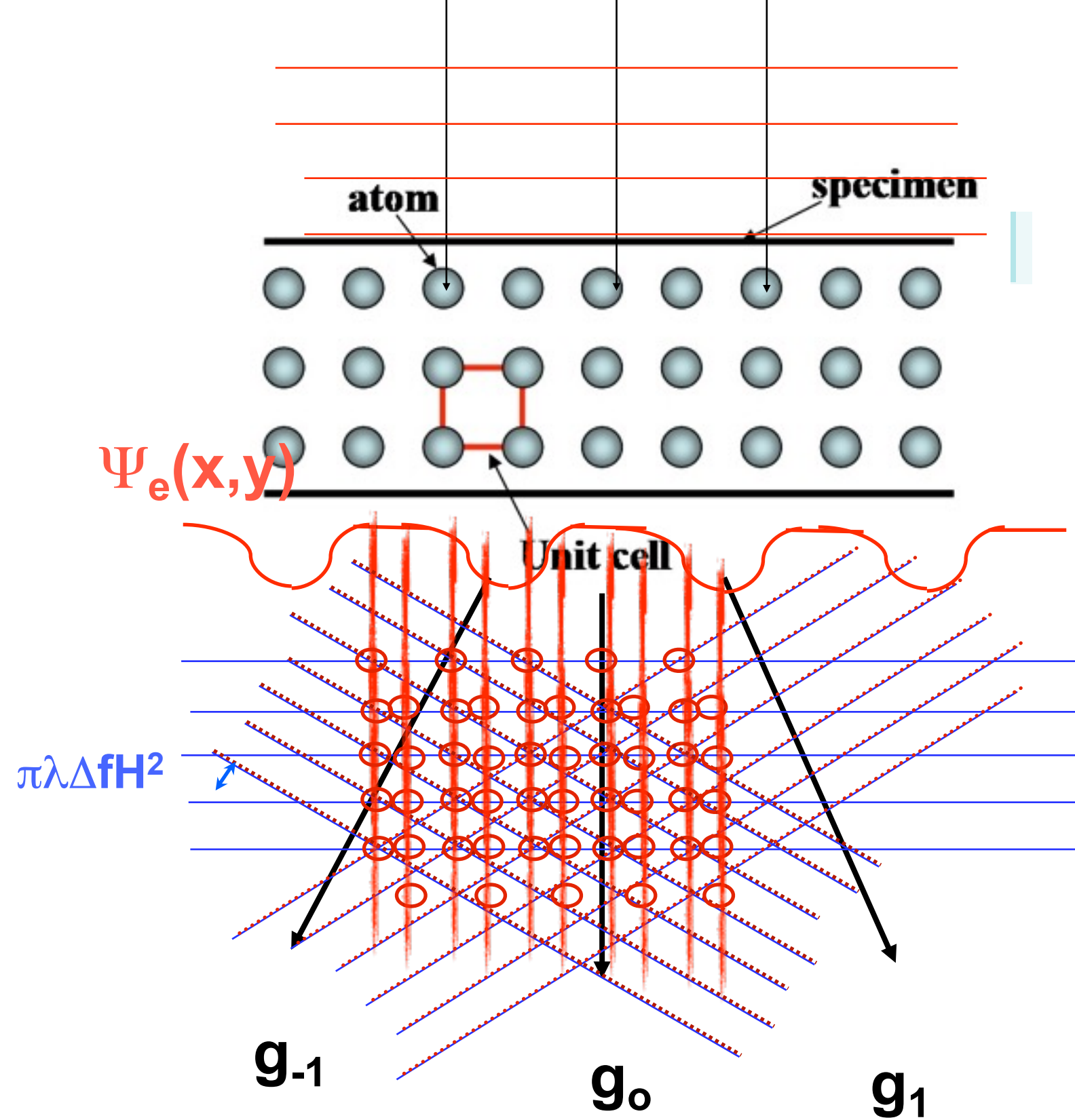
Image Plane

$$\Psi_i = [\Psi_0 \otimes \exp(-i\pi(x^2+y^2)/\lambda\Delta f)]$$

$$I = \Psi_i \Psi_i^*$$

$$\Psi_i = \Psi_0$$

$$\Psi_i = [\Psi_0 \otimes \exp(i\pi(x^2+y^2)/\lambda\Delta f)]$$



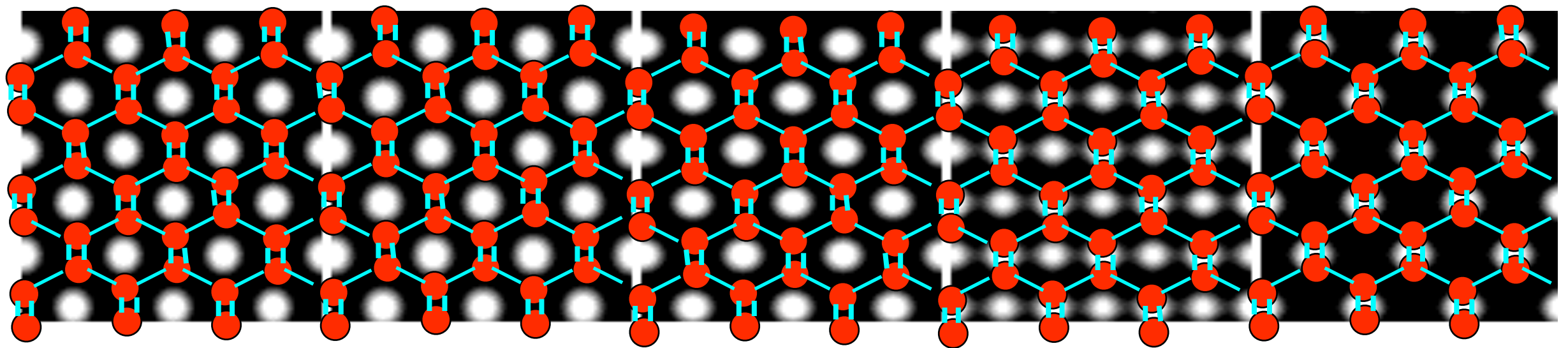
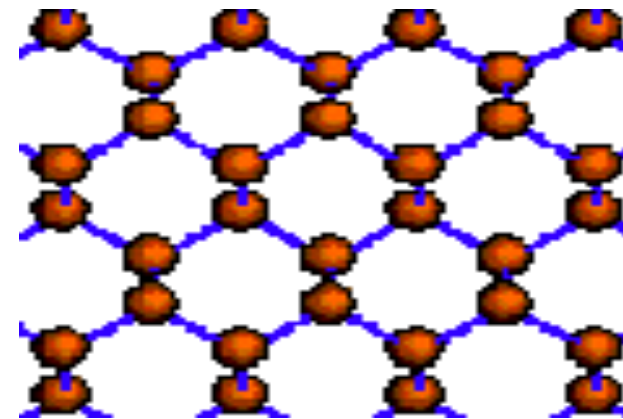
Ψ_e is composed of many Fourier components



高分辨影像之行為隨著欠焦而變

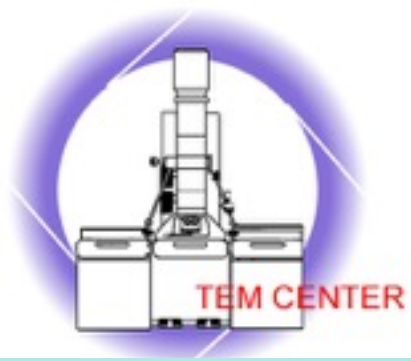
NTHU

Si [110], 400keV



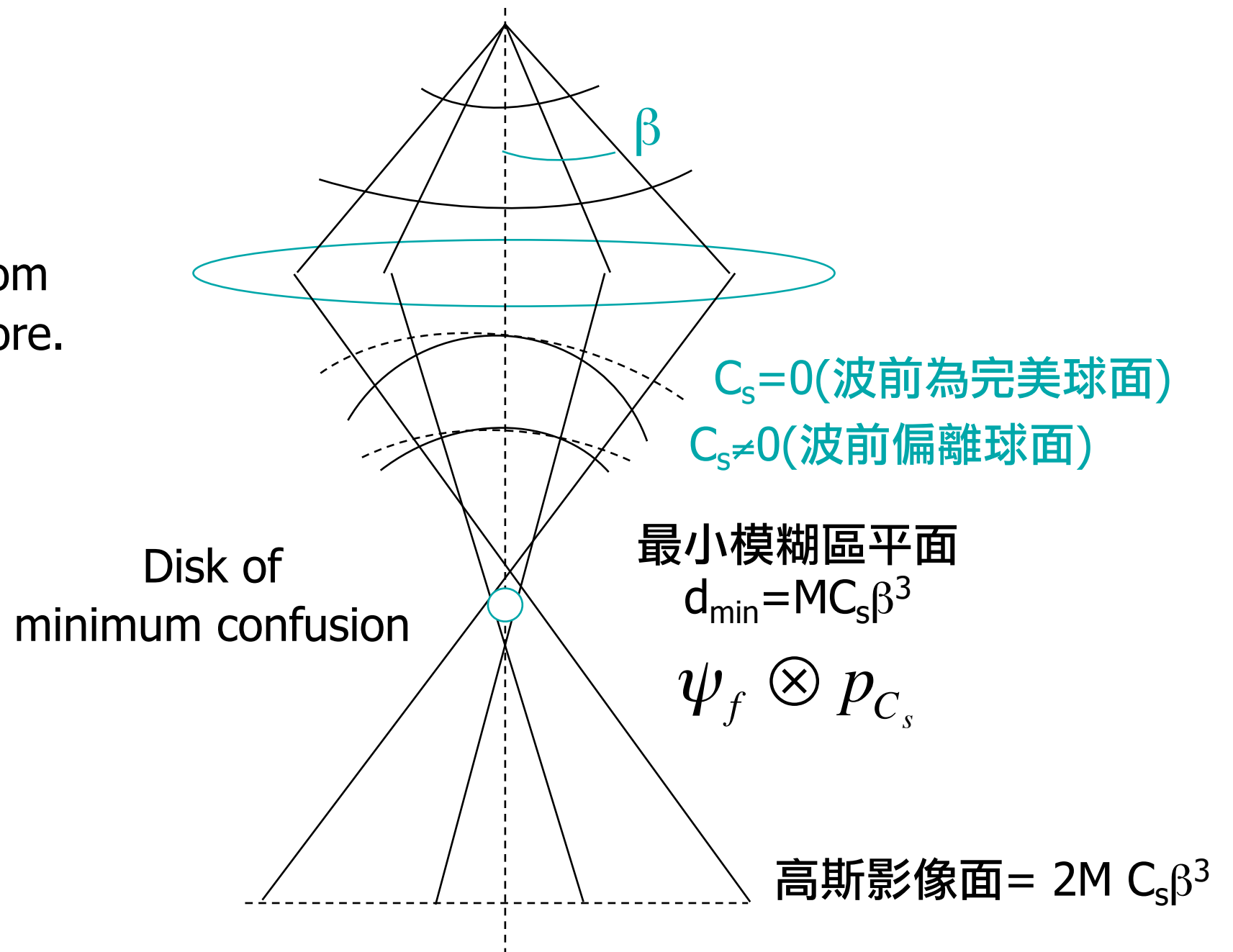
$\Delta f =$ **-16nm** **-32 nm** **-48nm** **-64nm** **-80nm**

Scherzer focus = -48nm

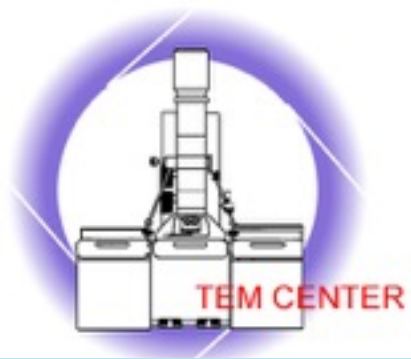


B. Spherical Aberration

1. lens has stronger focus power in the edge
2. electron beam enters from larger angle is refracted more.



- C_s : coefficient of spherical aberration
 $\sim 1\text{mm} \sim 3\text{mm}$
 much larger than the wavelength of electron



$$\psi_f \otimes p_{C_s} = \mathfrak{F}^{-1}[\mathfrak{F}(\psi_f) \cdot P_{C_s}]$$

$$P_{C_s} = \exp(2\pi i \frac{C_s \lambda^3 H^4}{4}) = \exp(2\pi i \frac{C_s \lambda^3 (H_x^2 + H_y^2)^2}{4})$$

The spherical aberration introduces an extra “phase factor in reciprocal space expression. The signal of higher frequency is modified much more. (Change the position of wave peak)

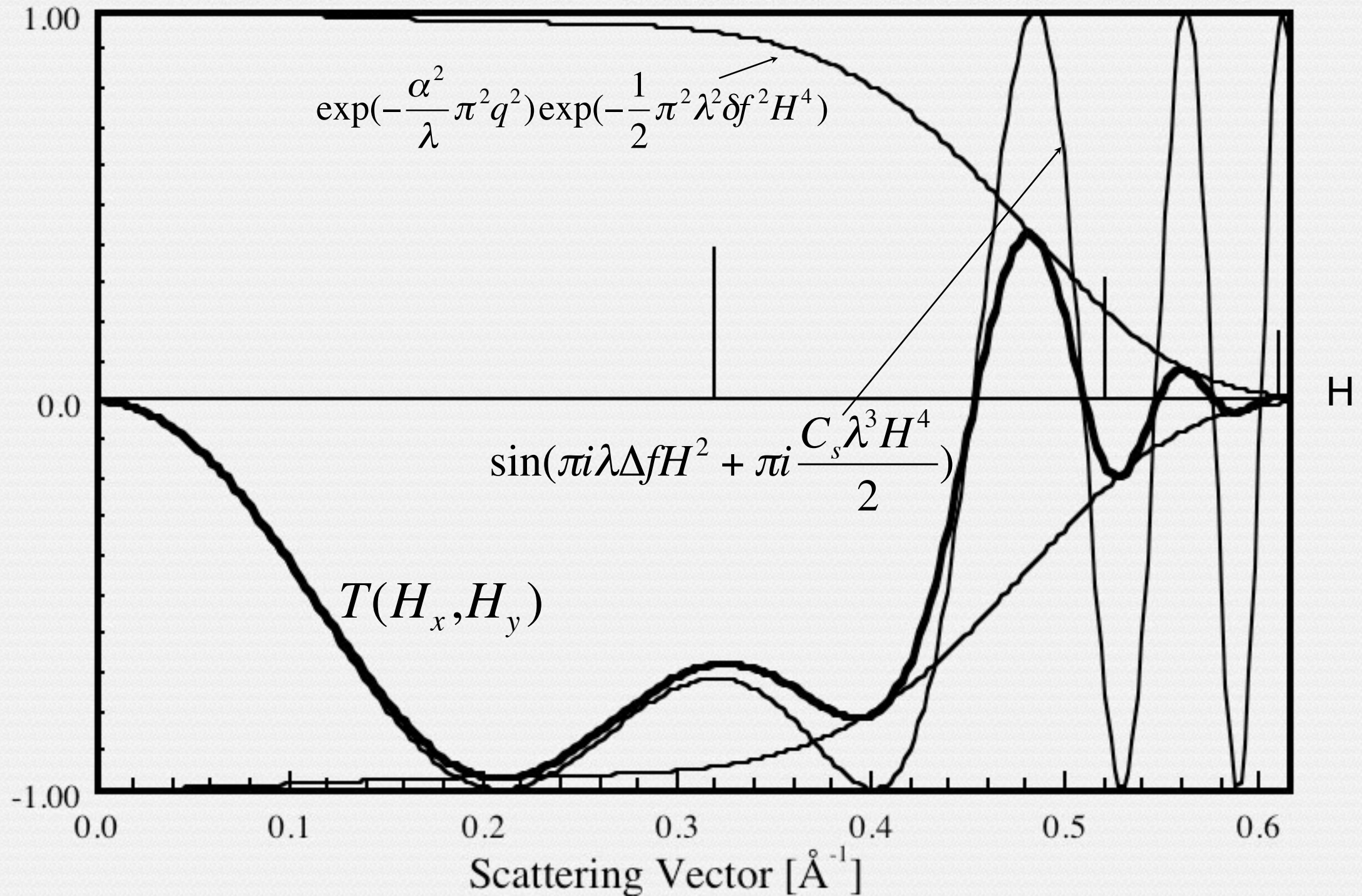
Total Phase Shift from Lens Aberration

$$\chi = \underbrace{\pi i \lambda \Delta f H^2}_{\text{defocus}} + \underbrace{\pi i \frac{C_s \lambda^3 H^4}{2}}_{\text{spherical aberration}}$$



CONTRAST TRANSFER FUNCTION

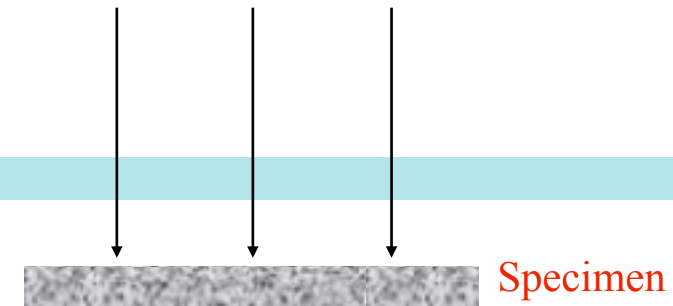
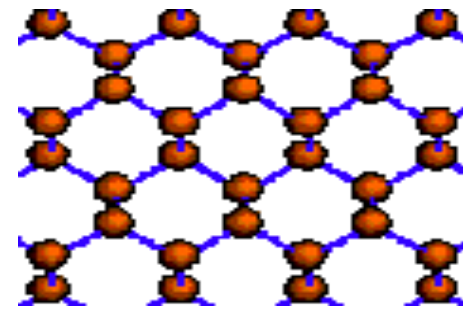
$V = 200.0 \text{ kV}$ $C_s = 0.9 \text{ mm}$ $\text{Def} = -580.00 \text{ \AA}$ $\Delta f = 50.00 \text{ \AA}$ $\text{Div} = 0.55 \text{ mrad}$





Transfer Function of Aberrated Lens

NTHU



$$\psi_e = A \exp[-i(\varphi)]$$

$$\Psi_g = F(\Psi_e) \exp(i\chi) P(H)$$

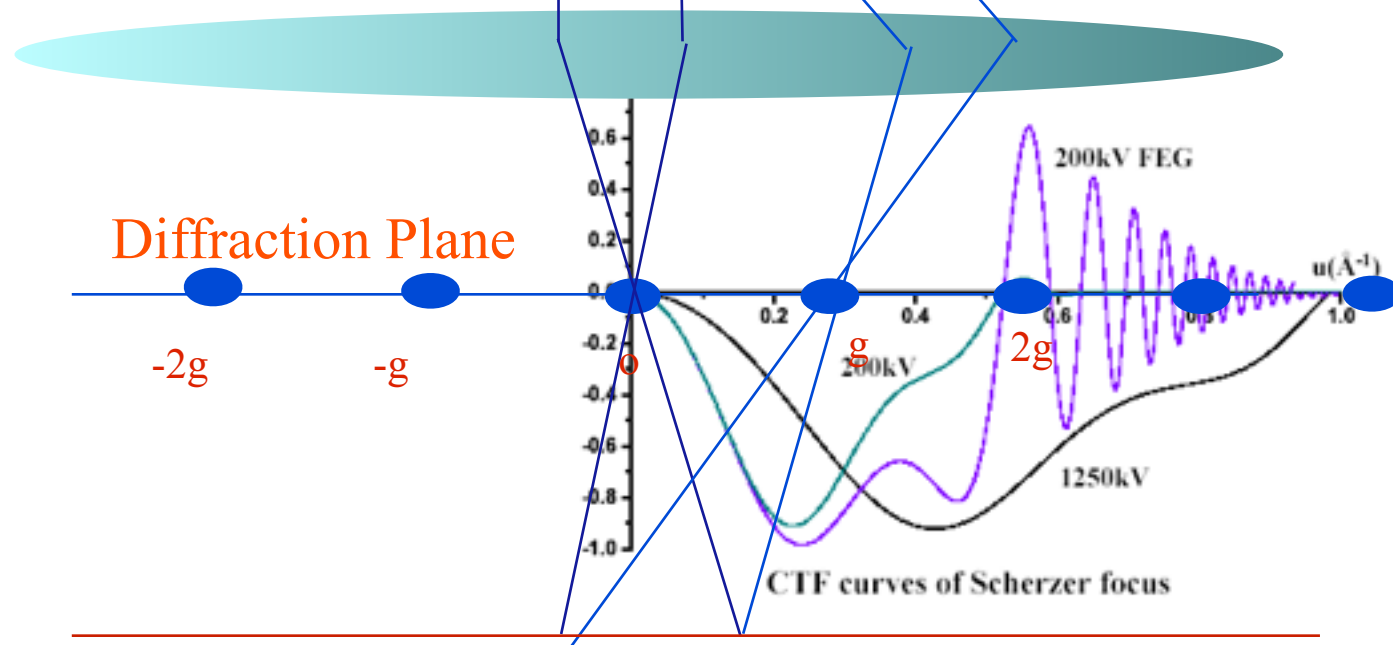
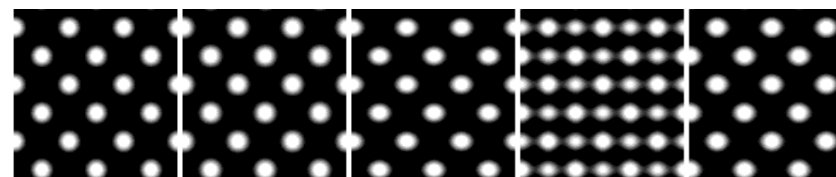


Image Plane

$$\psi_i \psi_i^* = I$$

$$\psi_i = \psi_e \otimes \mathfrak{S}^{-1} \exp(i\chi) P(H)$$

(phase lost)



Δf

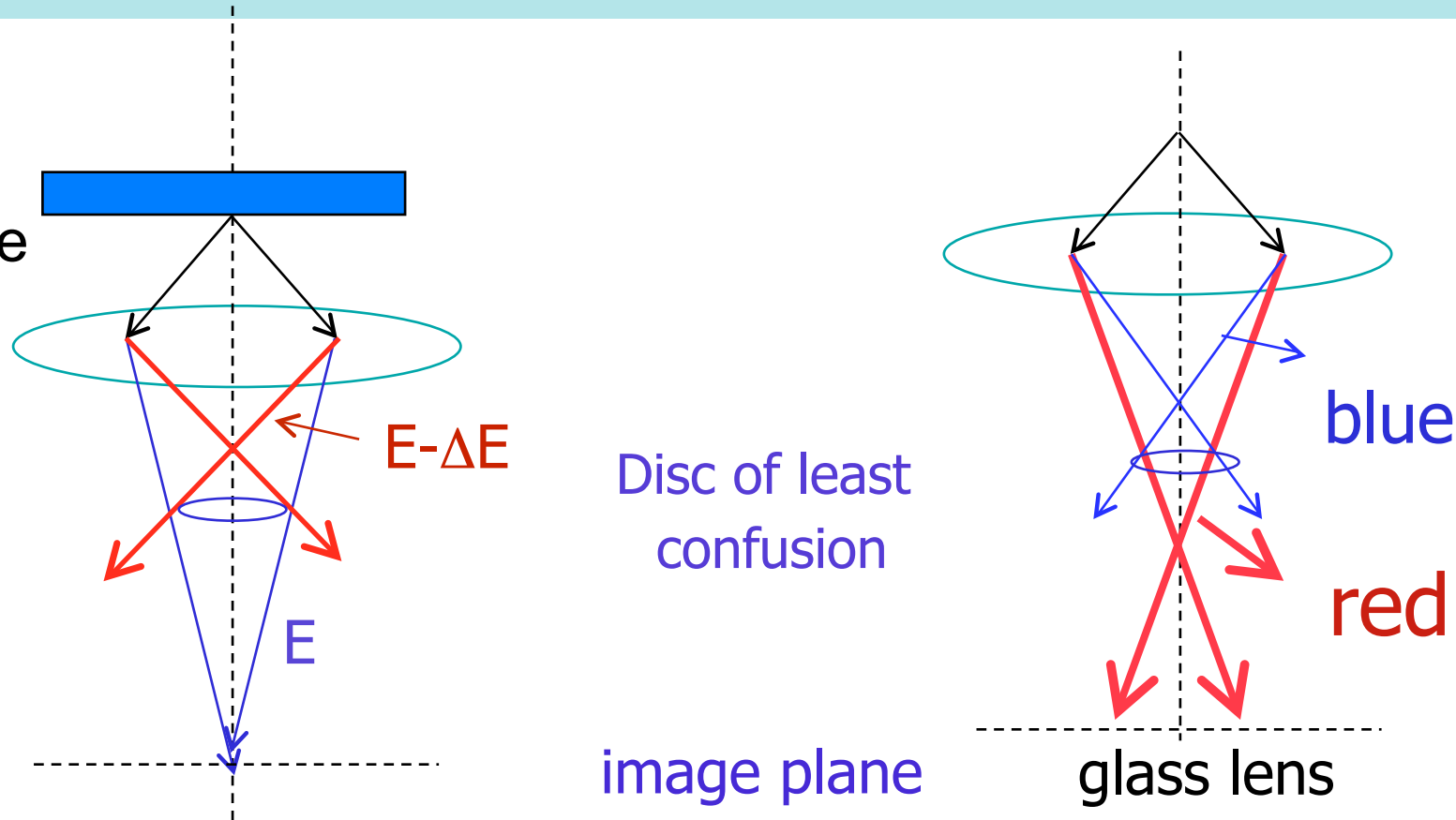


C. Chromatic Aberration

instability of the lens current

$$\frac{\delta i}{i}$$

electro-magnetic lens



$$\Gamma_{chr} = C_c \frac{\Delta E}{E_o} \beta$$

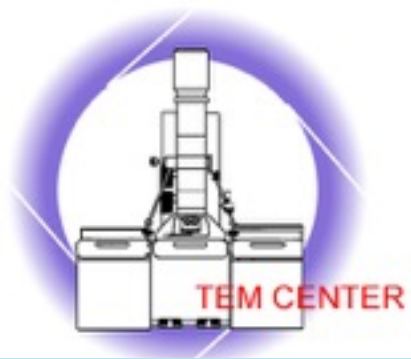
$$C_c = 1mm \sim 3mm$$

Lower energy electron is easier to be focused

Higher energy electron is more difficult to be focused

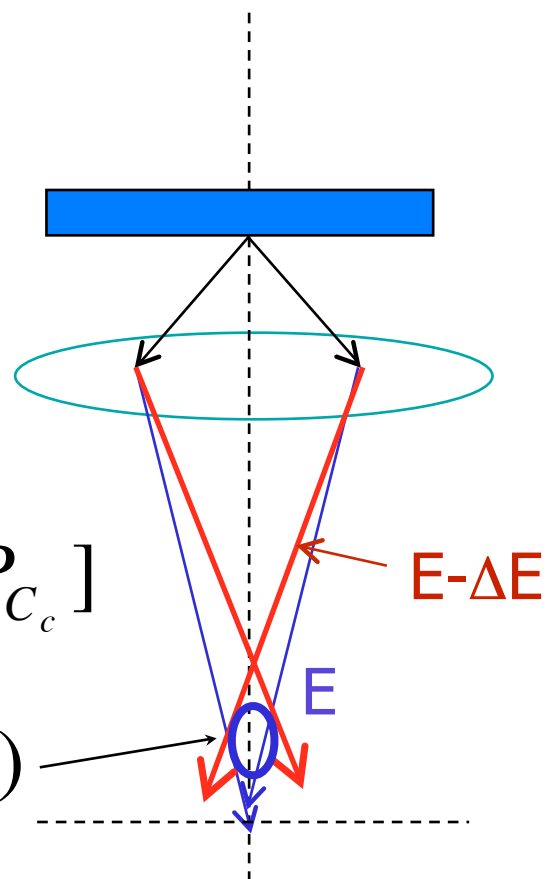
$$\frac{\delta f}{f} = \frac{\delta V}{V} + \frac{\delta i}{i}$$

focal spread instability of applied voltage instability of lens current



$$\delta f = C_c \left\{ \left(\frac{\delta V}{V} \right)^2 + 4 \left(\frac{\delta i}{i} \right)^2 \right\}^{1/2}$$

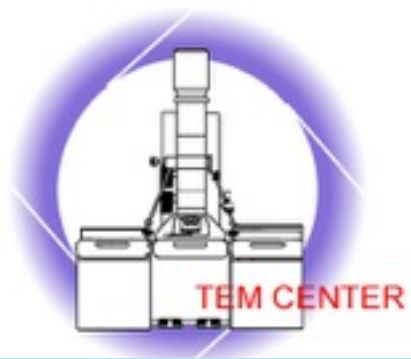
Since the energy of electrons is different in the image plane, they do not coherently interfere each other. i.e. As a result, they do not cause a shift shift as the “spherical aberration” and “de-focus” effect, instead they damping down the amplitude of the image wave.



The signal of high frequency damps more than the lower frequency part.

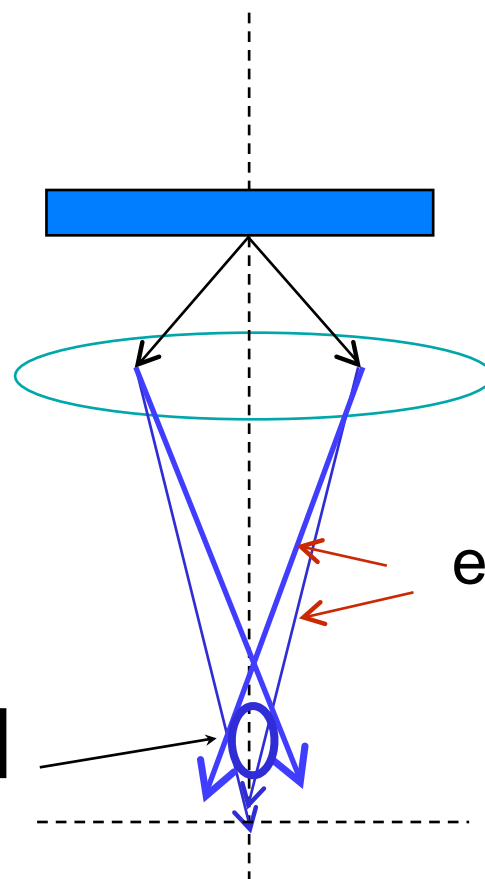
$$\psi_f \otimes p_{C_c} = \mathfrak{F}^{-1} [\mathfrak{F}(\psi_f) \cdot P_{C_c}]$$

$$P_{C_c} = \exp\left(-\frac{1}{2} \pi^2 \lambda^2 \delta f^2 H^4\right)$$



D. Spatial Coherency

Since the electrons do not coherently interfere each other. i.e. As a result, they do not cause a phase shift as the “spherical aberration” and “de-focus” effect, instead they damping down the amplitude of the image wave.



electrons of different divergent angle

$$\psi_f \otimes p_C = \mathfrak{S}^{-1}[\mathfrak{S}(\psi_f) \cdot P_C]$$

$$P_C = \exp\left(-\frac{\alpha^2}{\lambda} \pi^2 q^2\right), \text{ where } q = (\pi\lambda\Delta fH + \pi C_s \lambda^3 H^3)$$



(lens contrast transfer function)

$$T(H) = \exp(i\pi\lambda\Delta f H^2) \exp(i(\pi/2)C_s\lambda^3 H^4) \exp(-\pi^2\Delta^2\lambda^2 H^2/2) \exp(-\pi^2(\alpha/\lambda)^2 q/\ln(2))$$

$\exp(i\chi(H))$

defocus

phase shift

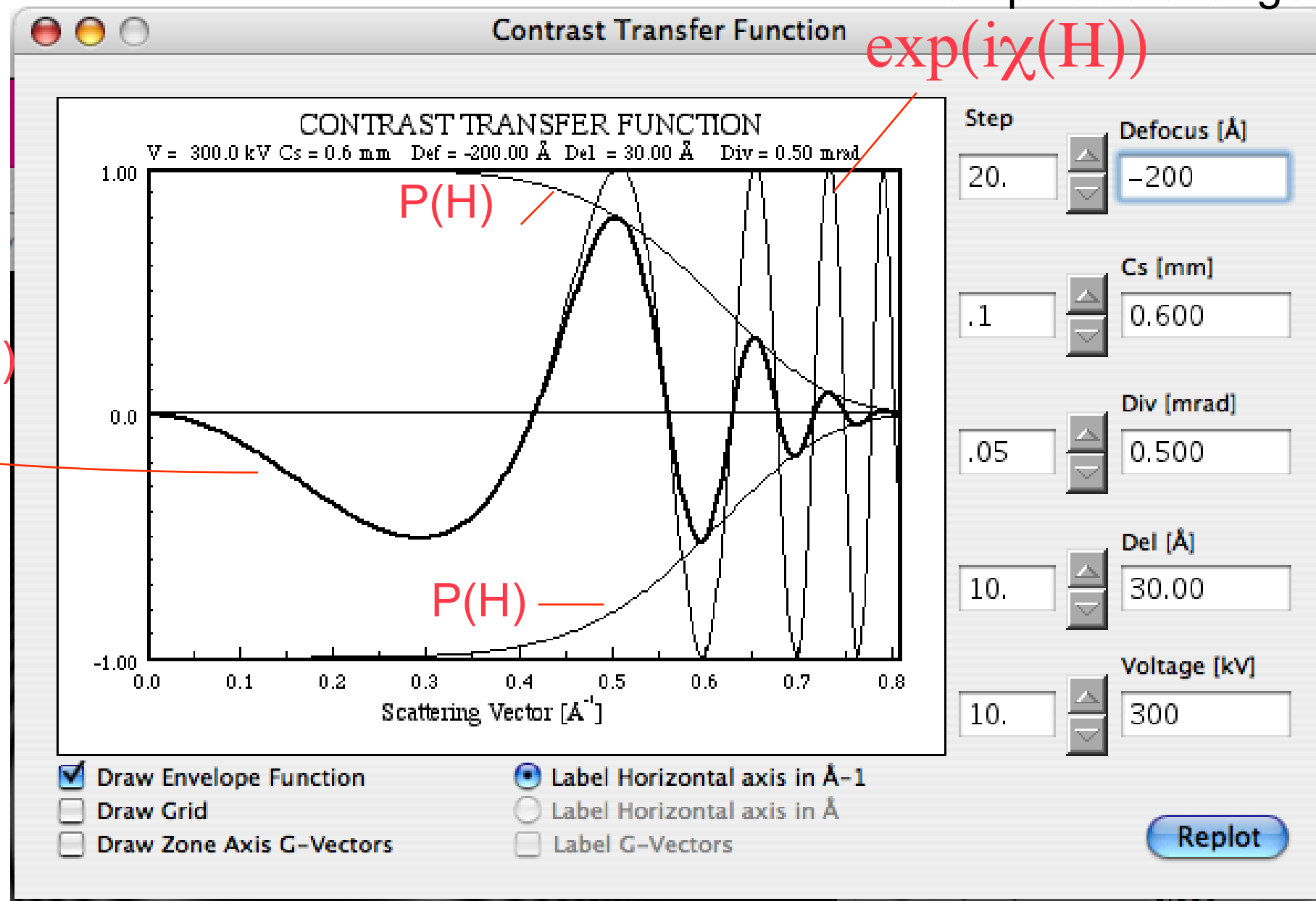
spherical
aberration

chromatic
aberration

spatial
coherency

amplitude change

$P(H)$



$\exp(i\chi(H))$

$\exp(i\chi(H))P(H)$

$P(H)$

Draw Envelope Function

Draw Grid

Draw Zone Axis G-Vectors

Label Horizontal axis in \AA^{-1}

Label Horizontal axis in \AA

Label G-Vectors

Replot



Optimum Focus and Minimum Contrast Focus

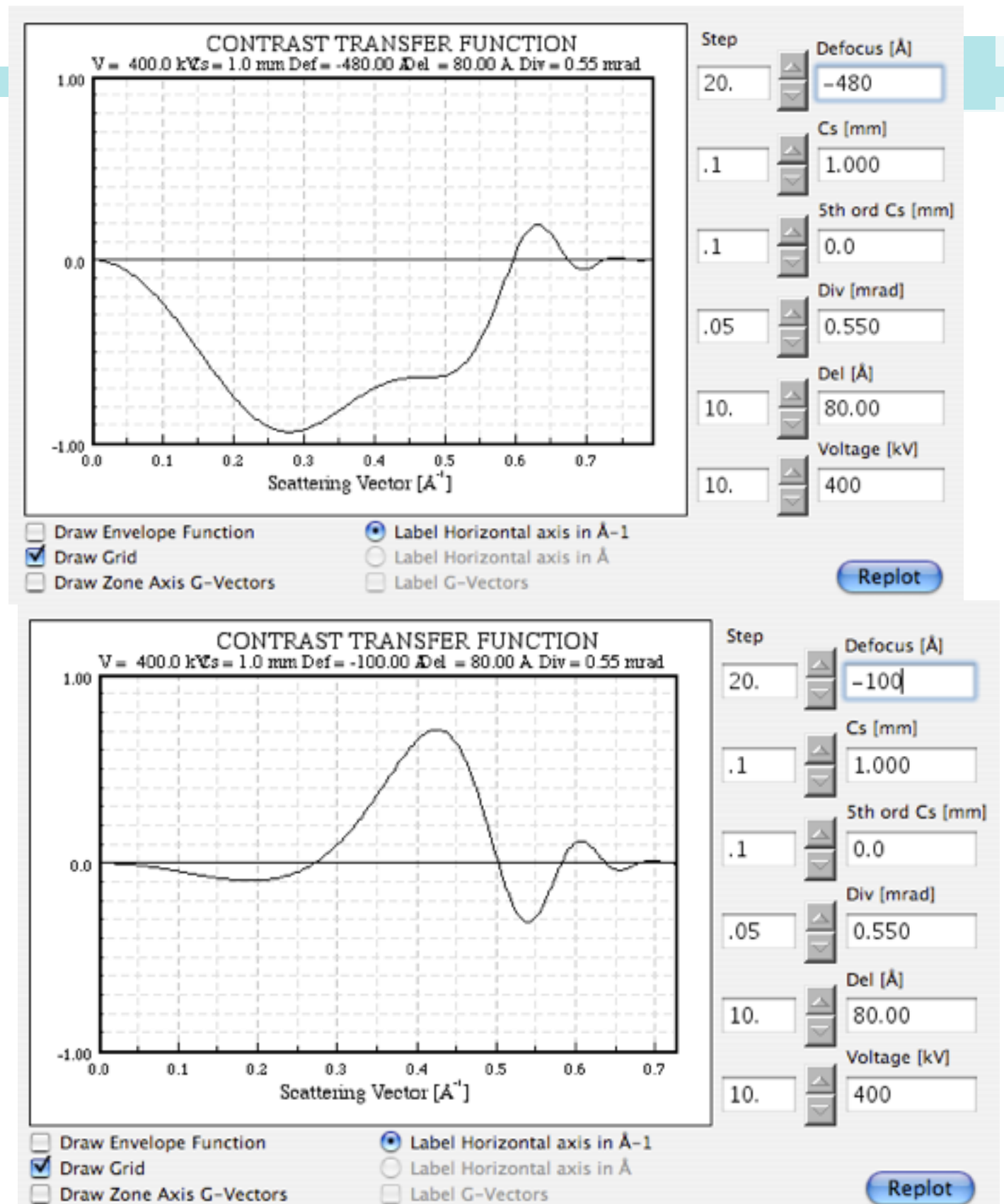
Optimum Focus: The focus value to make largest plateau in CTF

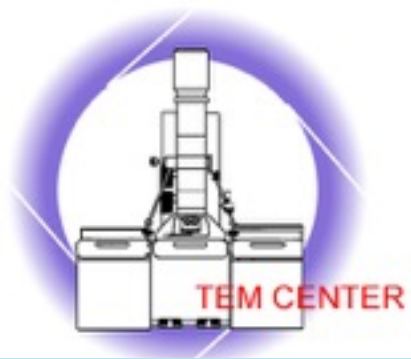
Scherzer focus
 $\text{value} = -1.22(C_s\lambda)^{1/2}$

Minimum Contrast Focus:
 (Gaussian focus)

The focus value to make largest plateau=0 in CTF

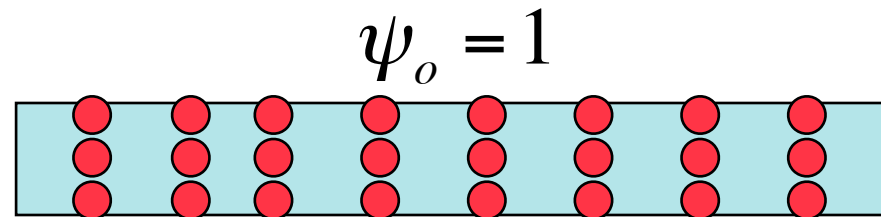
Gaussian focus
 $\text{value} = -0.3(C_s\lambda)^{1/2}$





Weak Phase Object

Assuming the object is a weak phase object



$$\psi_e = \exp(i\varphi(x,y))$$

$$= 1 + i\varphi(x,y)$$

Only the phase change involved
Amplitude does not change



$$\mathfrak{S}(\psi_e) = \delta + i\mathfrak{S}[\varphi(x,y)]$$

B.F.P.

$$\mathfrak{S}(\psi_e) \cdot T(H)$$

$$T(H_x, H_y) = \exp(\pi i \lambda \Delta f H^2) \exp(\pi i \frac{C_s \lambda^3 H^4}{2}) \exp(-\frac{\alpha^2}{\lambda} \pi^2 q^2) \exp(-\frac{1}{2} \pi^2 \lambda^2 \delta f^2 H^4)$$

defocus
spherical aberration
spatial coherency
chromatic aberration

$$\mathfrak{S}^{-1}[\mathfrak{S}(\psi_e) \cdot T(H)] = \psi_e \otimes t(r)$$



In diffraction Plane

$$\begin{aligned} \mathfrak{T}(\psi_e) \cdot T(H) &= \{\delta + i\mathfrak{T}[\varphi(x,y)]\} \{\exp(i\chi(H))\} P(H) \\ &= \{\delta + i\mathfrak{T}[\varphi(x,y)]\} \{\cos(\chi(H)) + i\sin(\chi(H))\} P(H) \\ &= \{\delta + 0 + i\mathfrak{T}[\varphi(x,y)]\cos(\chi(H)) - \mathfrak{T}[\varphi(x,y)]\sin(\chi(H))\} P(H) \end{aligned}$$

In Image Plane

$$\psi_i = \mathfrak{T}[\mathfrak{T}(\psi_e) \cdot T(H)] = \left\{ 1 - \varphi\left(\frac{-x}{M}, \frac{-y}{M}\right) \otimes \mathfrak{T}(\sin(\chi(H))) + i\varphi\left(\frac{-x}{M}, \frac{-y}{M}\right) \otimes \mathfrak{T}(\cos(\chi(H))) \right\} \otimes P(H)$$

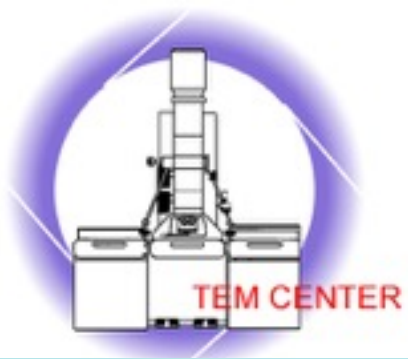
$$I = \psi_f \psi_f^*$$

$$= \left\{ 1 - \varphi\left(\frac{-x}{M}, \frac{-y}{M}\right) \otimes \mathfrak{T}(\sin(\chi(H))) \right\}^2 \otimes P^2(H) + \left\{ [i\varphi\left(\frac{-x}{M}, \frac{-y}{M}\right) \otimes \mathfrak{T}(\cos(\chi(H)))]^2 \otimes P^2(H) \right\}$$

if we neglect the second order terms

$$\sim 1 - 2\varphi\left(\frac{-x}{M}, \frac{-y}{M}\right) \otimes \mathfrak{T}(\sin(\chi(H))) \otimes P^2(H)$$

This is so called phase contrast



Two Resolutions: How to Improve Resolution

NTHU

$$d = \frac{\lambda}{2n \sin \alpha}$$

幾何光學
分辨率

Scherzer Resolution
Point-point resolution

$$d = 0.66 C_s^{1/4} \lambda^{3/4}$$

$C_s \downarrow$

$\lambda \downarrow$

(high voltage TEM
Cs corrected TEM)

Information limit

$C_c \downarrow$

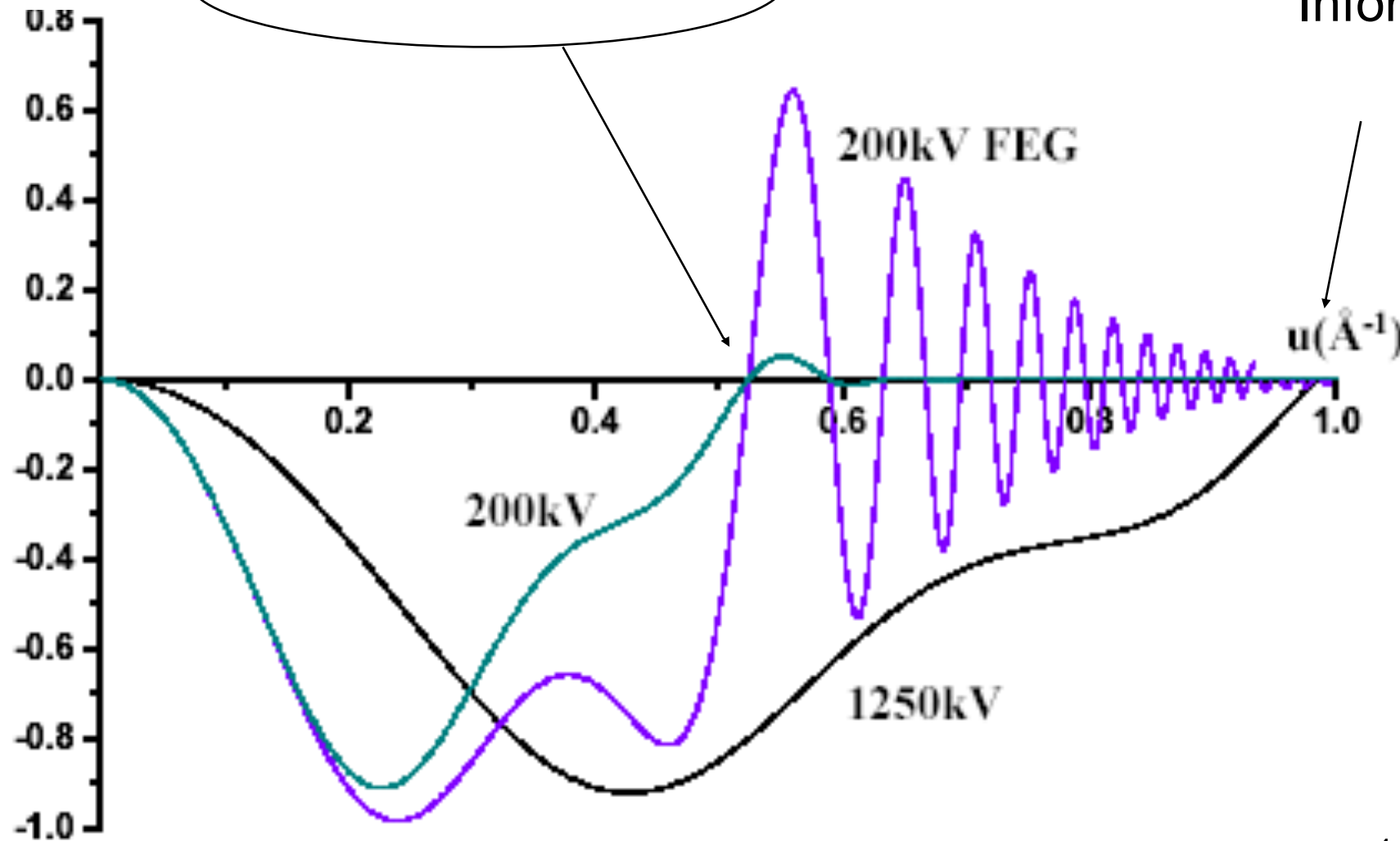
$\alpha \downarrow$

Coherency
(FEG Gun

Monochromator

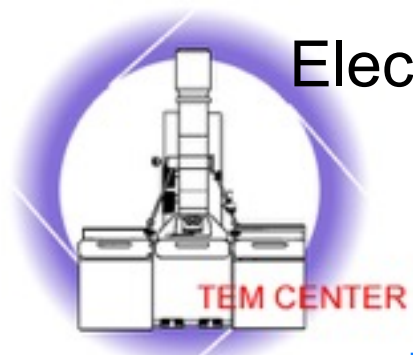
C_c corrector

C_s corrector)



CTF curves of Scherzer focus $= -1.22(C_s \lambda)^{1/2}$

CTF有很寬之通帶



Electron wave

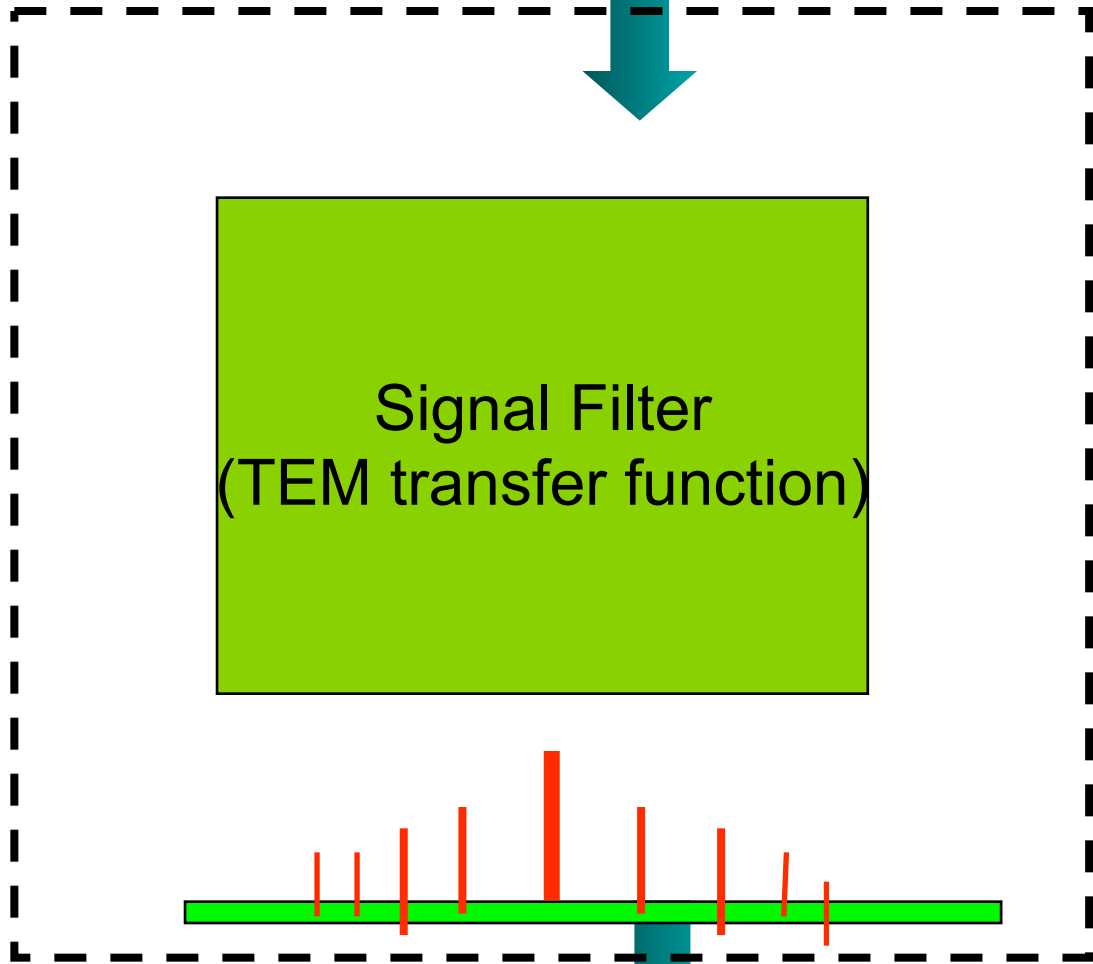


Objective lens acts as a signal filter

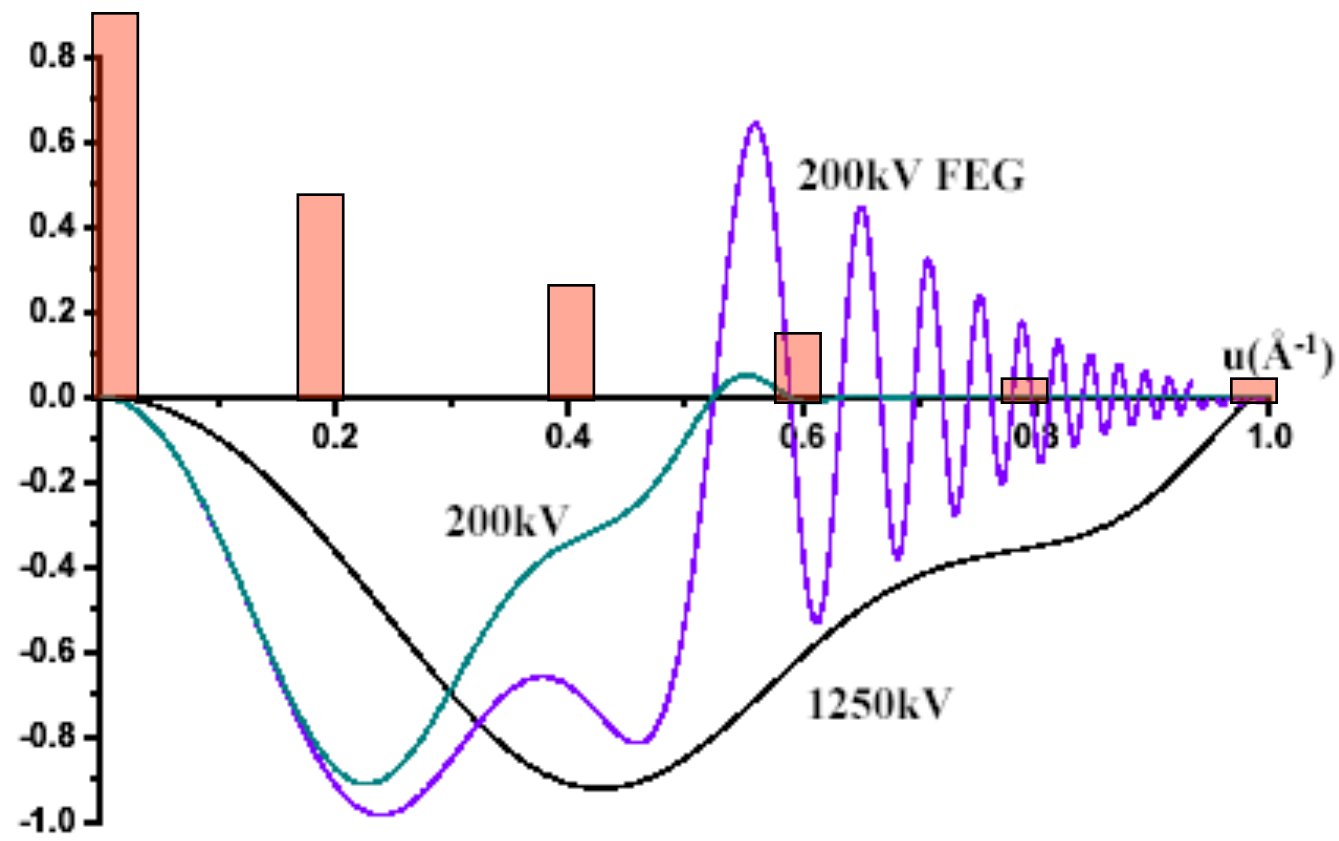
Specimen (Object)

Electrons interact with atoms
Pick up structure information

NTHU



Diffraction plane



CTF curves of Scherzer focus

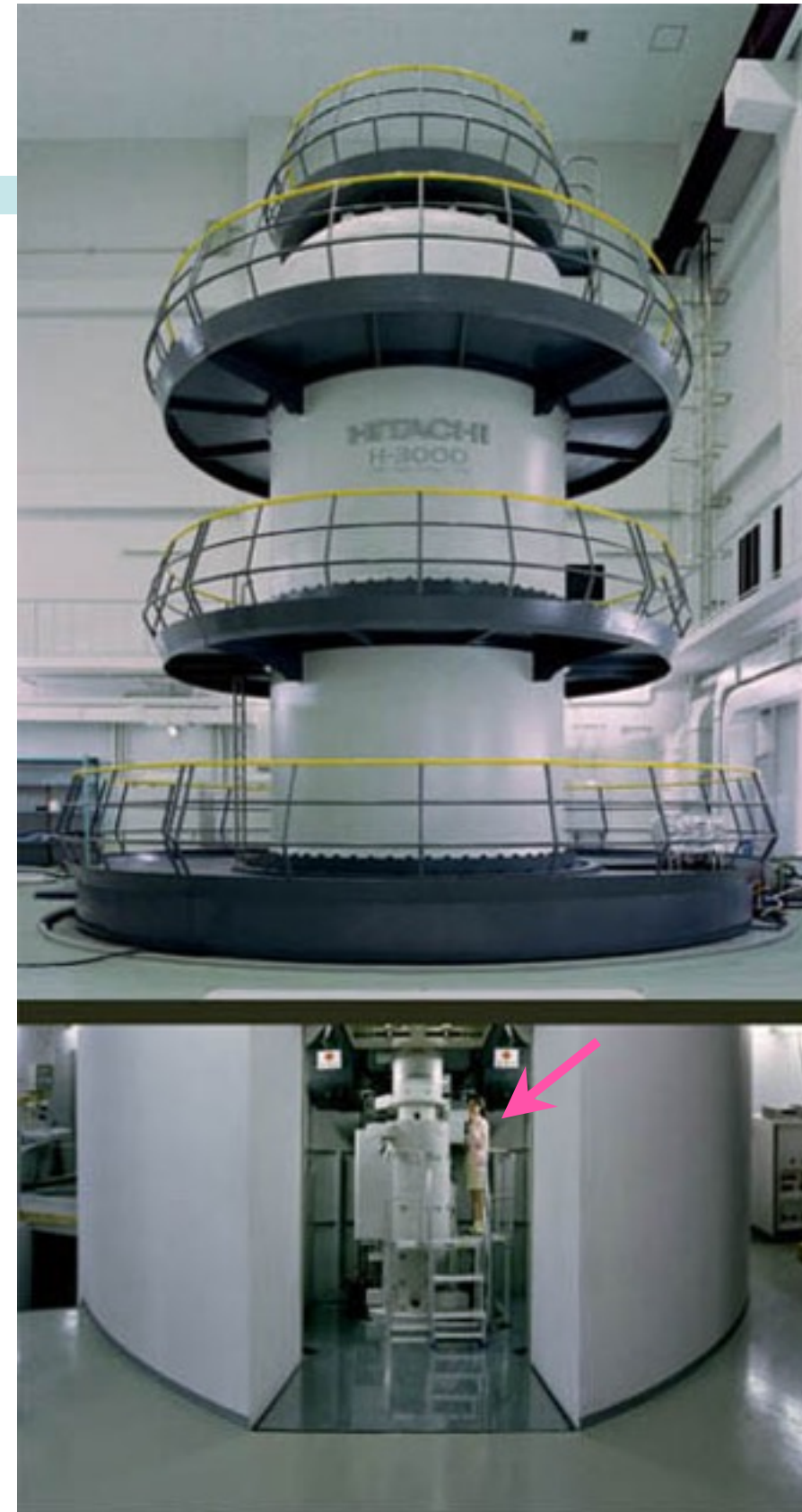


Recorded image (Observer)

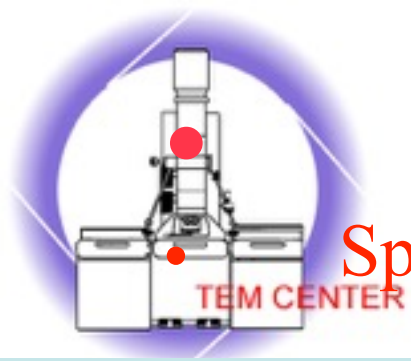


Using Ultra-High Voltage TEM

- **1. Electron Wave Length**
 - Decreasing the electron wavelength
 - Develop **ultra higher accelerating voltage** up to 1MeV ~ 0.1 nm
- **2. Coherence of electron wave**
 - Using a field emission gun (FEG), the temporal incoherence can be reduce, information limit extend to 0.1nm



Osaka University, Japan



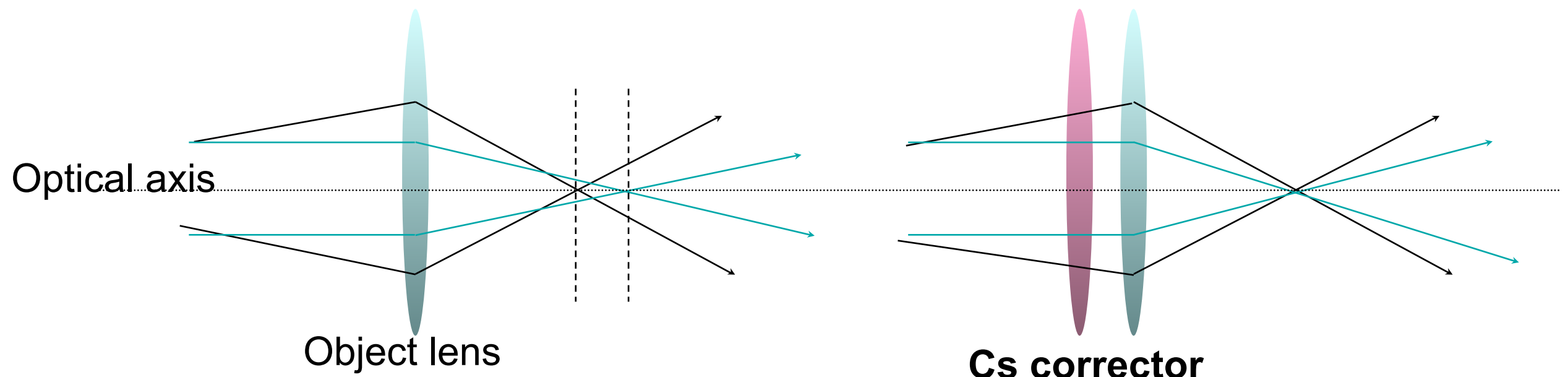
Lens Aberration Correction

Spherical aberration C_s , Chromatical aberration C_c Astigmatism etc.

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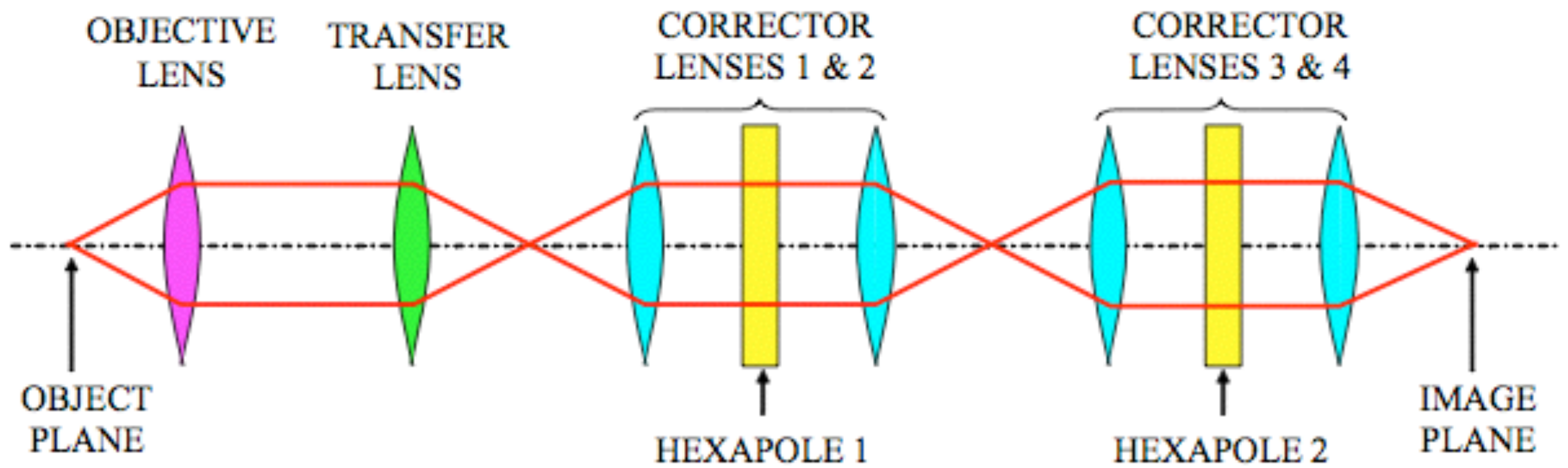
- Simplest, a better lens design yielding lower spherical aberration at intermediate voltages
 - ~ 0.17 nm is reached at 300kV
- Develop **Cs corrector** in intermediate voltages
 - ~ 0.1 nm
- Develop **Monochromator** in intermediate voltage

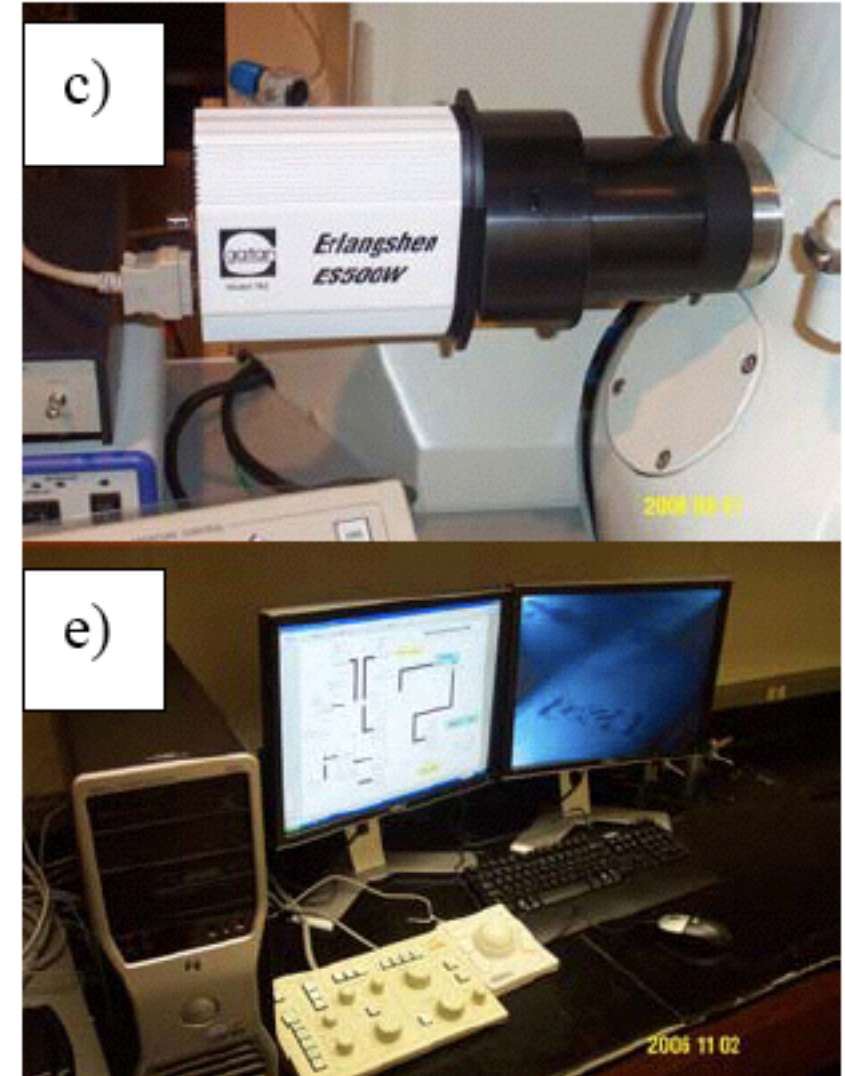
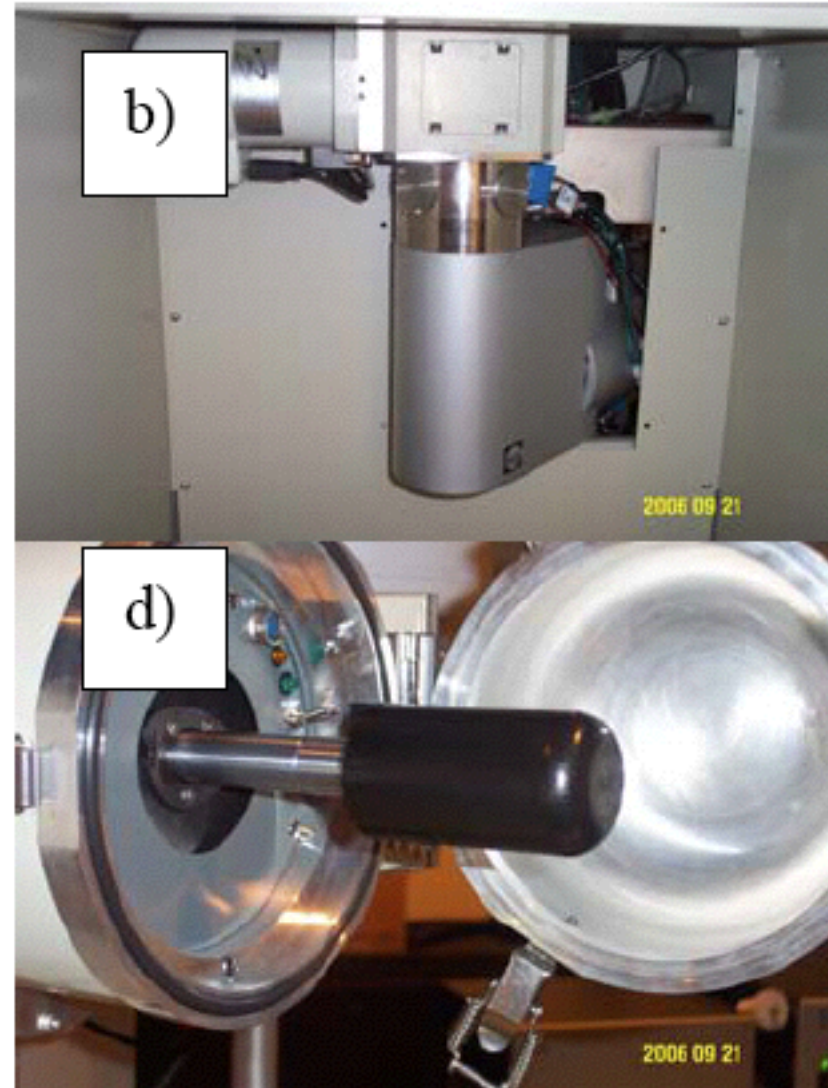
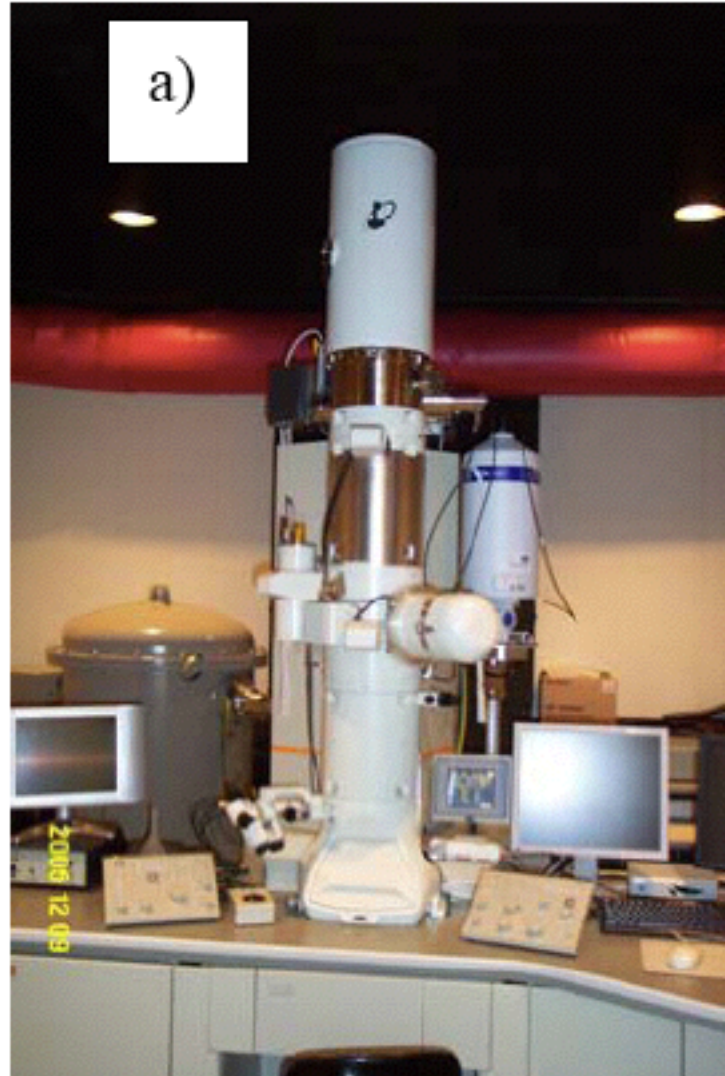
Spherical aberration C_s

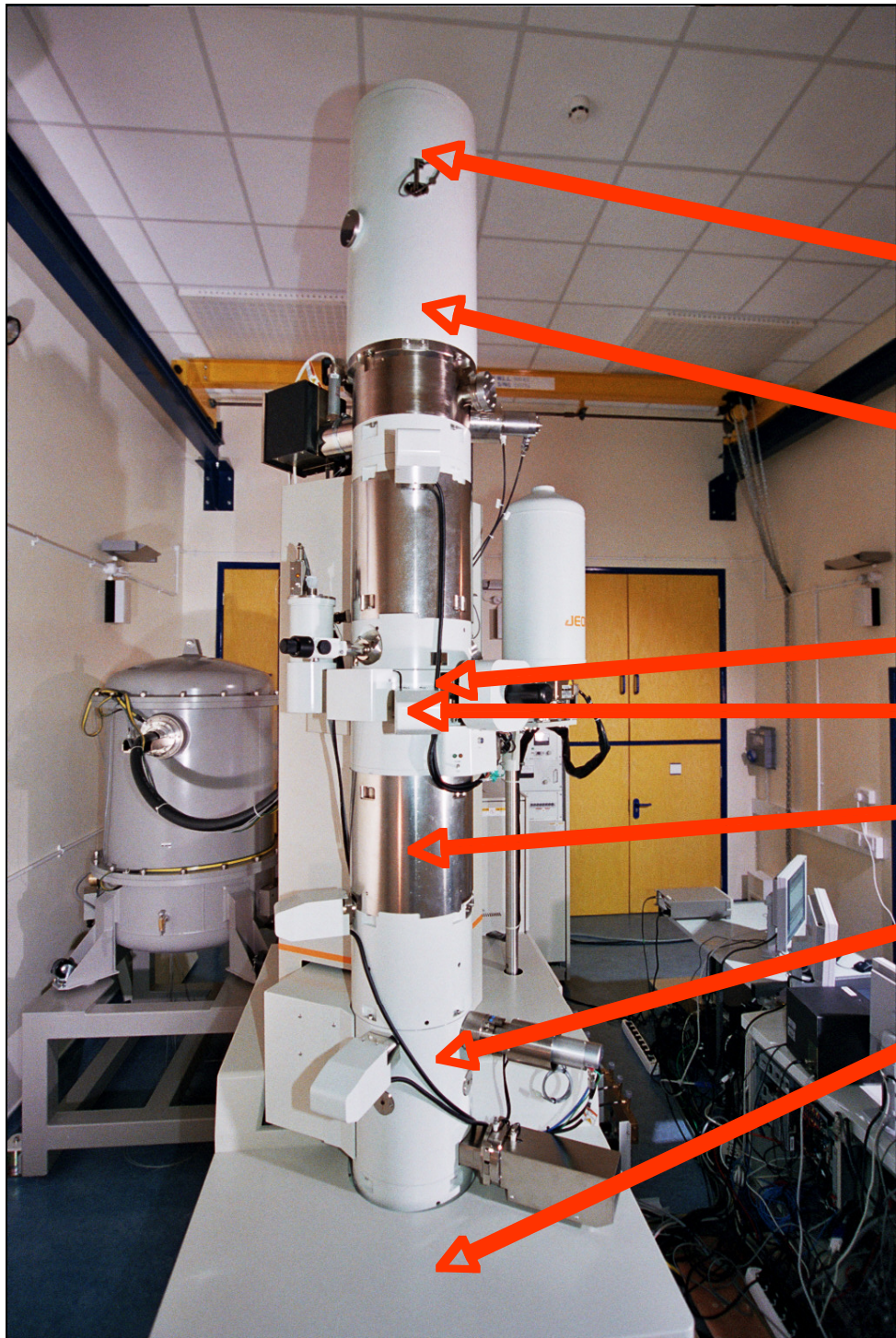


Hardware Correctors

- Probe forming corrector
- Objective Lens Corrector







HREM - initial JEOL 2200FS

FEG

200kV HT

X-Y piezo stage

URP polepiece

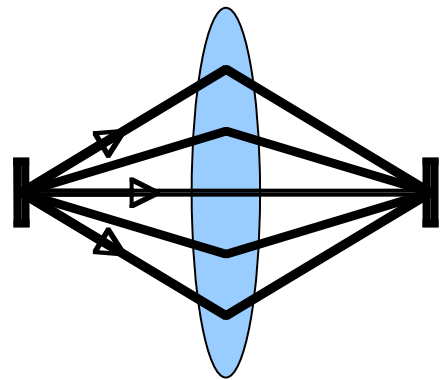
CEOS TEM corrector

Omega filter

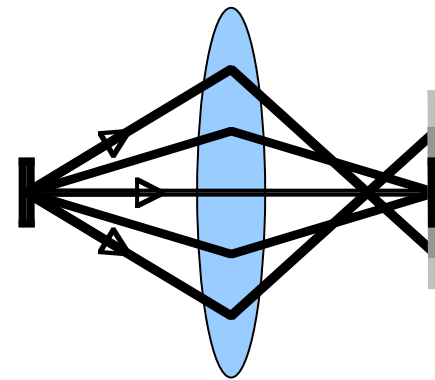
2k x 2k camera

purpose-built room

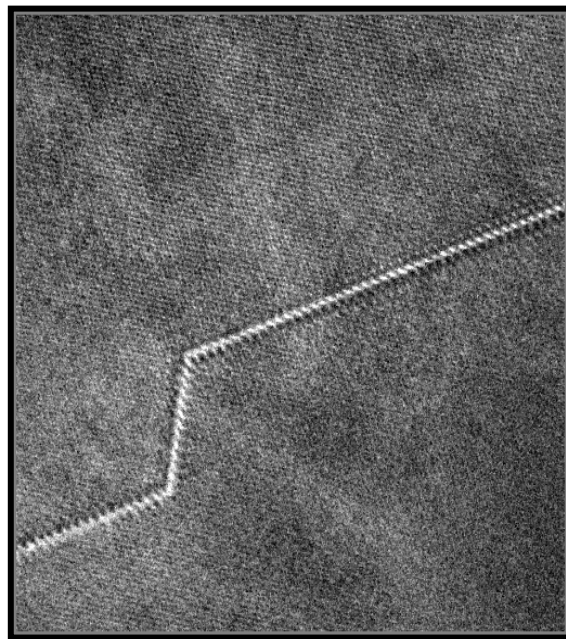
delocalisation



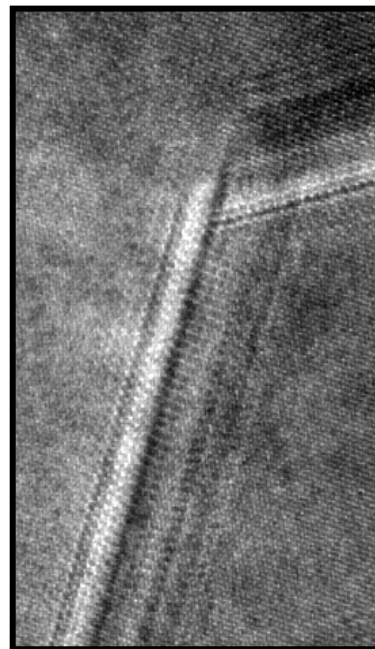
(a)



(b)



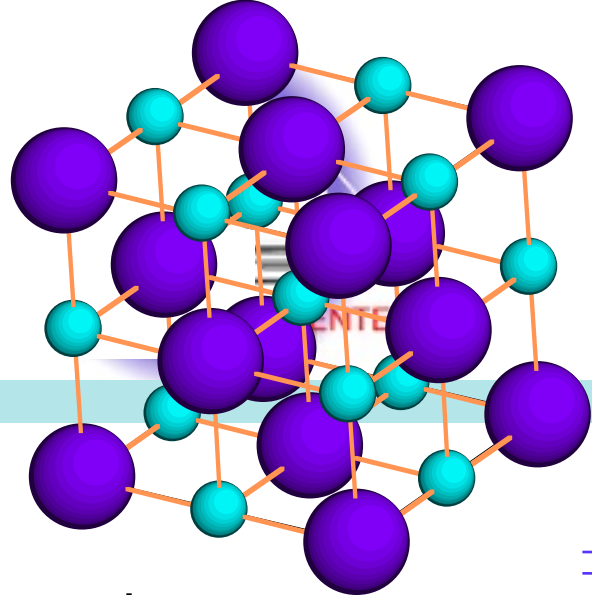
zero Cs



with Cs

twin boundary in gold
111 zone
0.144nm fringes
(200kV)

Determination of Atomic Structure



Electrons ψ_0

Specimen

Dynamical Scattering

Lens Aberration
($C_s, C_c, \Delta f$)

$-2g$

$-g$

0

g

$2g$

Δf Image Plane

refine
structural
model

Guessing a structural model

MultiSlice Simulation
(Exit Wave)

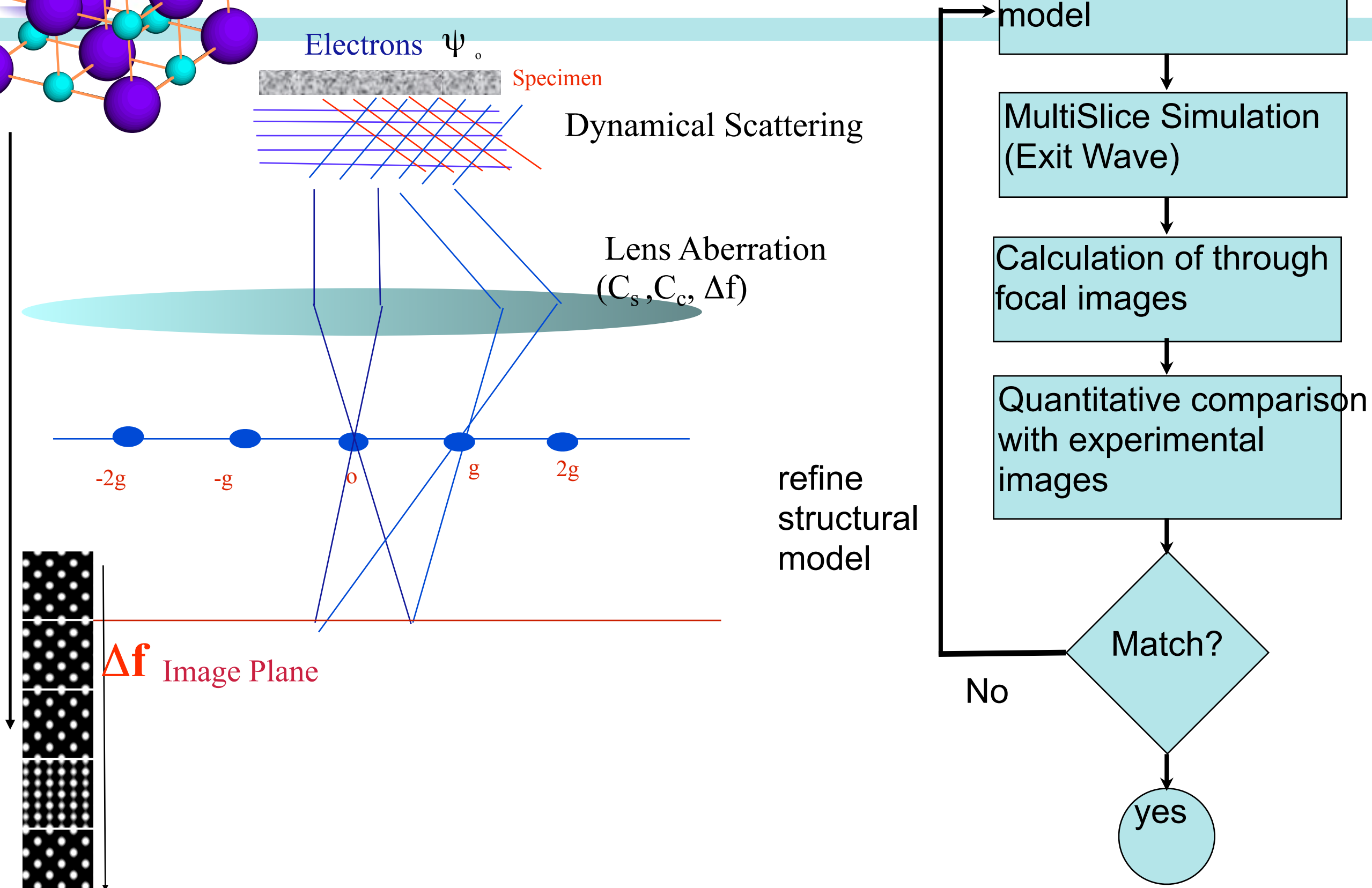
Calculation of through
focal images

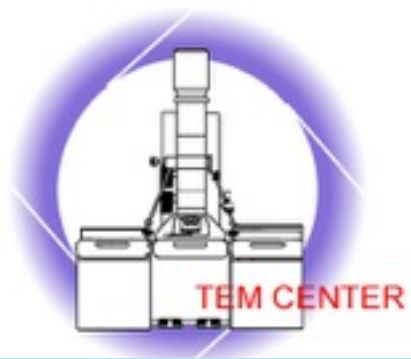
Quantitative comparison
with experimental
images

Match?

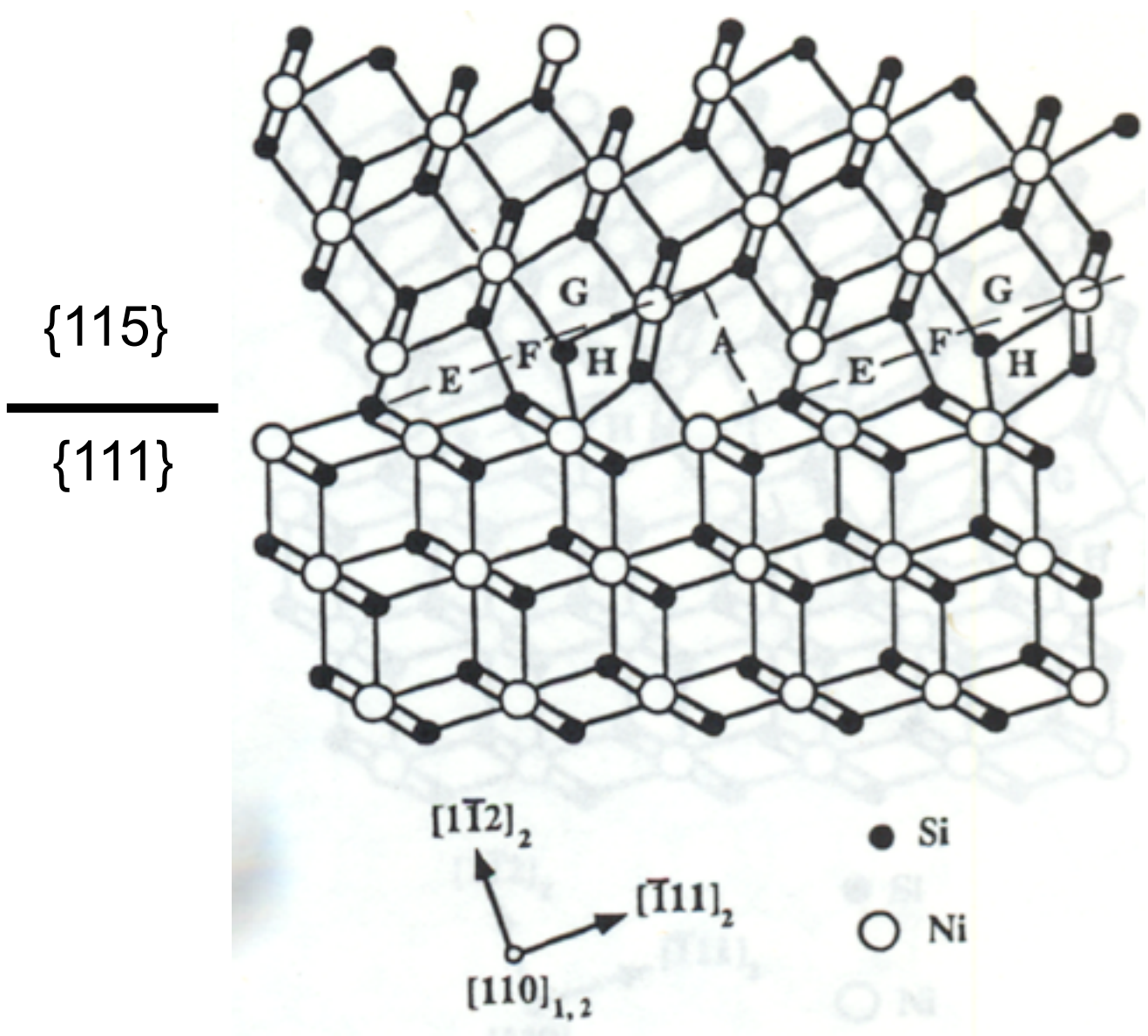
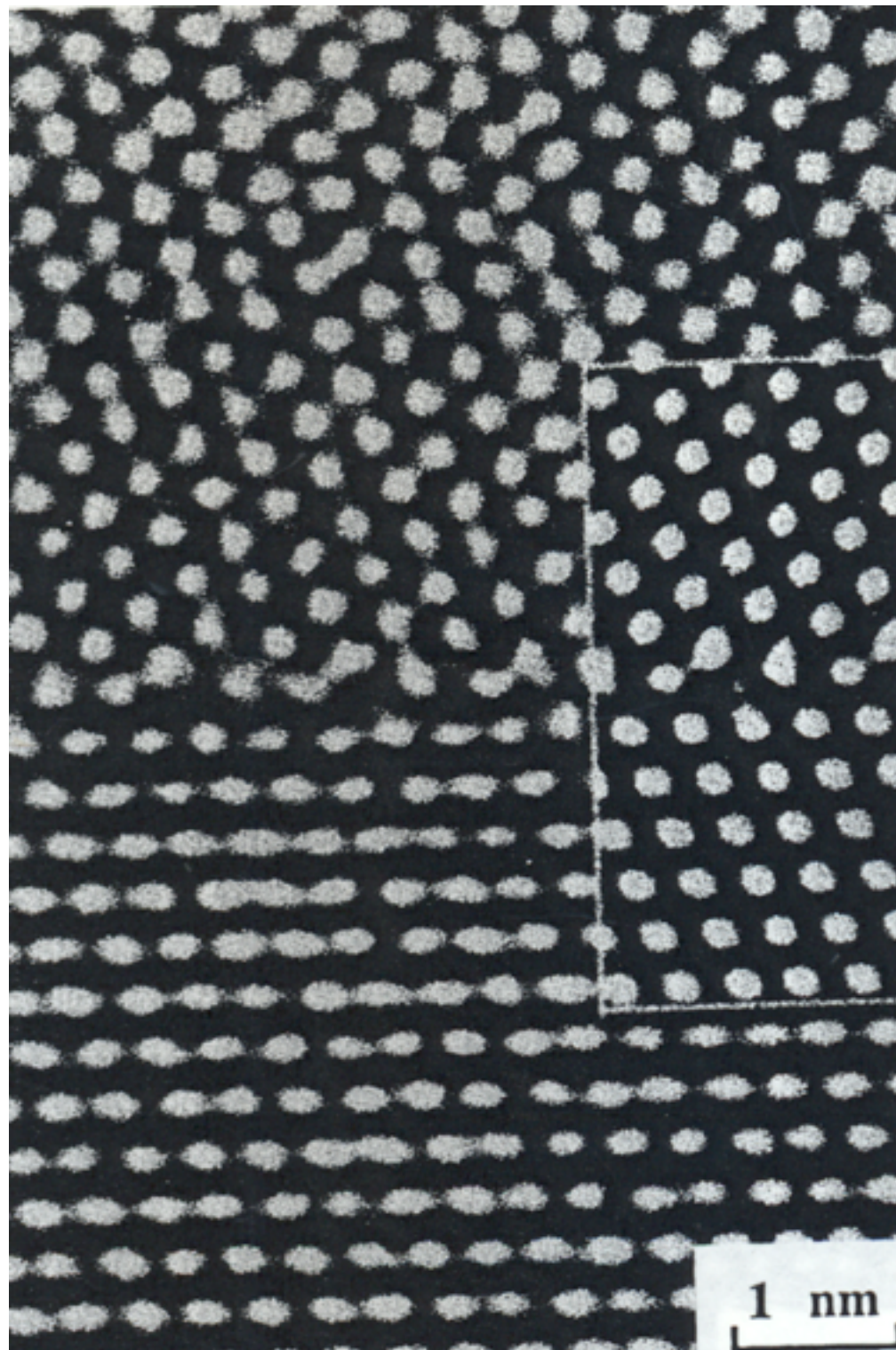
No

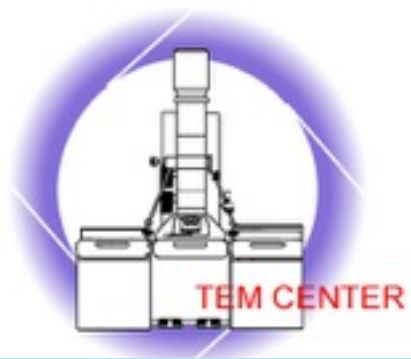
yes



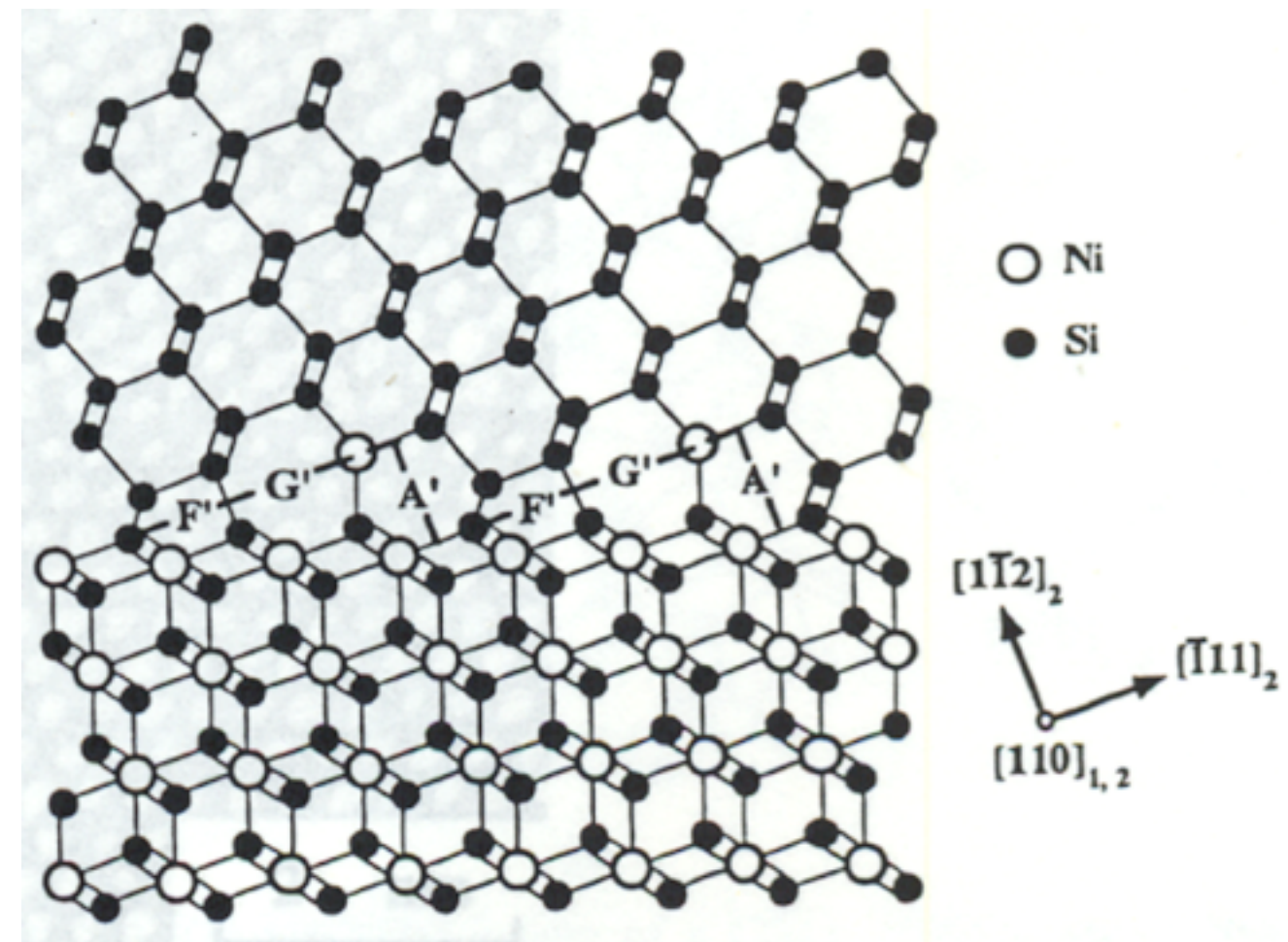
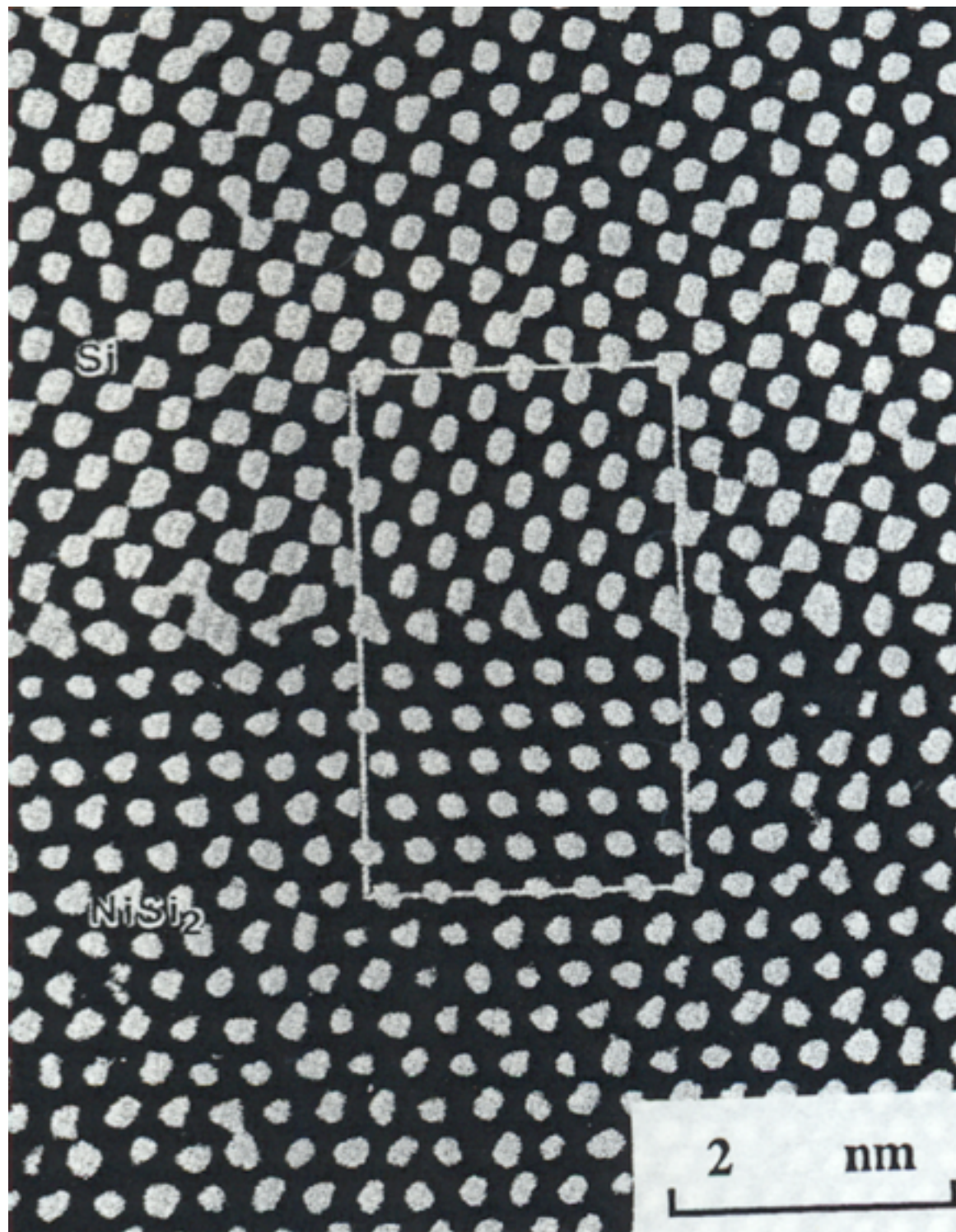


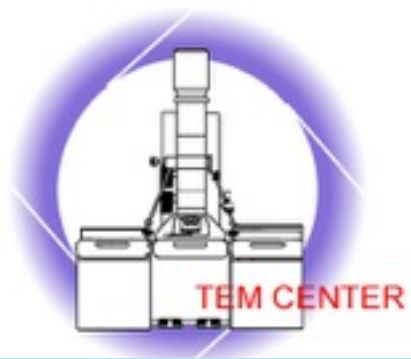
Example: NiSi₂ {115}/{111} Twin Boundary



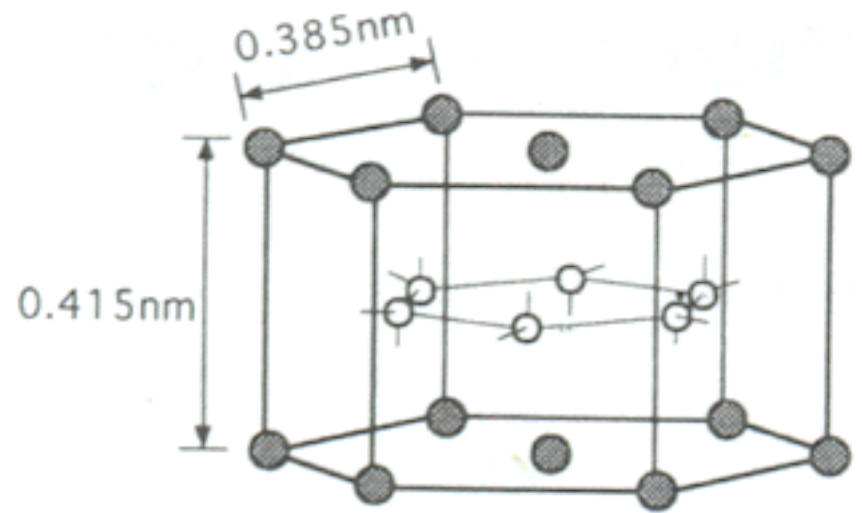


Example: Si{115}/ NiSi₂{111} Twin Boundary

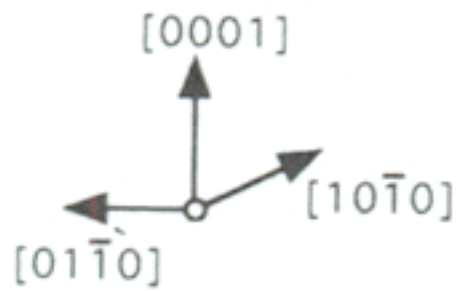




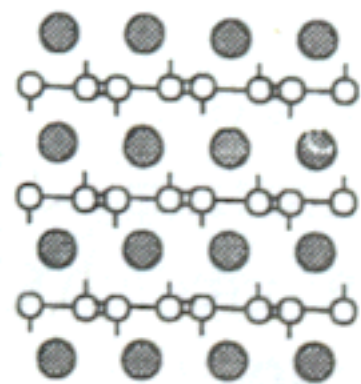
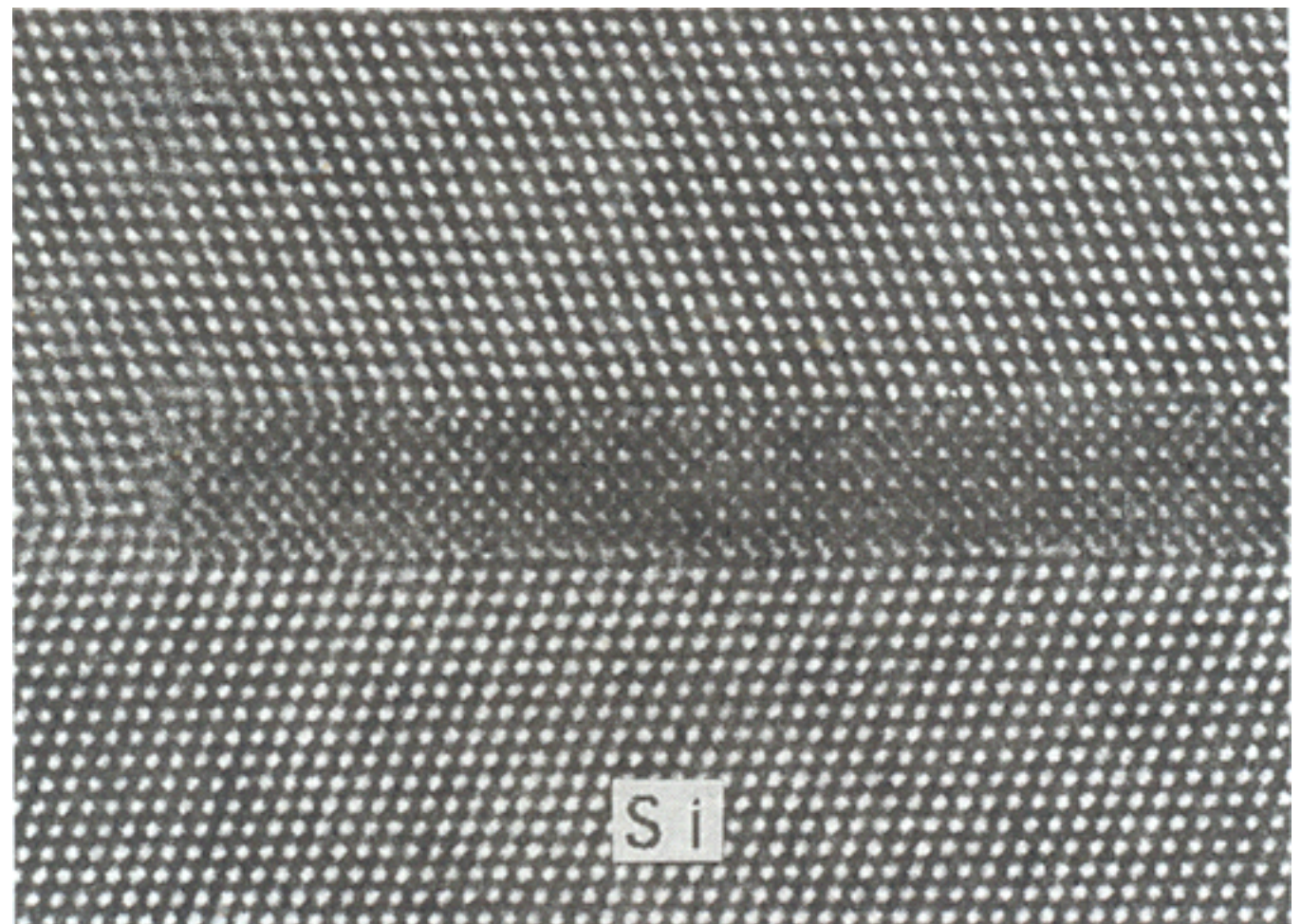
Example: TbSi₂/ Si Interface



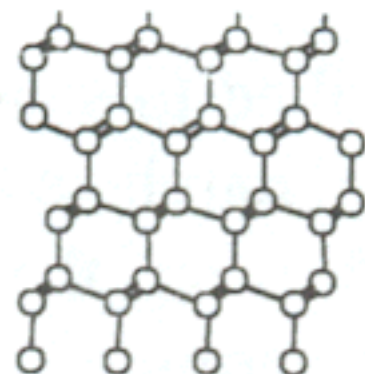
● Tb
○ Si



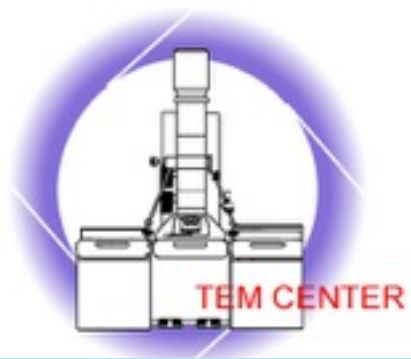
(a)



(b)



(c)



Displacement Map

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Analysis of Variations in Structure from High Resolution Electron Microscope Images by Combining Real Space and Fourier Space Information

Martin J. Hÿtch

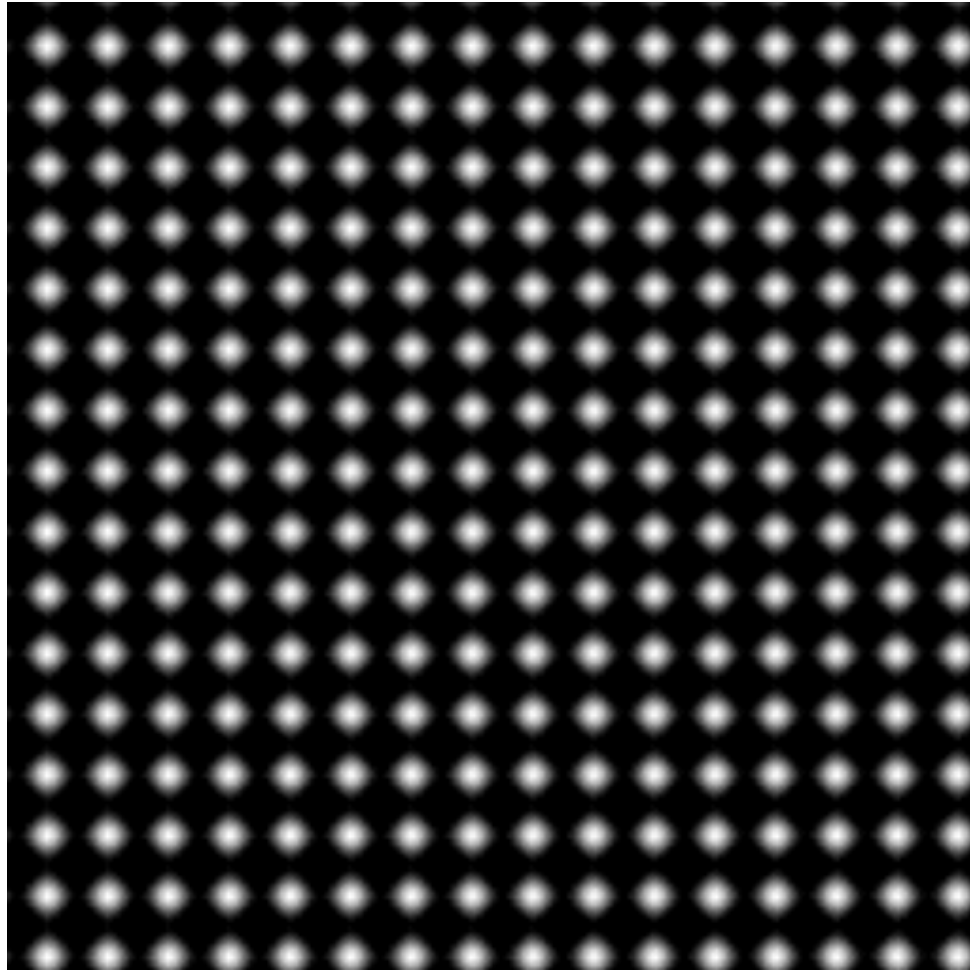
Microsc. Microanal. Microstruct. 8 (1997) 41–57

Quantitative measurement of displacement and strain fields from HREM micrographs

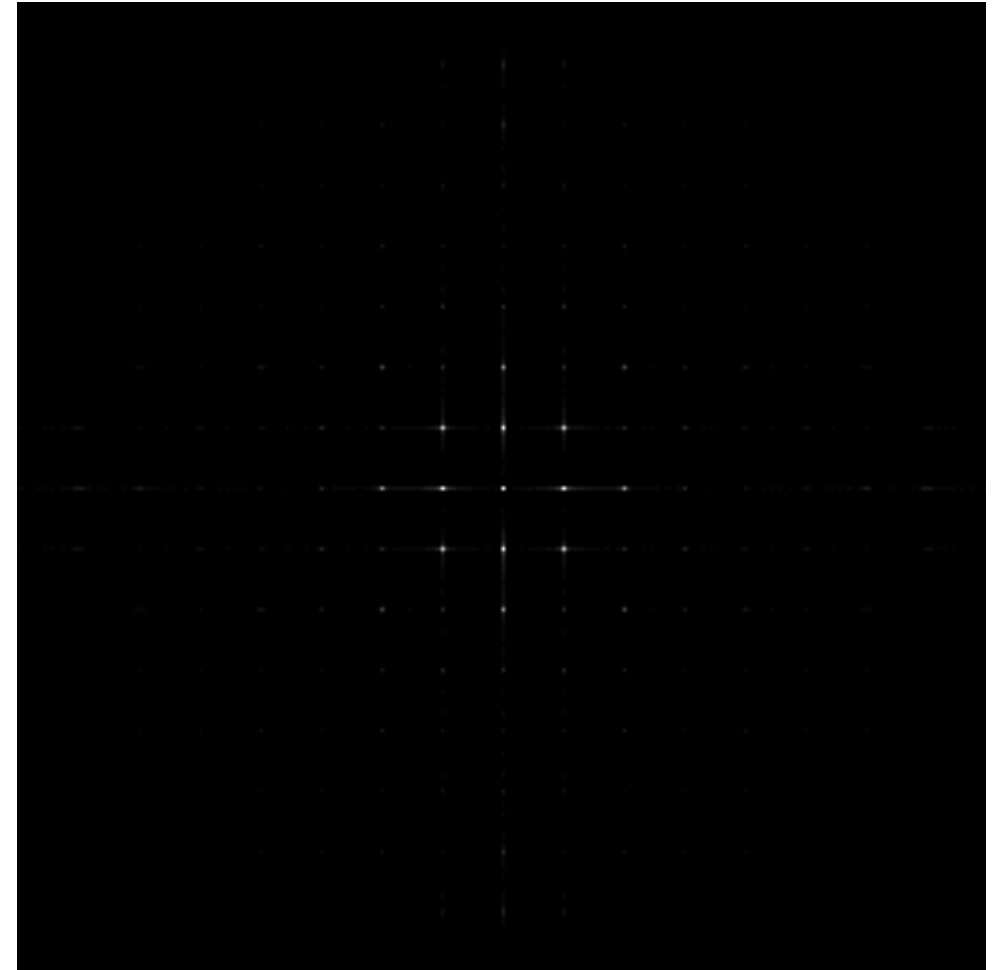
Ultramicroscopy 74 (1998) 131–146

M.J. Hÿtch^{a,*}, E. Snoeck^b, R. Kilaas^c

Background on Geometric Phase

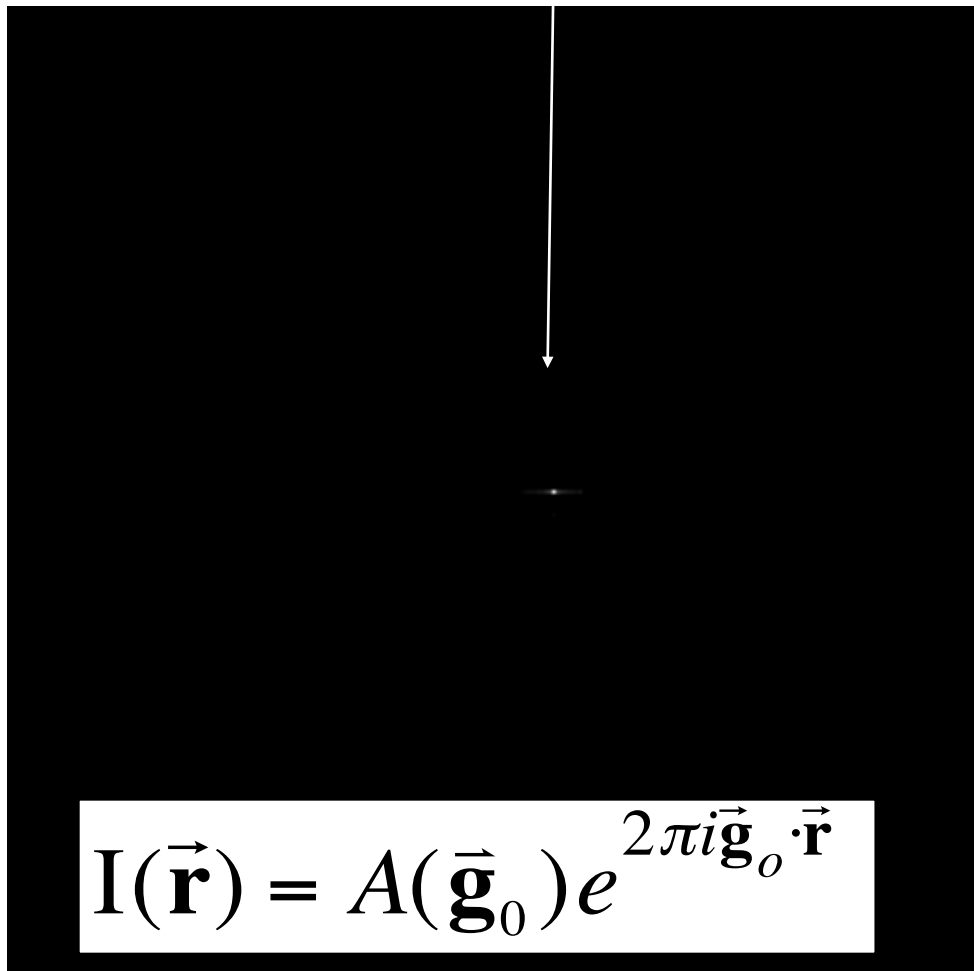
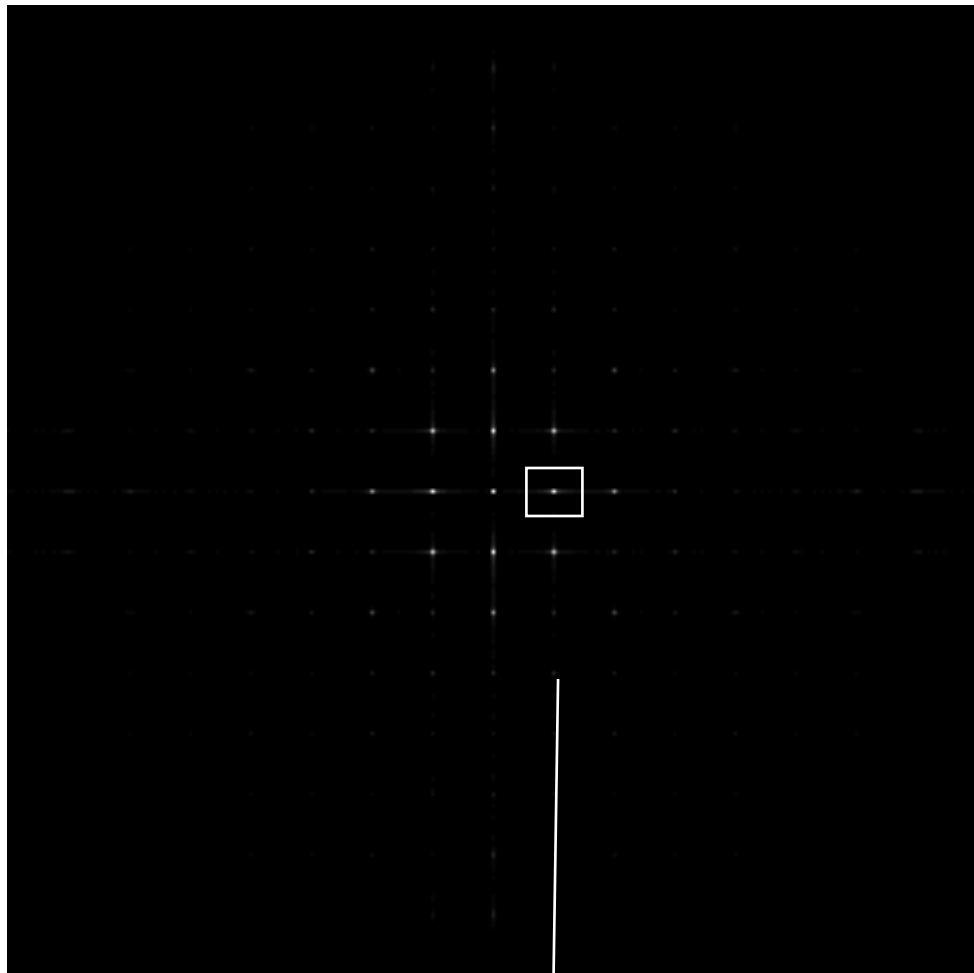


Fourier
Transform

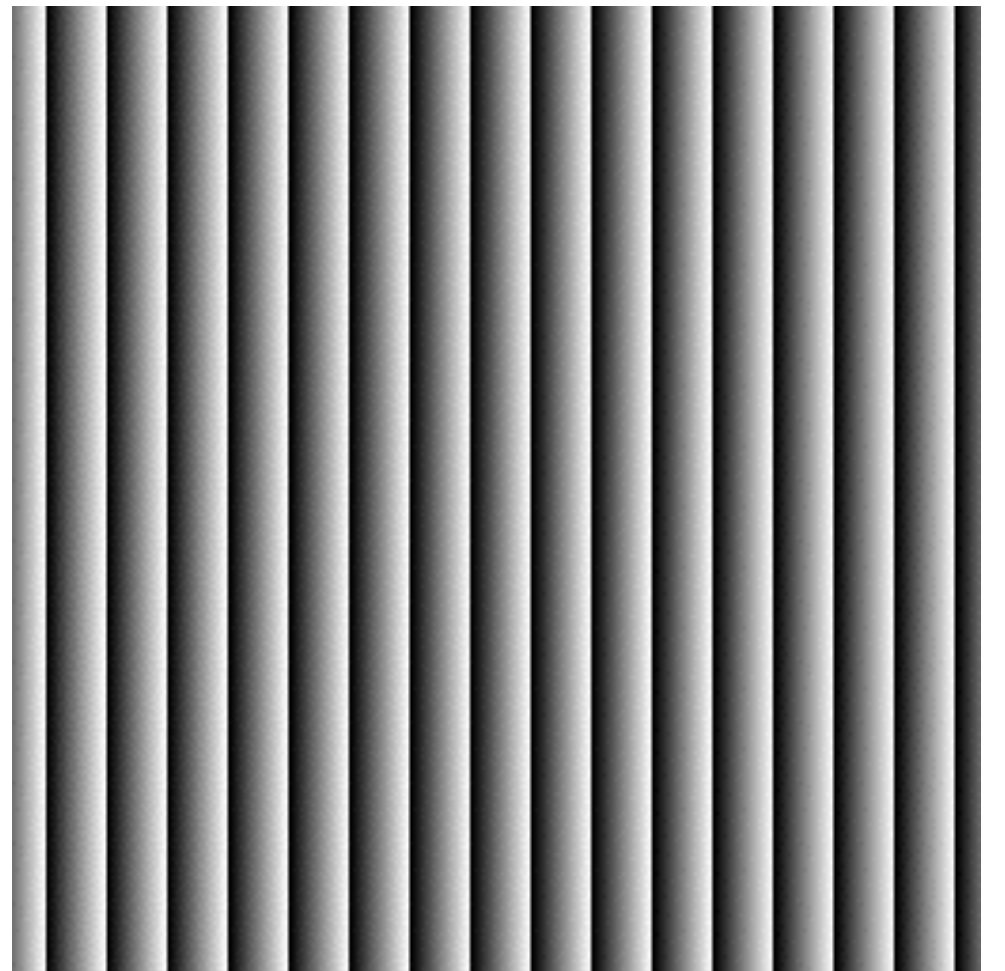
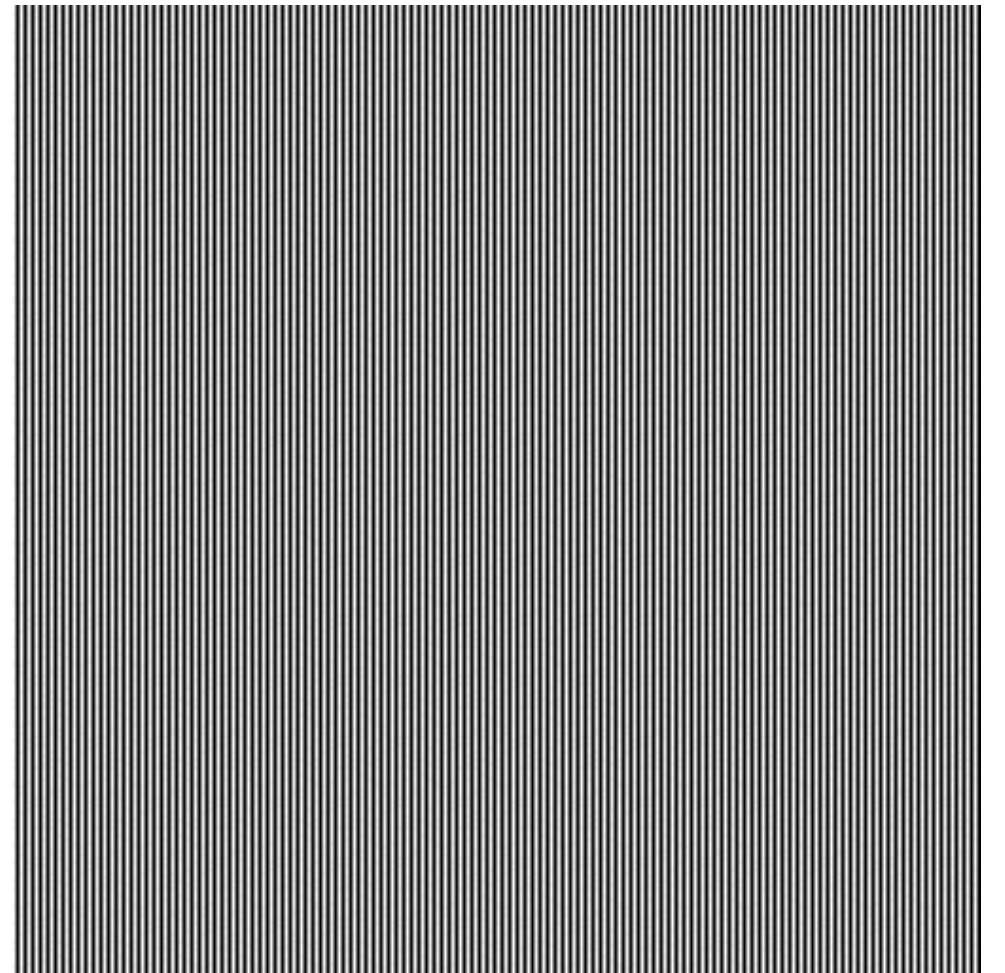
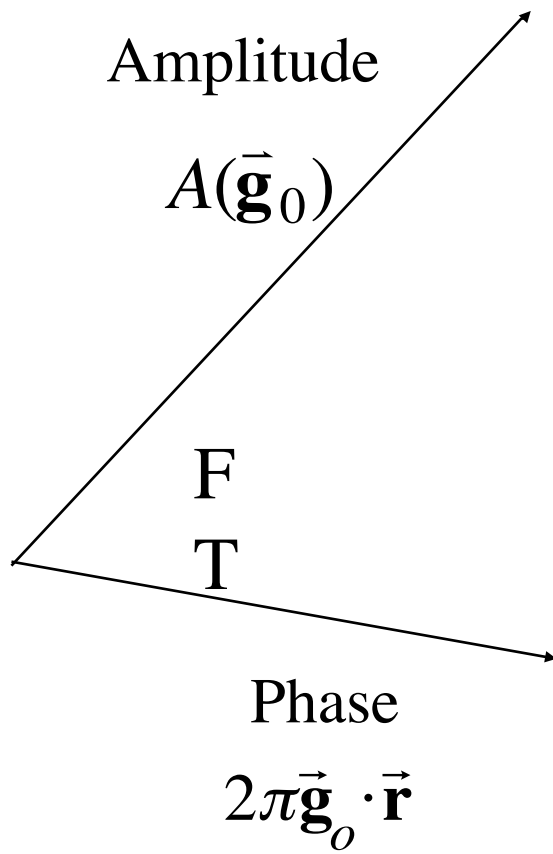


$$I(\vec{r}) = \sum_{\vec{g}} A(\vec{g}) e^{2\pi i \vec{g} \cdot \vec{r}}$$

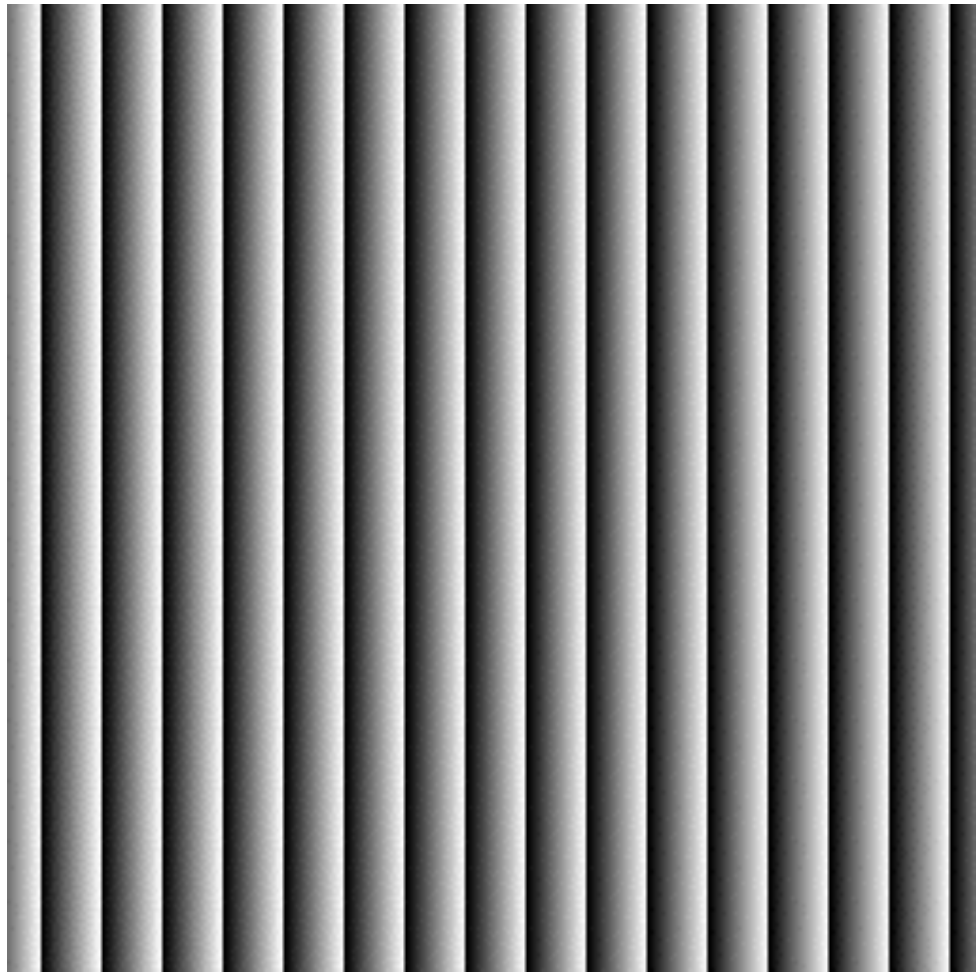
By Dr. Roar Kilaas



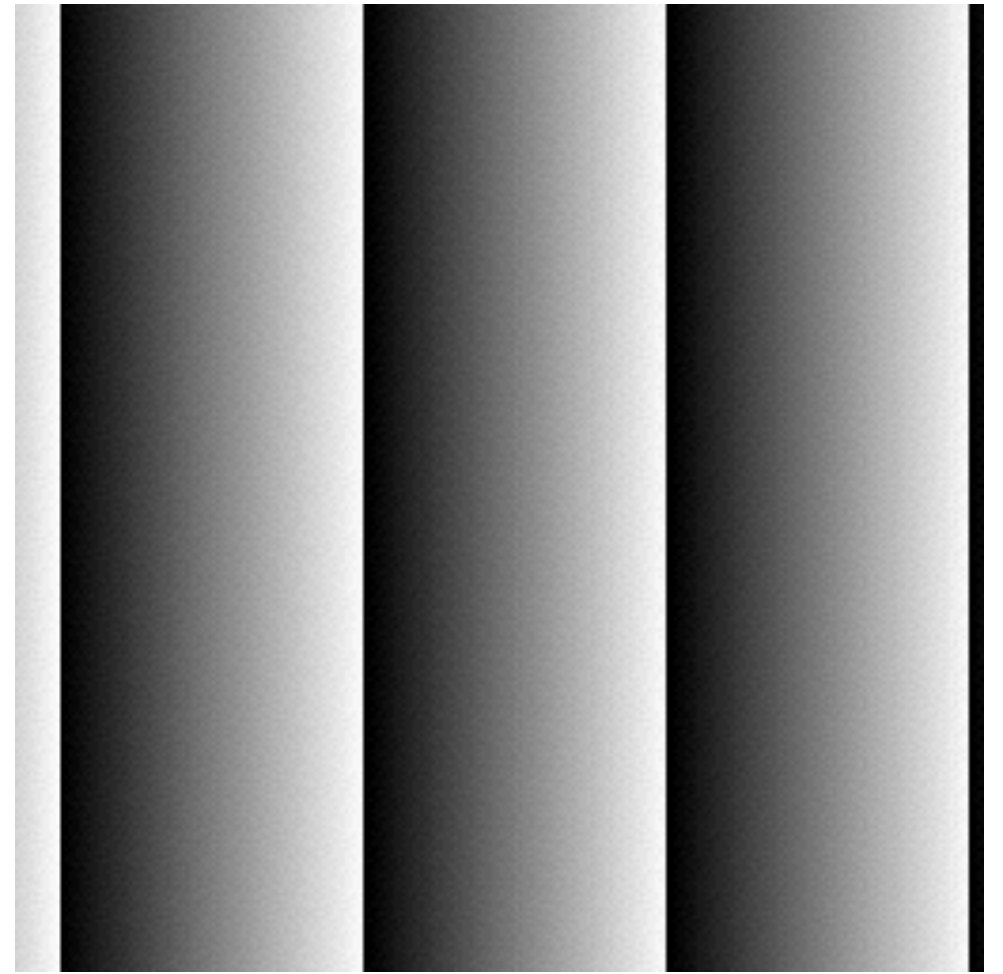
$$I(\vec{\mathbf{r}}) = A(\vec{\mathbf{g}}_0) e^{2\pi i \vec{\mathbf{g}}_0 \cdot \vec{\mathbf{r}}}$$



Digital Moire Images



$$\frac{2\pi\vec{g}_0 \cdot \vec{r}}{M} ; \quad M = 1$$



$$\frac{2\pi\vec{g}_0 \cdot \vec{r}}{M} ; \quad M = 5$$

Higher and higher magnification M is equivalent to shifting the reciprocal lattice vector closer and closer to the center of the Fourier transform. The phase image used for the displacement calculation is equivalent to $M \rightarrow \infty$, where subtracting off the term $2\pi\mathbf{g}_0 \cdot \mathbf{r}$ has the same effect as shifting the origin of the FT to the position of the reciprocal frequency \mathbf{g}_0

- Non perfect crystal - Small deviations from perfect lattice spacings

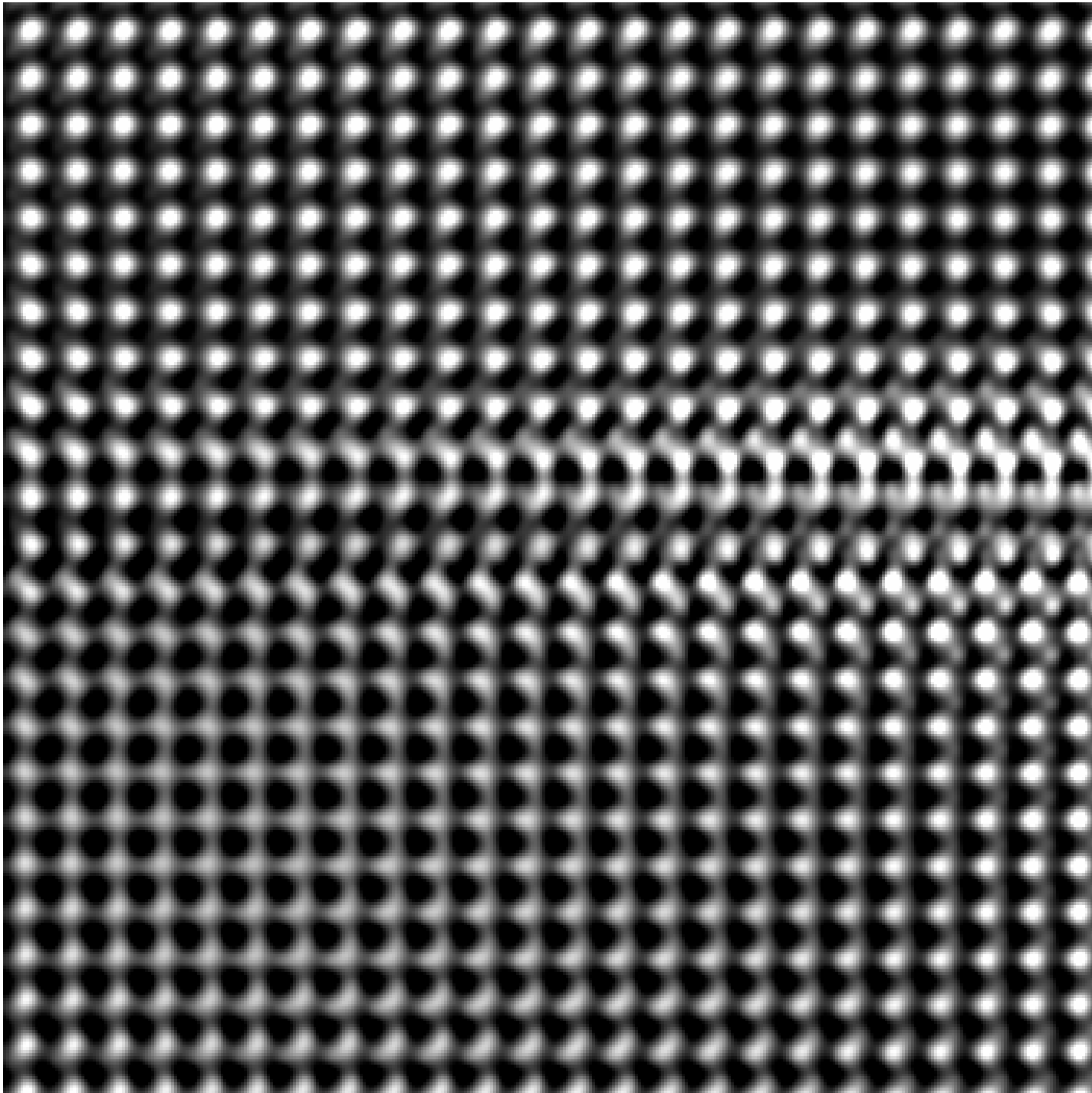
$$\mathbf{I}(\vec{\mathbf{r}}) = A(\vec{\mathbf{r}})e^{2\pi i\vec{\mathbf{g}}(\vec{\mathbf{r}})\cdot\vec{\mathbf{r}}} = A(\vec{\mathbf{r}})e^{2\pi i(\vec{\mathbf{g}}_0 + \Delta\vec{\mathbf{g}}(\vec{\mathbf{r}}))\cdot\vec{\mathbf{r}}}$$

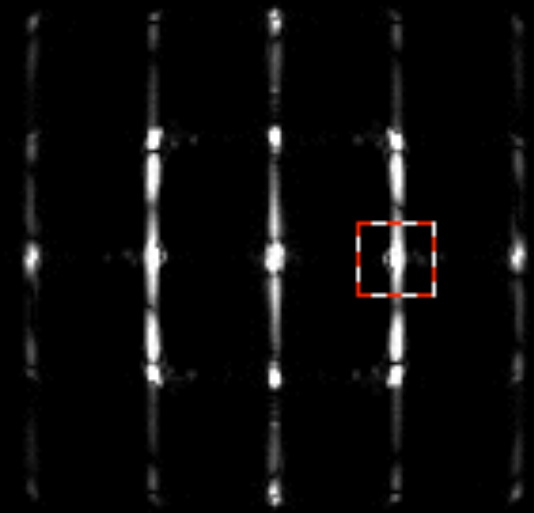
- Displacement Field description

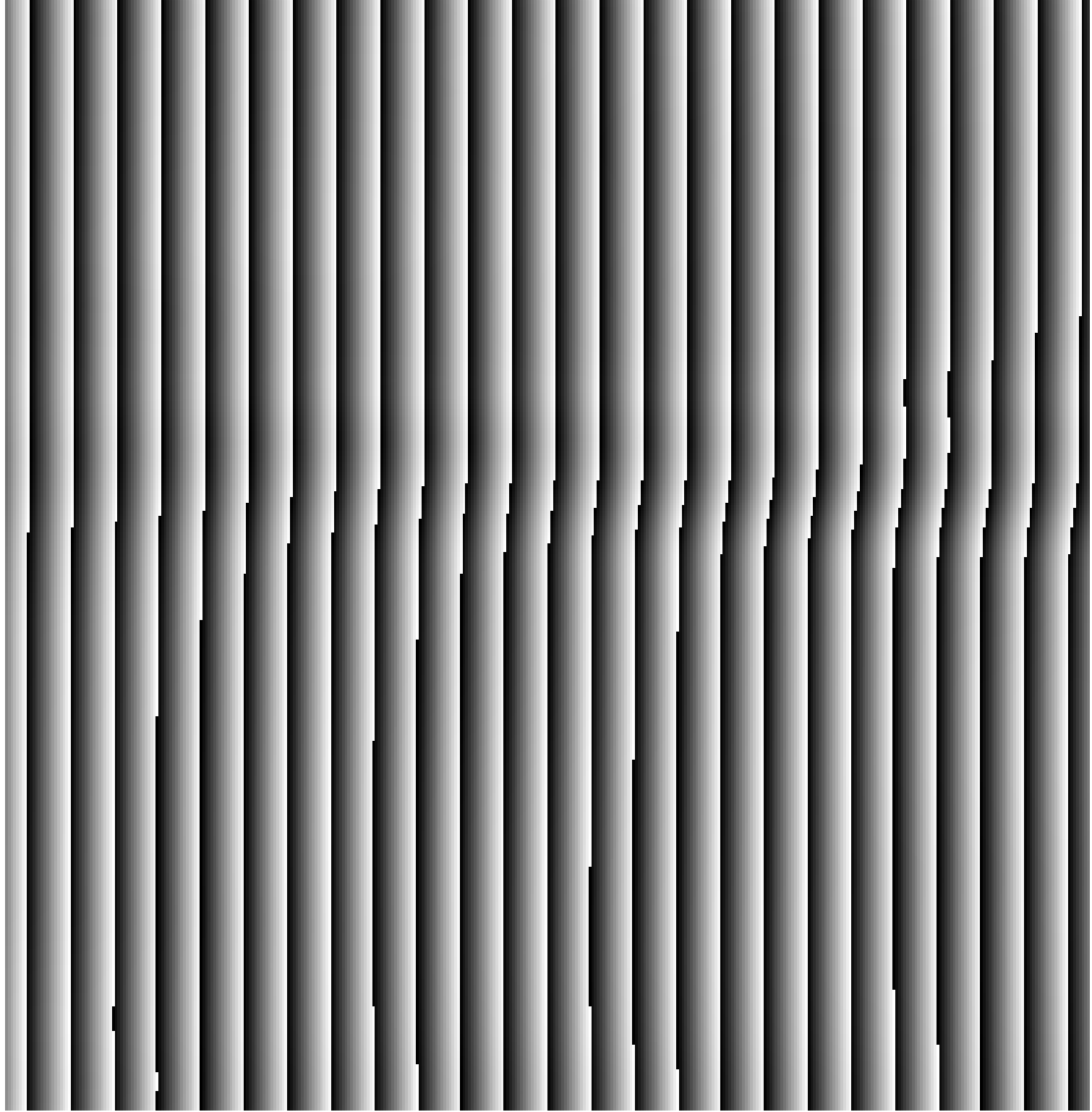
$$\begin{aligned} \vec{\mathbf{g}}(\vec{\mathbf{r}})\cdot\vec{\mathbf{r}} &= \frac{1}{u_0 + \delta(\vec{\mathbf{r}})} \hat{\mathbf{g}}_0 \cdot \vec{\mathbf{r}} = \\ &= \frac{1}{u_0} \hat{\mathbf{g}}_0 \cdot \vec{\mathbf{r}} - \frac{1}{u_0} \hat{\mathbf{g}}_0 \cdot \frac{\delta(\vec{\mathbf{r}})}{u_0} \vec{\mathbf{r}} = \vec{\mathbf{g}}_0 \cdot \vec{\mathbf{r}} - \vec{\mathbf{g}}_0 \cdot \Delta\mathbf{u}(\vec{\mathbf{r}}) \end{aligned}$$

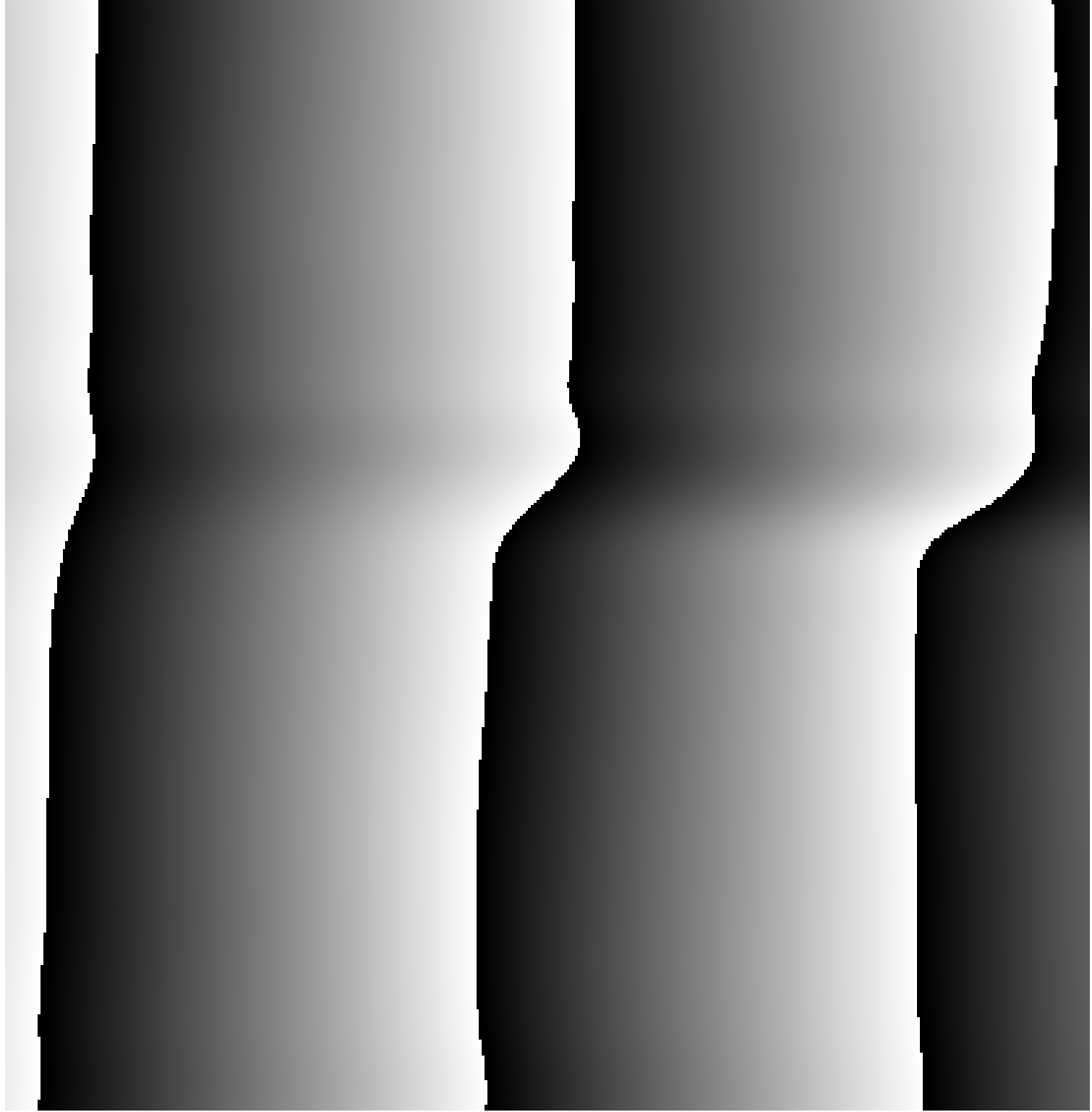
- Amplitude and Phase

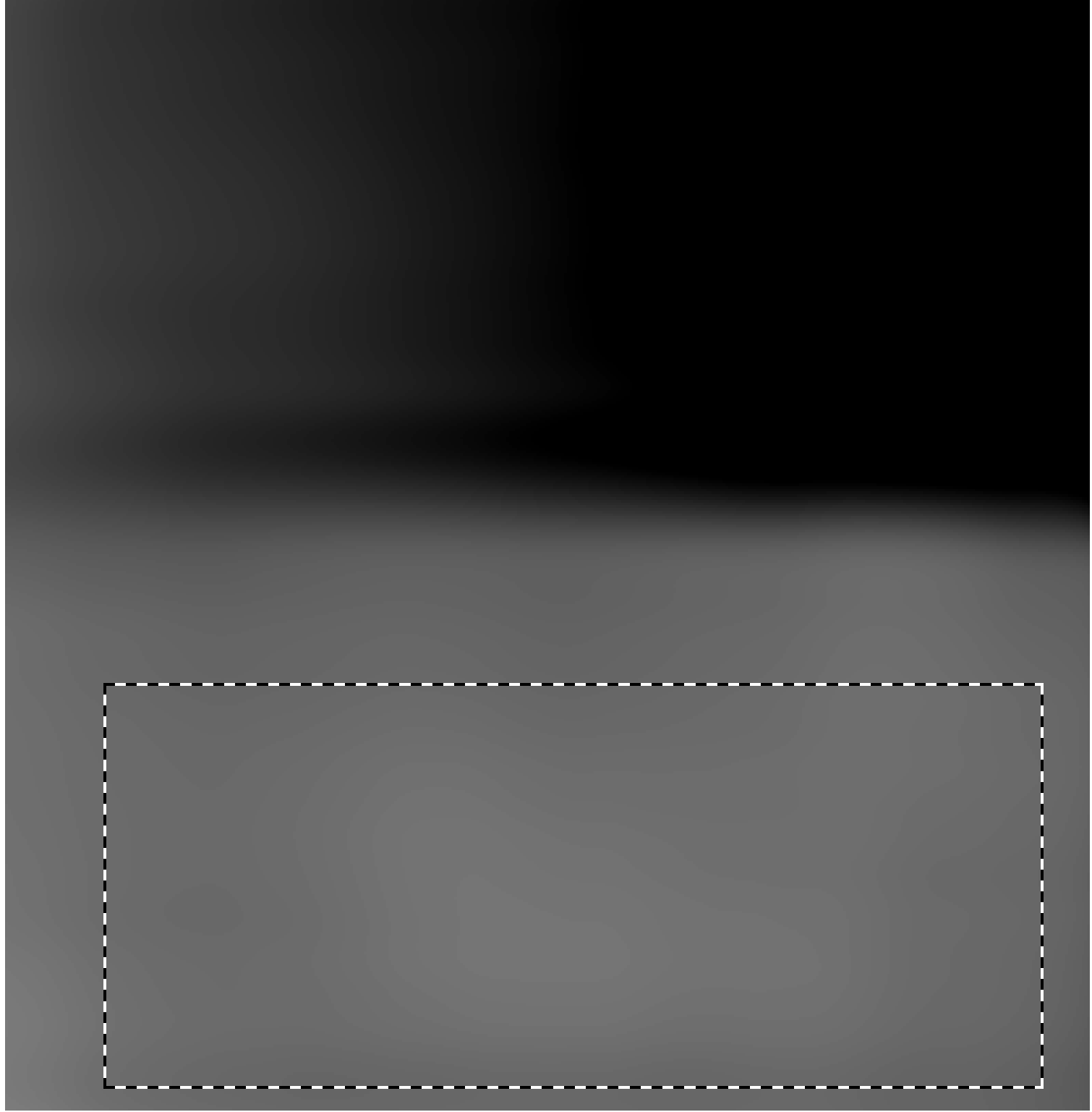
$$\begin{aligned}
 I(\mathbf{r}) &= A(\mathbf{r}) e^{2\pi i \mathbf{g}(\mathbf{r}) \cdot \mathbf{r}} = A(\mathbf{r}) e^{2\pi i (\mathbf{g}_0 + \Delta \mathbf{g}(\mathbf{r})) \cdot \mathbf{r}} \\
 &= A(\mathbf{r}) e^{2\pi i (\mathbf{g}_0 \cdot \mathbf{r} + \mathbf{g}_0 \cdot \Delta \mathbf{u}(\mathbf{r}))} = A(\mathbf{r}) \exp(iP(\mathbf{r}))
 \end{aligned}$$

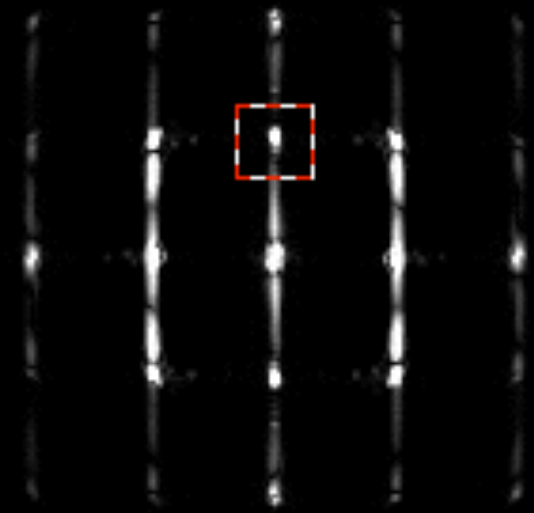


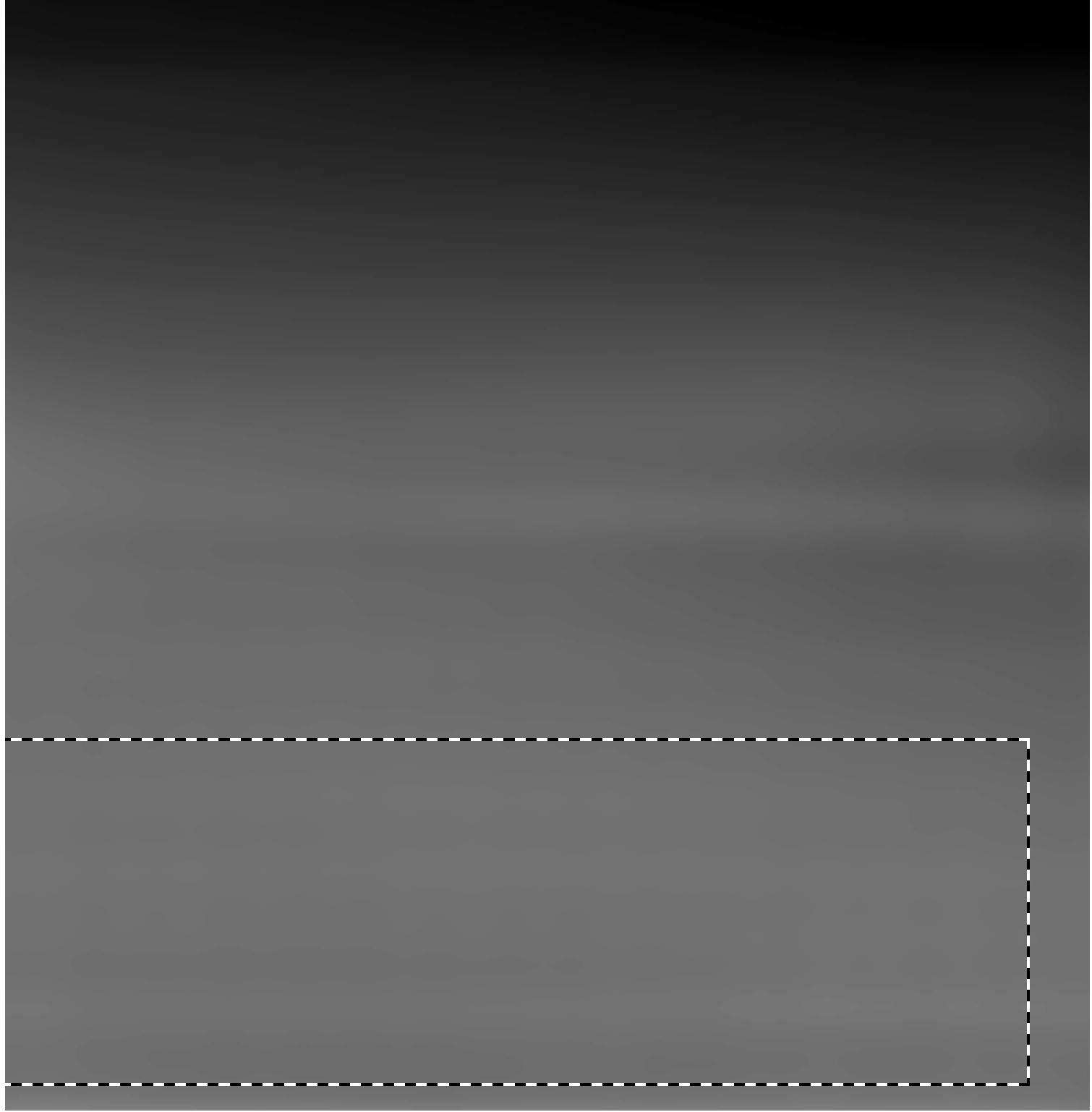












Displacement Field Calculation

- Requires 2 phase images from 2 different reflections
- Implicit definition of a reference lattice

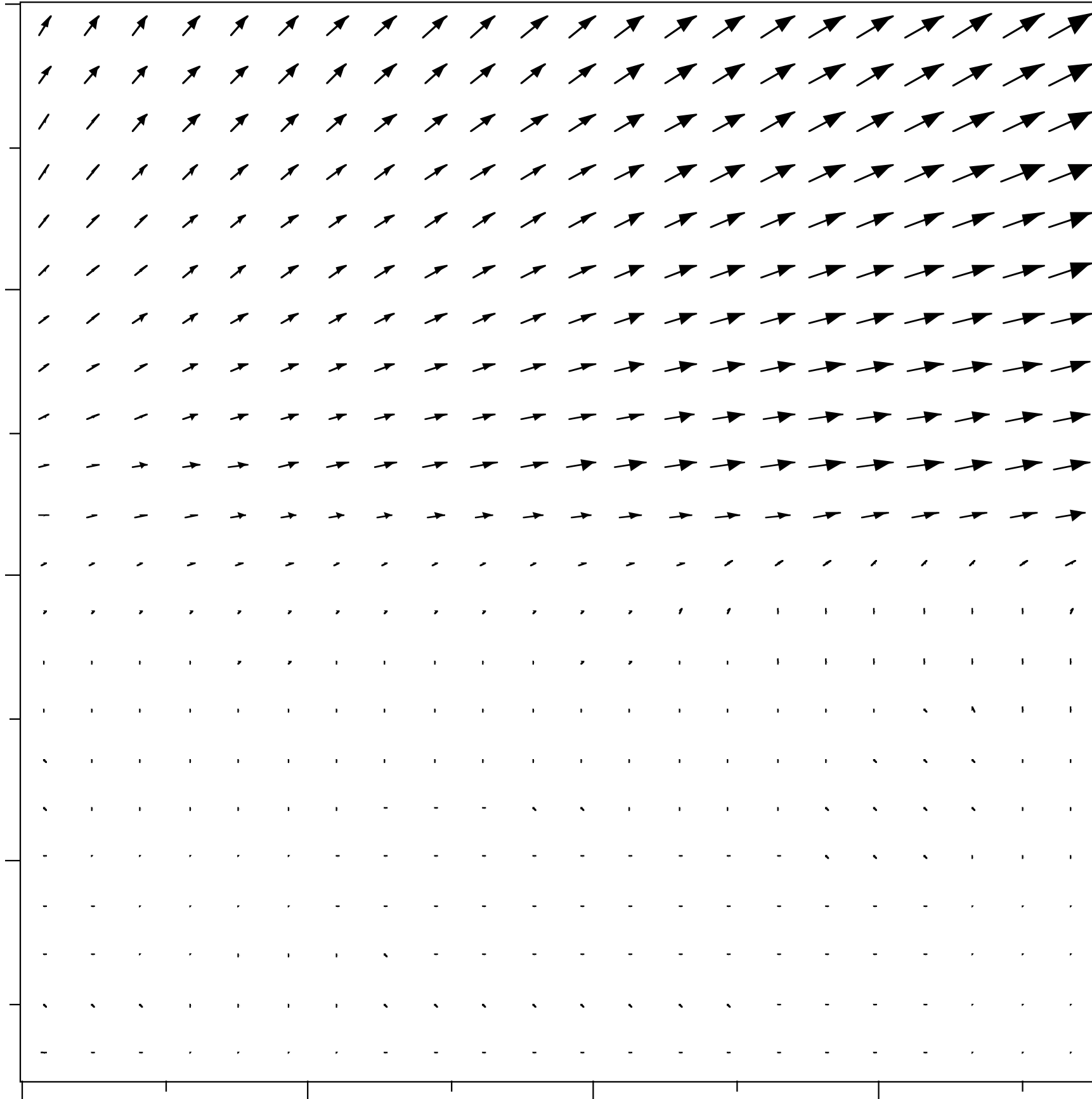
$$P_{g_1}(\vec{r}) = 2\pi \vec{g}_1 \cdot \vec{u}(\vec{r}) = 2\pi(g_{1x} \cdot u_x(\vec{r}) + g_{1y} \cdot u_y(\vec{r}))$$

$$P_{g_2}(\vec{r}) = 2\pi \vec{g}_2 \cdot \vec{u}(\vec{r}) = 2\pi(g_{2x} \cdot u_x(\vec{r}) + g_{2y} \cdot u_y(\vec{r}))$$

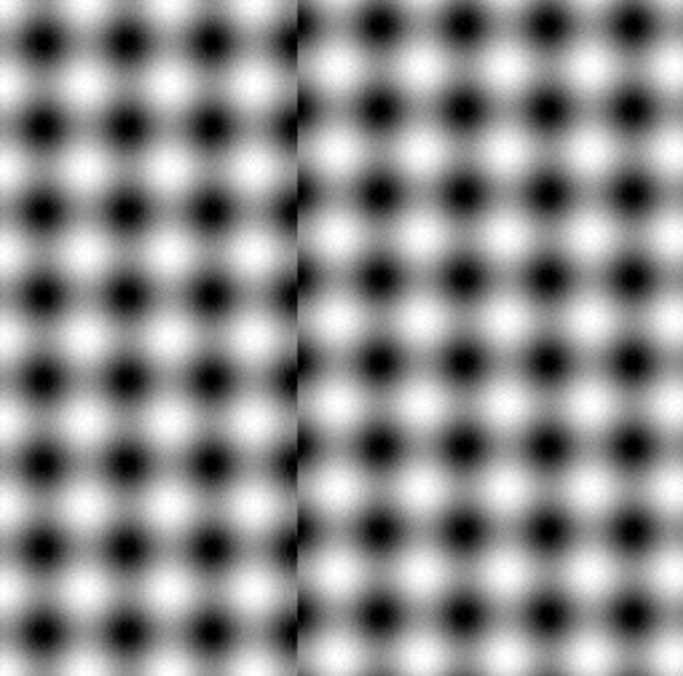
- Solution for the displacements with respect to the reference lattice

$$u_x(\vec{r}) = \frac{1}{2\pi} \left(\frac{P_{g_1}(\vec{r}) \cdot g_{2y} - P_{g_2}(\vec{r}) \cdot g_{1y}}{g_{1x} \cdot g_{2y} - g_{1y} \cdot g_{2x}} \right)$$

$$u_y(\vec{r}) = \frac{1}{2\pi} \left(\frac{P_{g_2}(\vec{r}) \cdot g_{1x} - P_{g_1}(\vec{r}) \cdot g_{2x}}{g_{1x} \cdot g_{2y} - g_{1y} \cdot g_{2x}} \right)$$



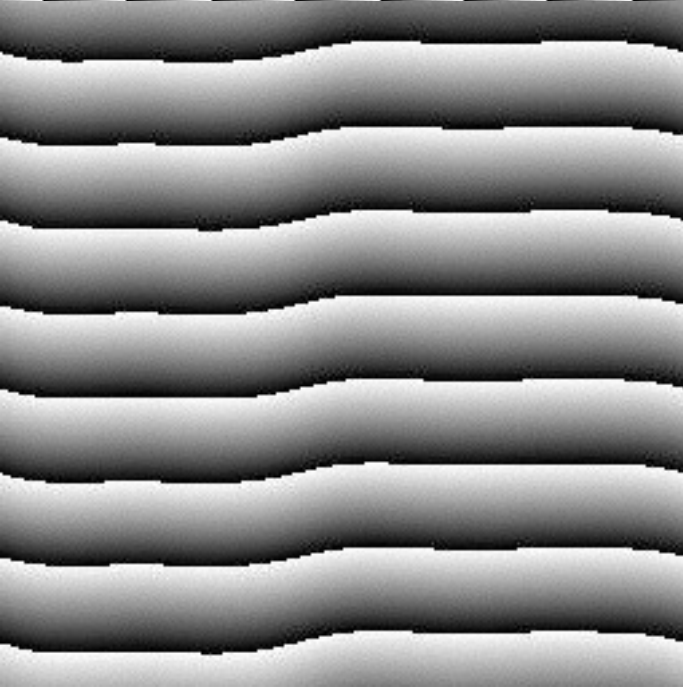
Shift Case



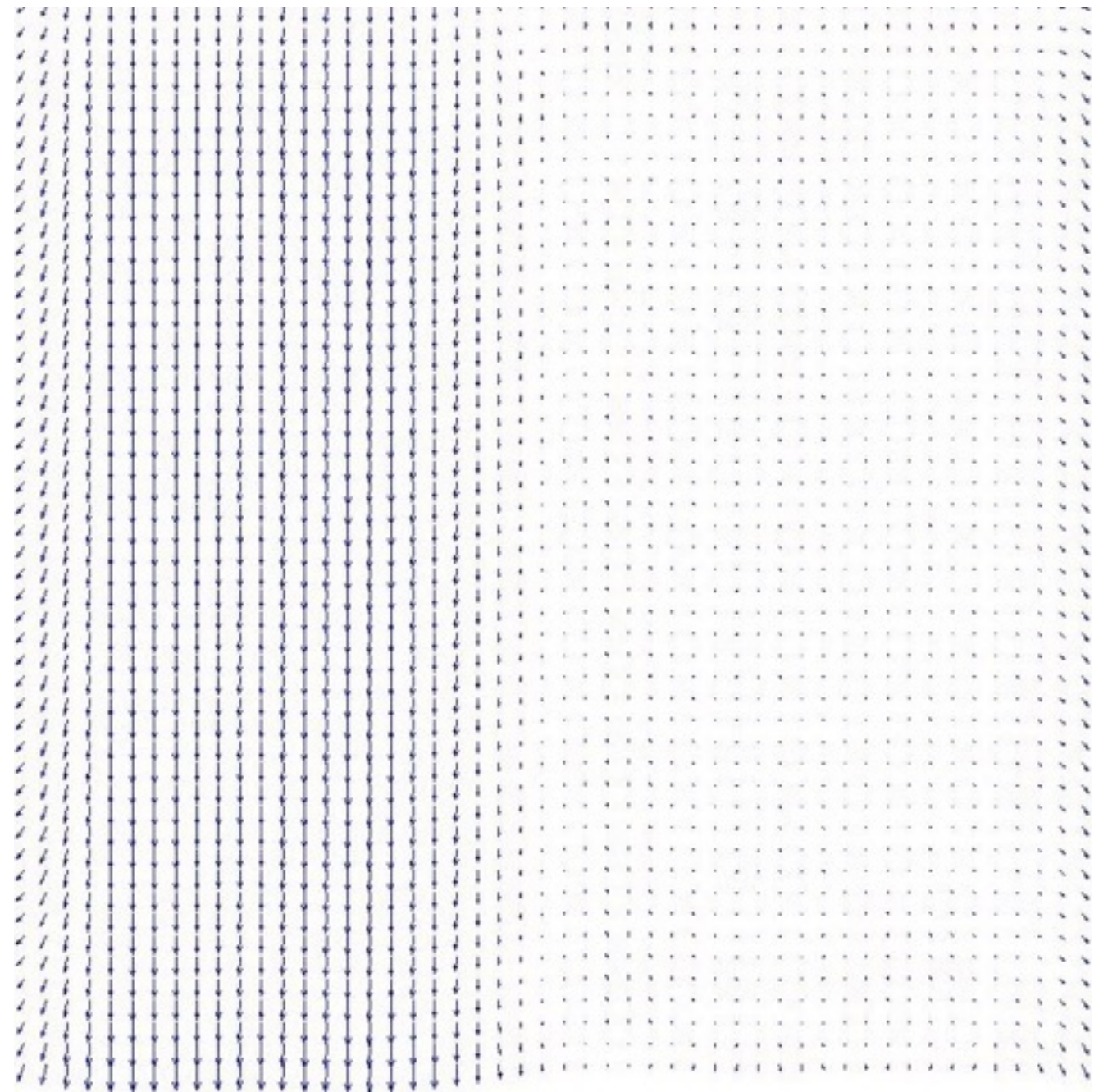
object



phase1

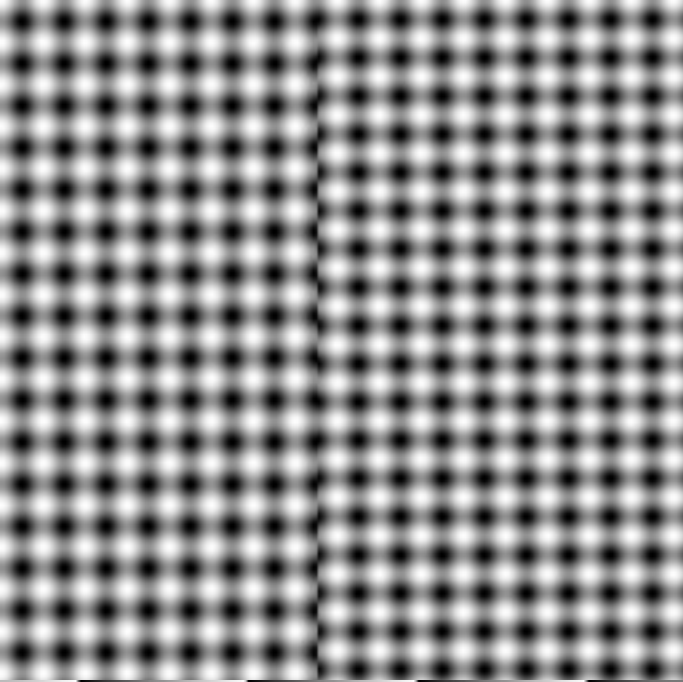


phase2

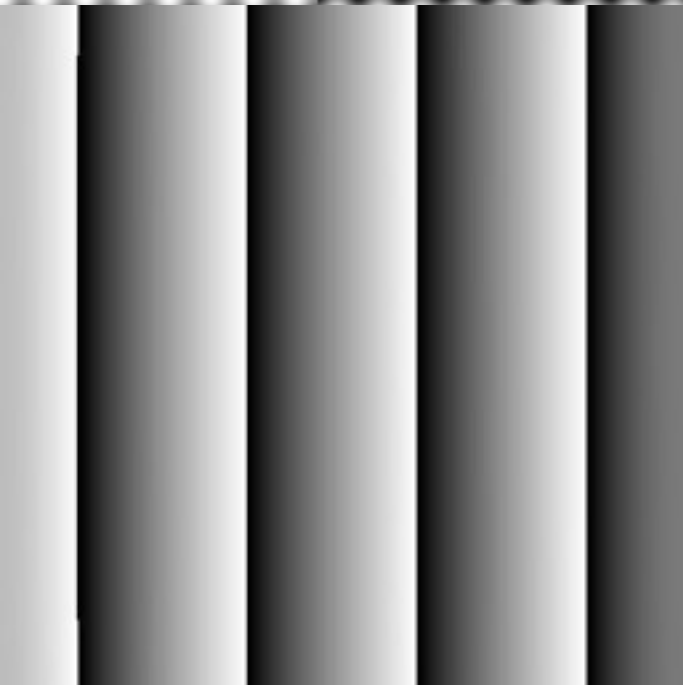


Displacement map

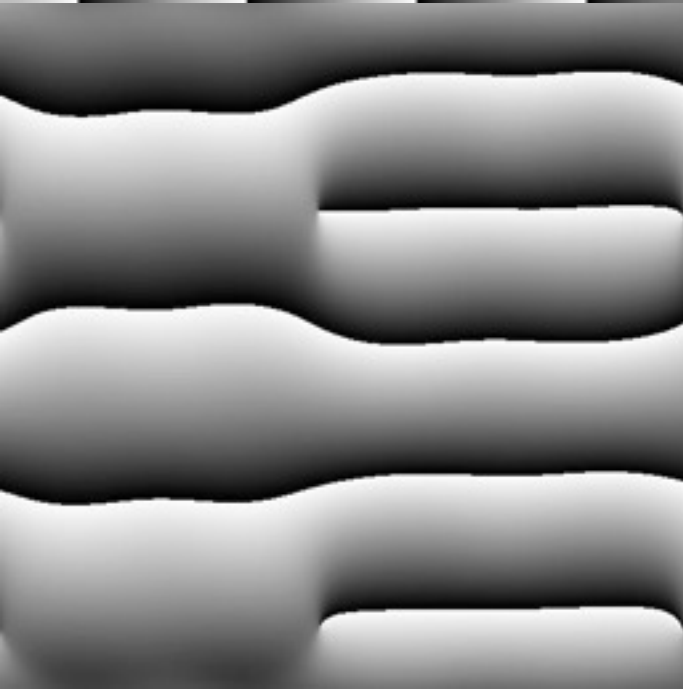
Dilatation Case



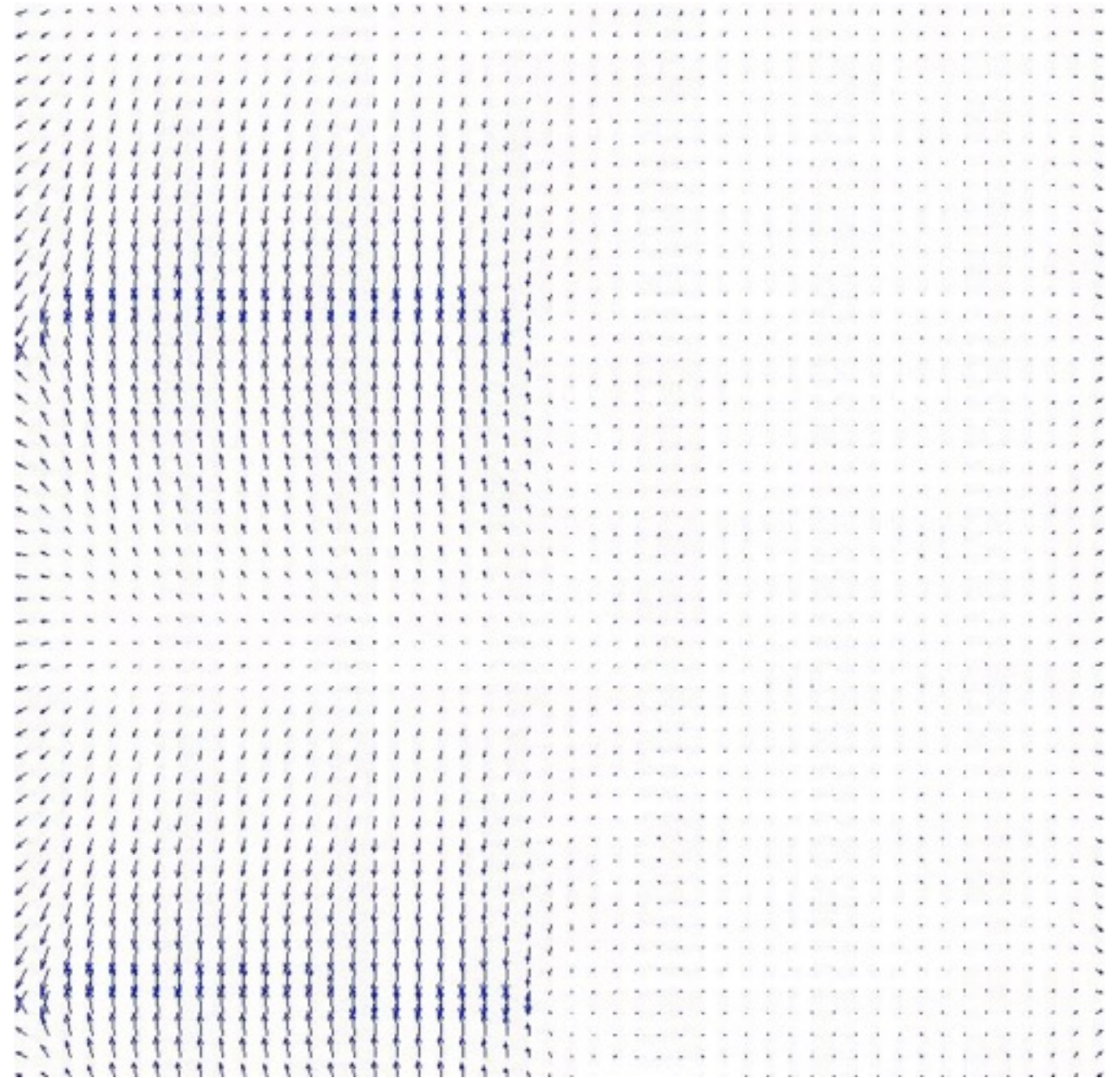
object



phase1

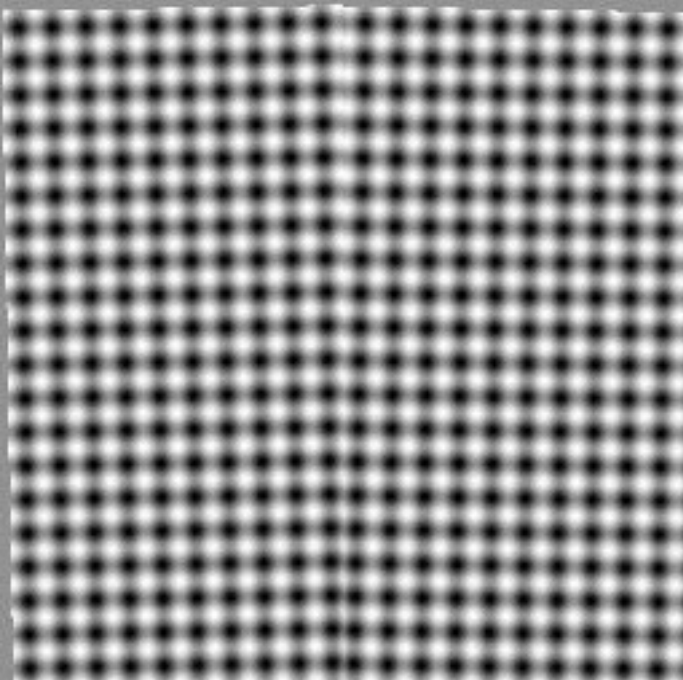


phase2

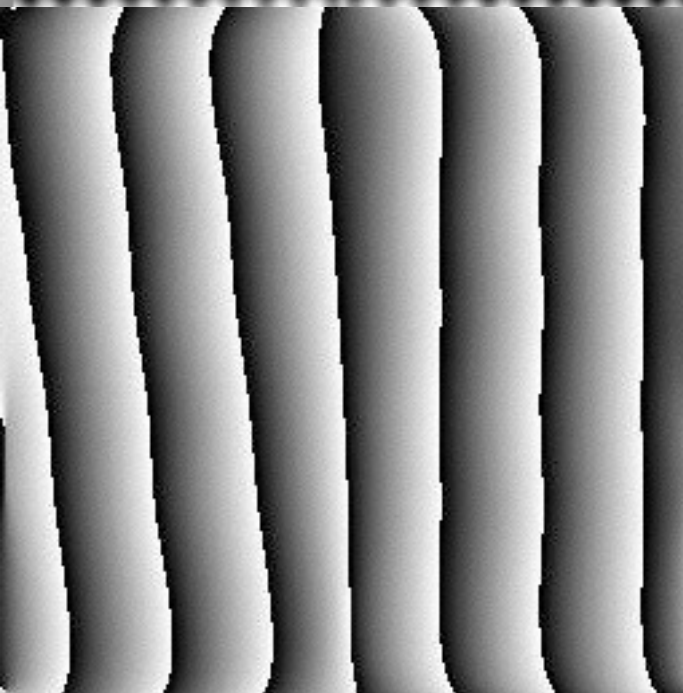


Displacement map

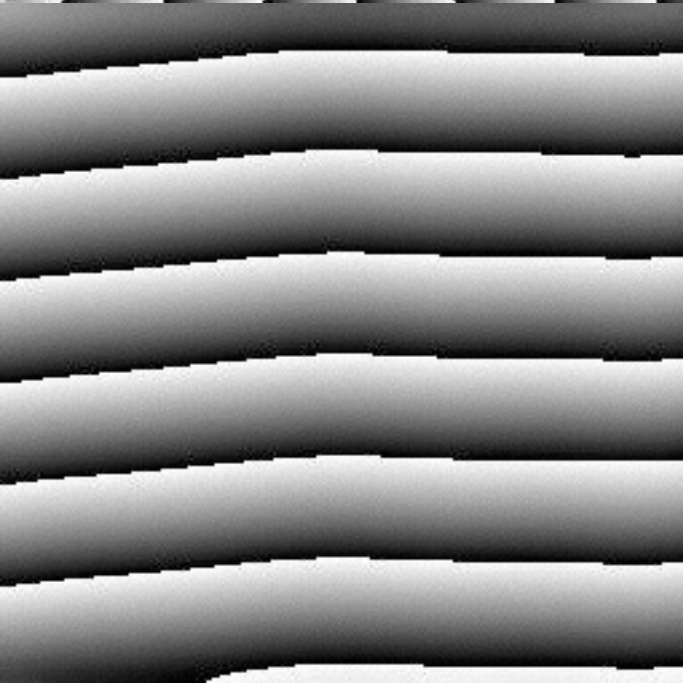
Rotation Case



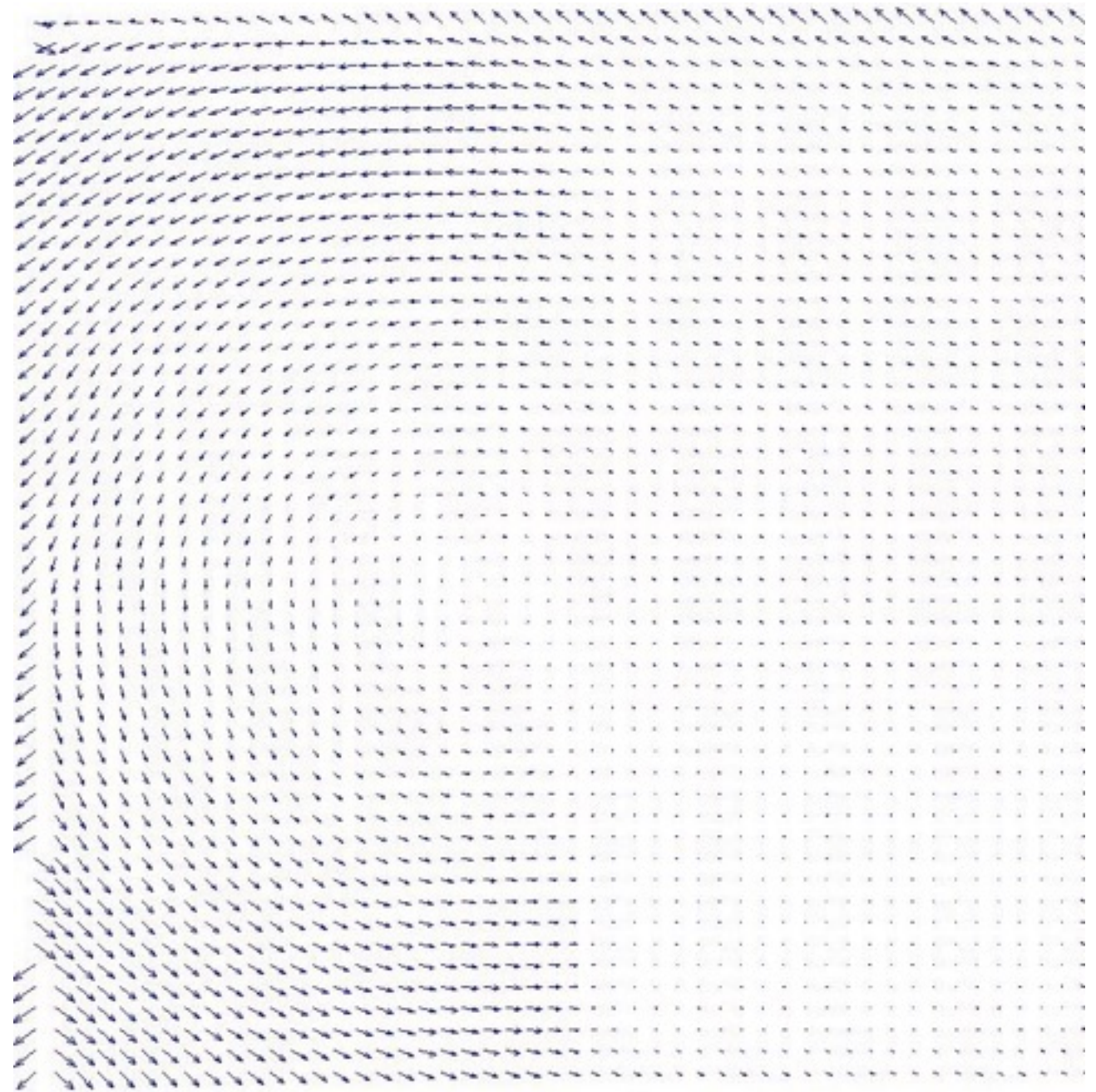
object



phase1



phase2

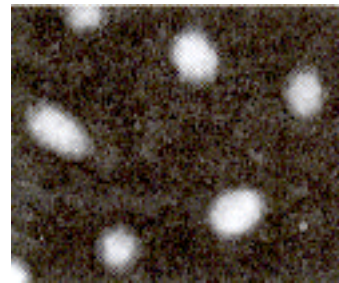


Displacement map

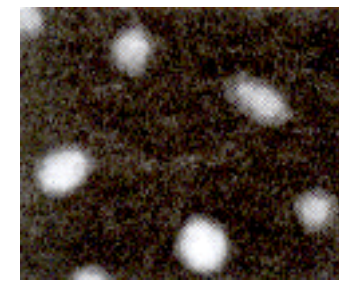
Alternative Strain Map

Template matching- cross correlation

Template



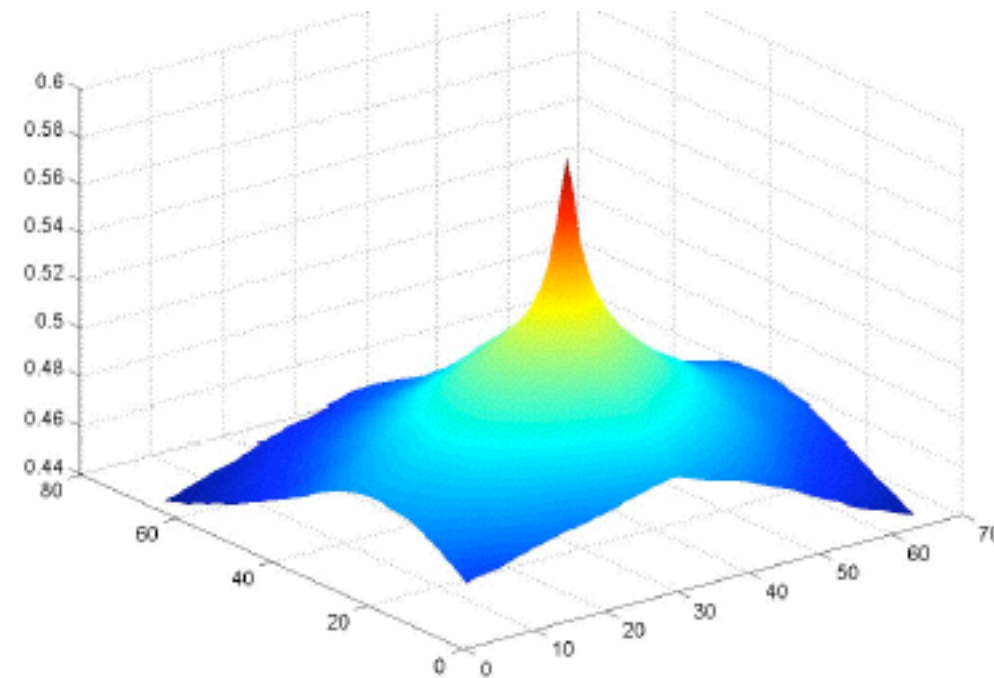
I1



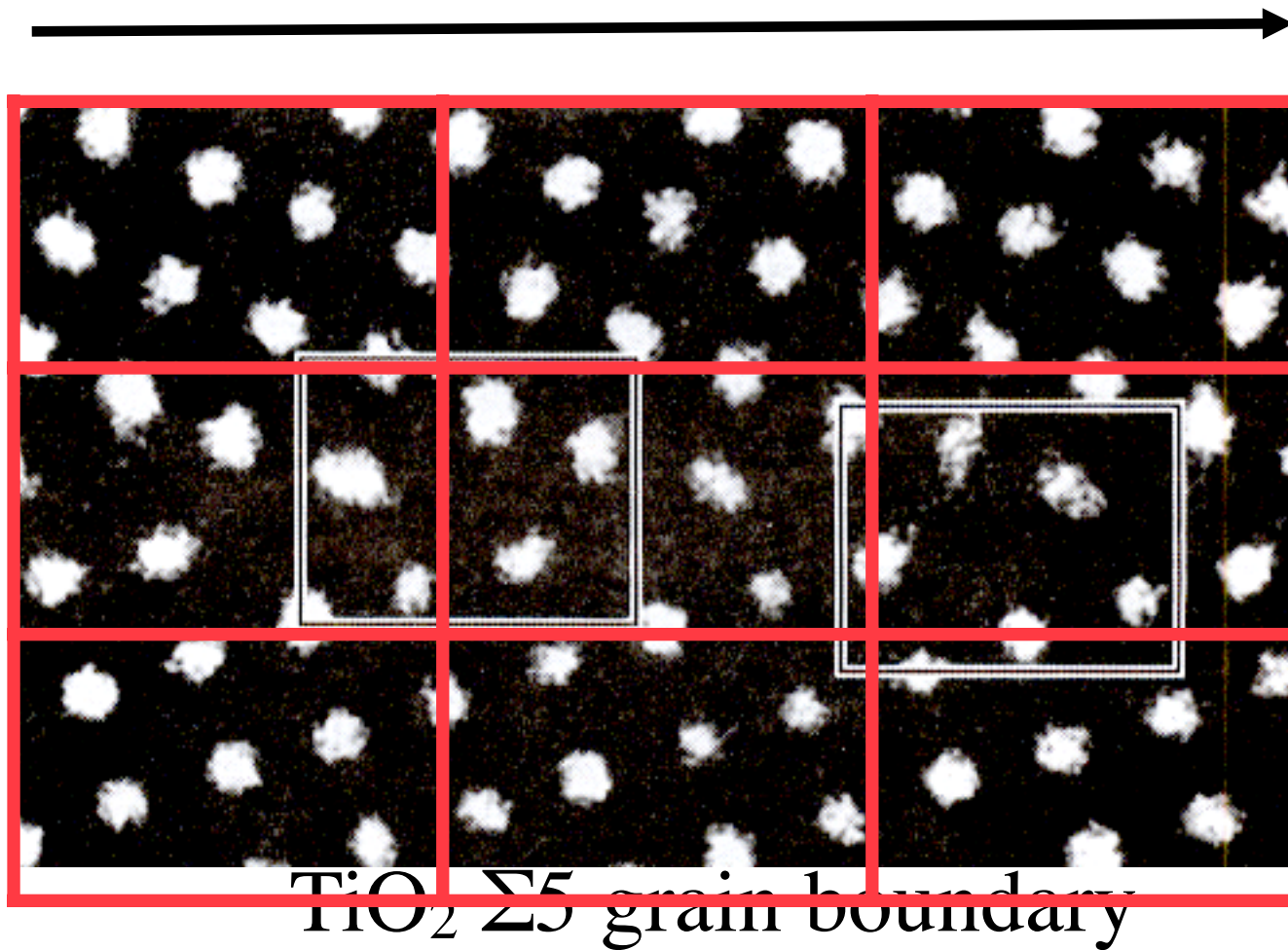
object

I2

$$ccf = \frac{\mathfrak{F}(I_1)\mathfrak{F}(I_2^*)}{|I_1||I_2|}$$



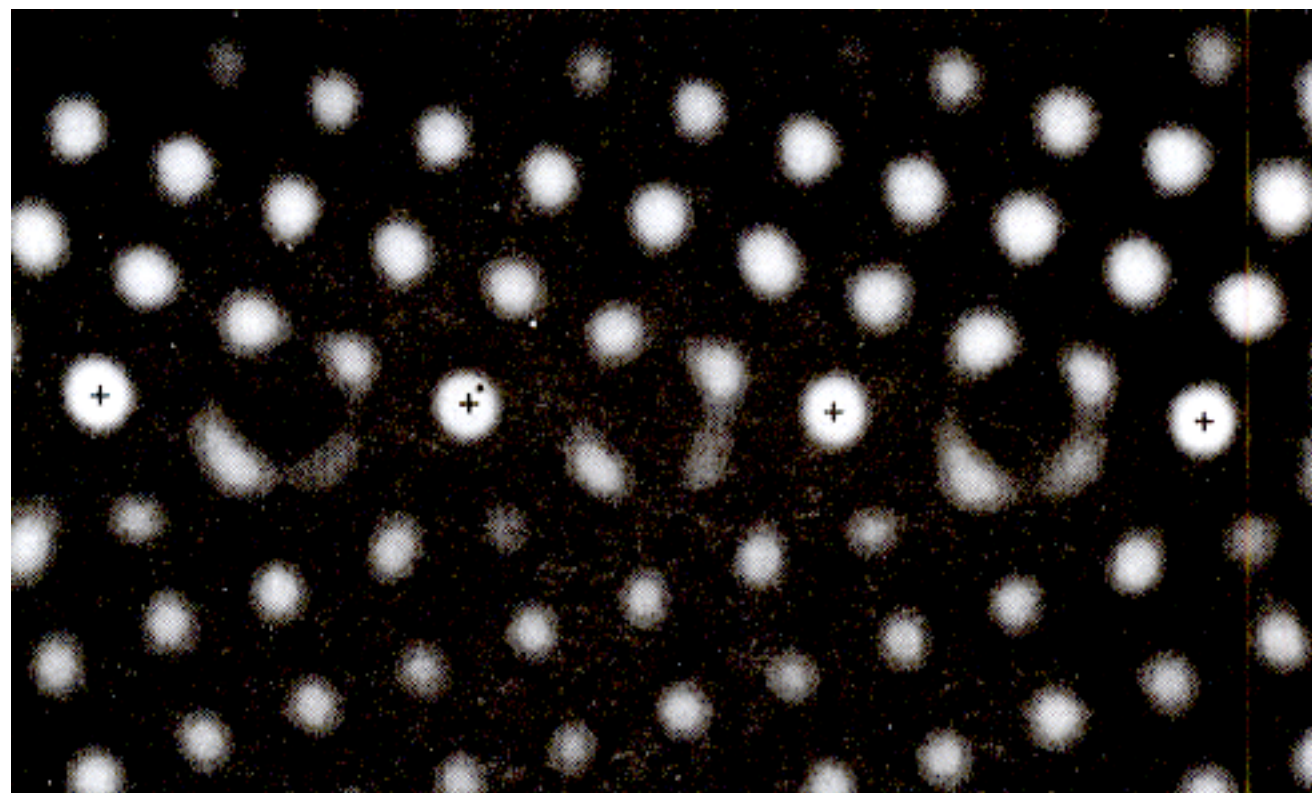
The value of ccf give an indication of similarity of two images



1. Scanning the template across the object image

2. Generating CCF map

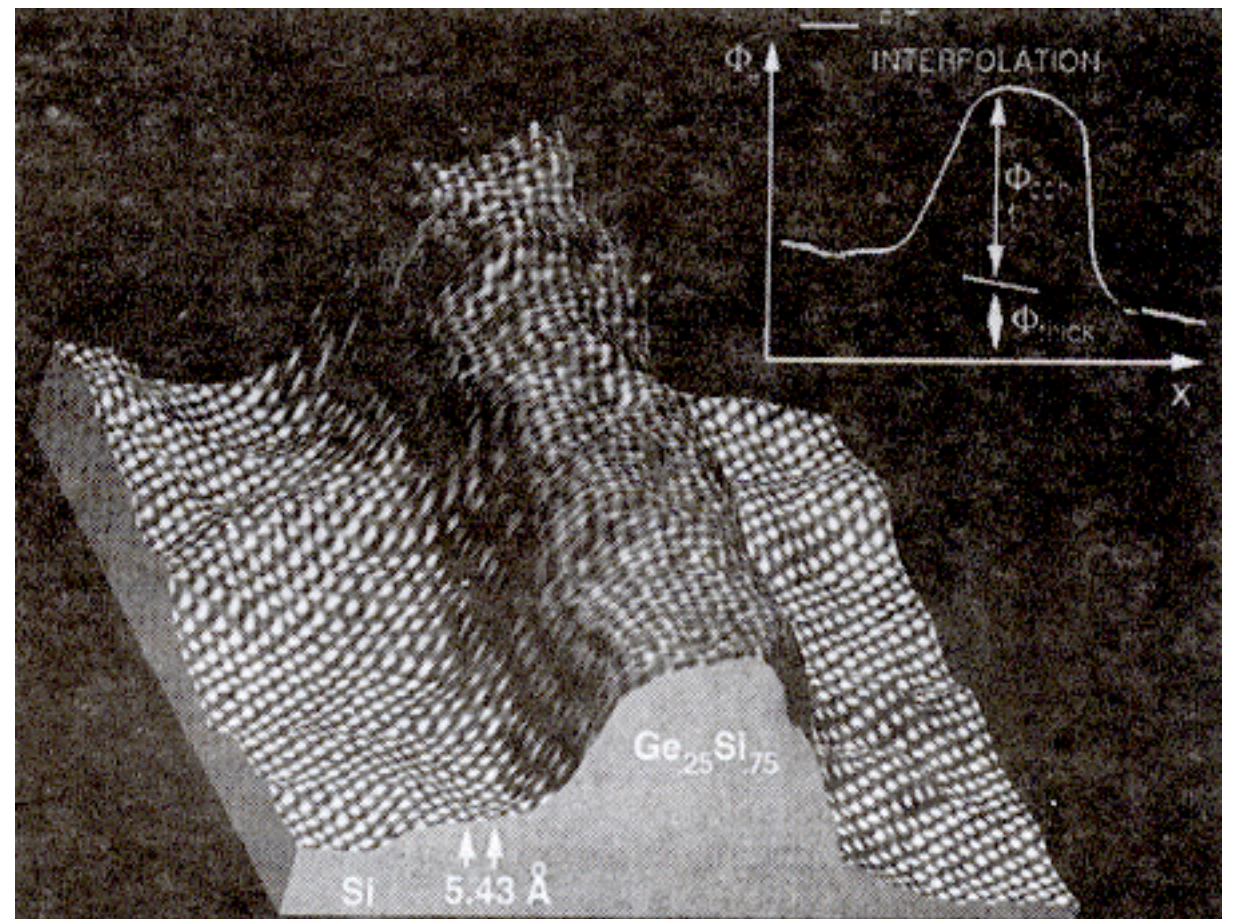
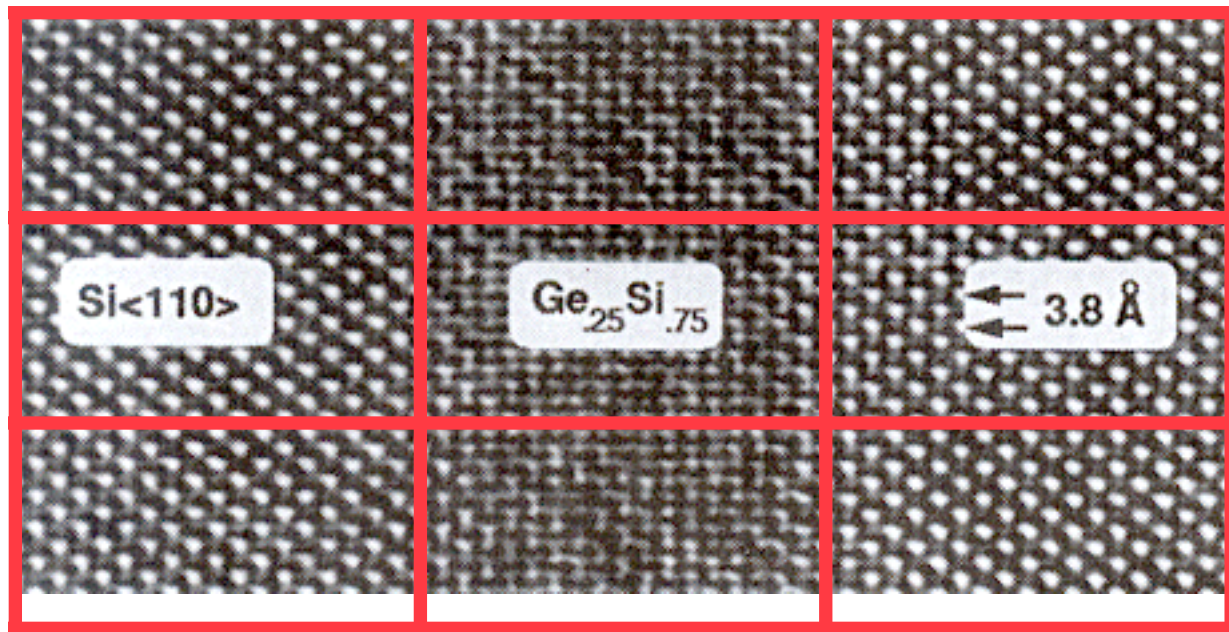
Pattern Recognition
for structure
identification



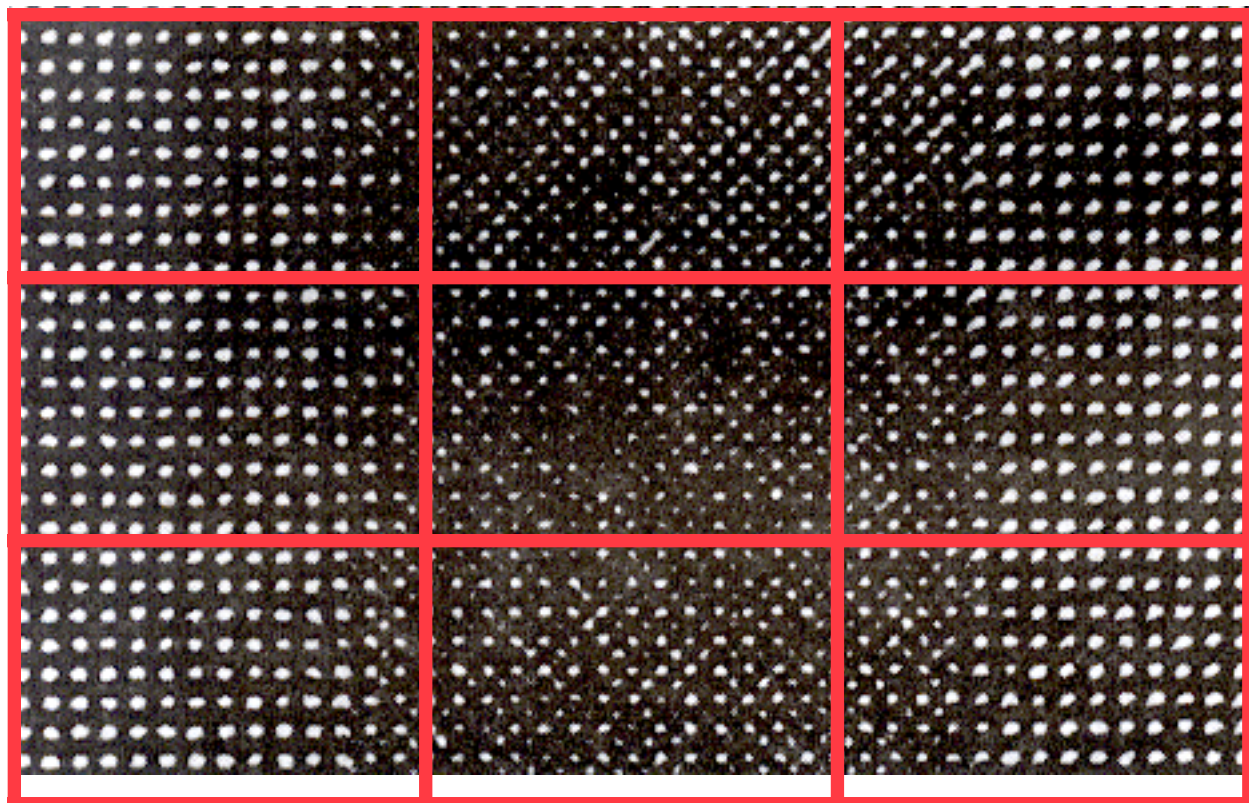
ccf map

Atom Resolution Compositional Map

Si/GeSi quantum well



(Al)GaAs GaAs (Al)GaAs



CCF map with HRTEM skin

